

# New developments in solid state photomultipliers

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*&*

*Fermilab, Batavia*

# Outline

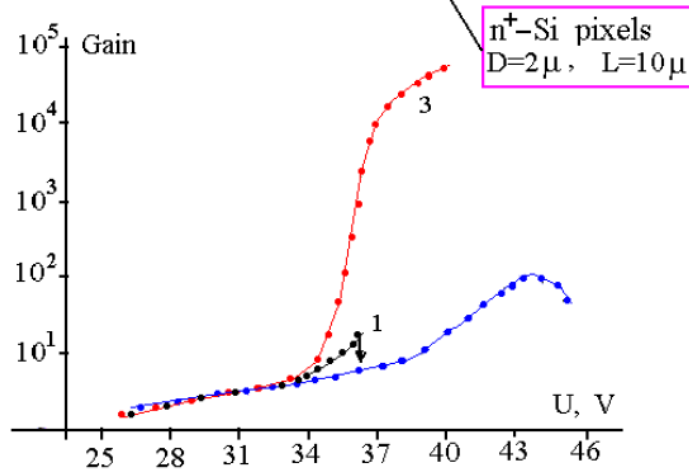
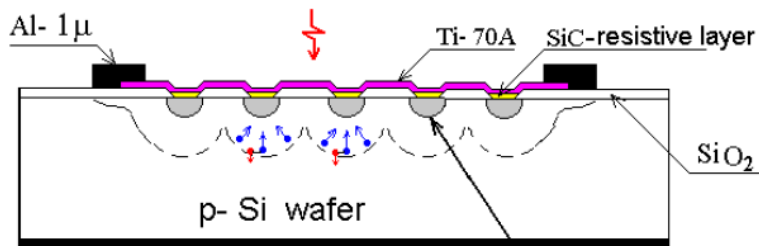
- New developments in SiPMs:
  - high PDE
  - low noise
  - low X-talk
  - low after-pulsing
  - fast timing
  - large dynamic range, fast recovery time
  - radiation hard
- New developments in HAPDs
- Exotics
- SSPMs prospects

# SiPMs

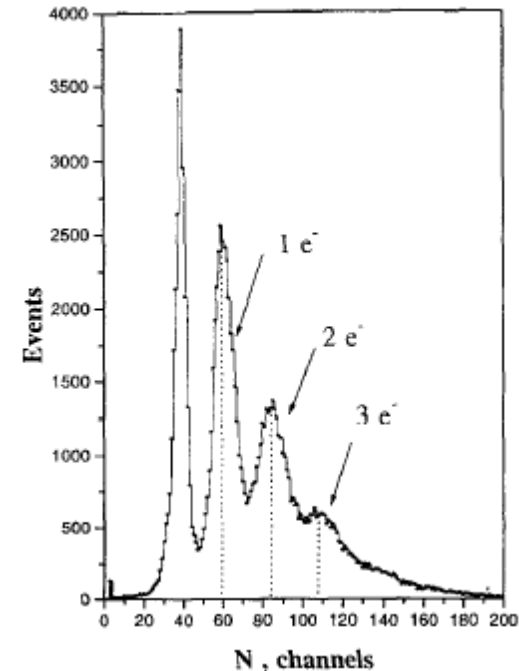
# First design (MRS APD, 1989)

The very first metall-resistor-semiconductor APD (MRS APD) proposed in 1989 by A. Gasanov, V. Golovin, Z. Sadygov, N. Yusipov (Russian patent #1702831, from 10/11/1989). APDs up to  $5 \times 5 \text{ mm}^2$  were produced by MELZ factory (Moscow).

Geometric factor was low. Only few % photon detection efficiency for red light was measured with  $0.5 \times 0.5 \text{ mm}^2$  APD. MRS APD had very good pixel-to-pixel uniformity.



1- Si p-n-junction; 2- Si-SiC-planar structure  
3- Si-SiC-micro-pixel (micro-channel)



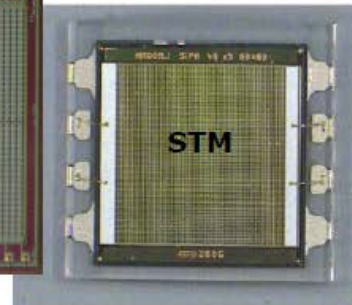
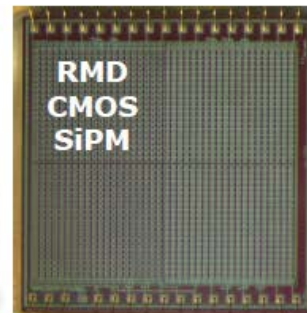
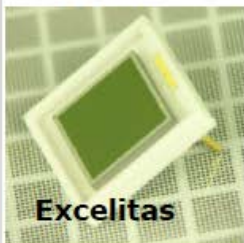
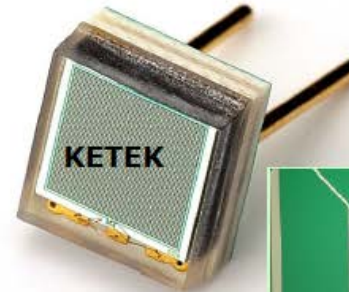
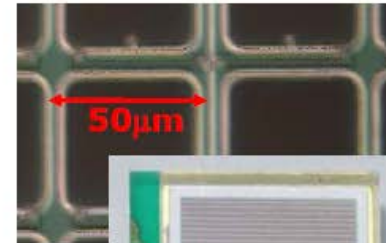
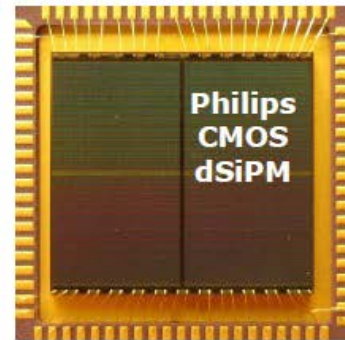
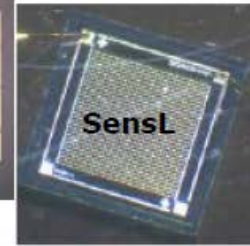
LED pulse spectrum  
(A. Akindinov et al., NIM387 (1997) 231)

# Developers and producers

## Today

Many institutes/companies are involved in SiPM development/production:

- **CPTA**, Moscow, Russia
- **MePhi/Pulsar Enterprise**, Moscow, Russia
- **Zecotek**, Vancouver, Canada
- **Hamamatsu HPK**, Hamamatsu, Japan
- **FBK-AdvanSiD**, Trento, Italy
- **ST Microelectronics**, Catania, Italy
- **Amplification Technologies** Orlando, USA
- **SensL**, Cork, Ireland
- **MPI-HLL**, Munich, Germany
- **RMD**, Boston, USA
- **Philips**, Aachen, Germany
- **Excelitas tech.** (formerly Perkin-Elmer)
- **KETEK**, Munich, Germany
- **National Nano Fab Center**, Korea
- **Novel Device Laboratory (NDL)**, Beijing, China
- **E2V**
- **CSEM**

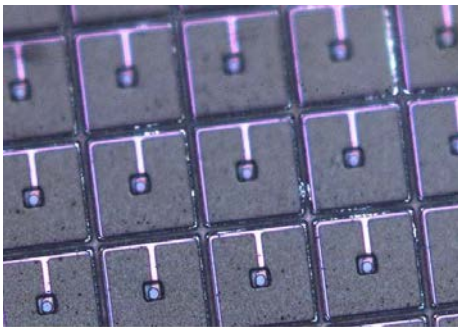
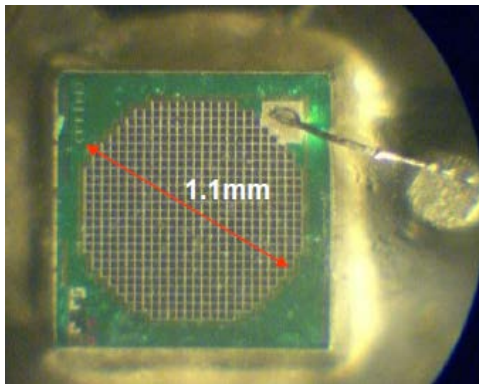


# Photon Detection Efficiency

Photon detection efficiency (PDE) is the probability to detect single photon when threshold is  $<1$  pixel charge. It depends on the pixel active area quantum efficiency (QE), geometric factor ( $G_f$ ) and probability of primary photoelectron to trigger the pixel breakdown  $P_b$  (depends on the  $V-V_b$ ,  $V_b$  – is a breakdown voltage)

$$\text{PDE}(\lambda, U, T) = \text{QE}(\lambda, T) * G_f * P_b(\lambda, U, T)$$

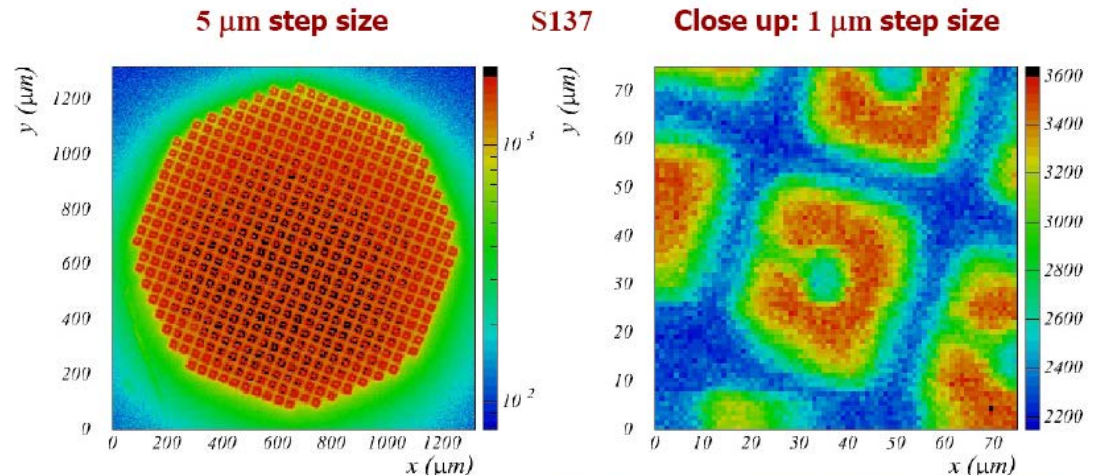
## CPTA SSPM



## SSPM 2d scan with focused laser beam

### Surface sensitivity for single photons

- 2d scan in the focal plane of the laser beam ( $\sigma \approx 5 \mu\text{m}$ )
- intensity: on average  $\ll 1$  photon
- Selection: single pixel pulse height, in TDC 10 ns window



September 26, 2007

Light07, Ringberg castle

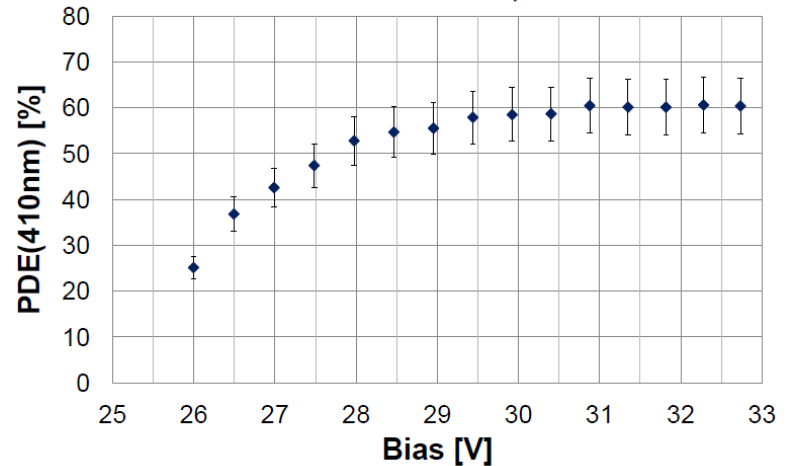
Peter Križan, Ljubljana

Non-sensitive zones between cells reduce PDE

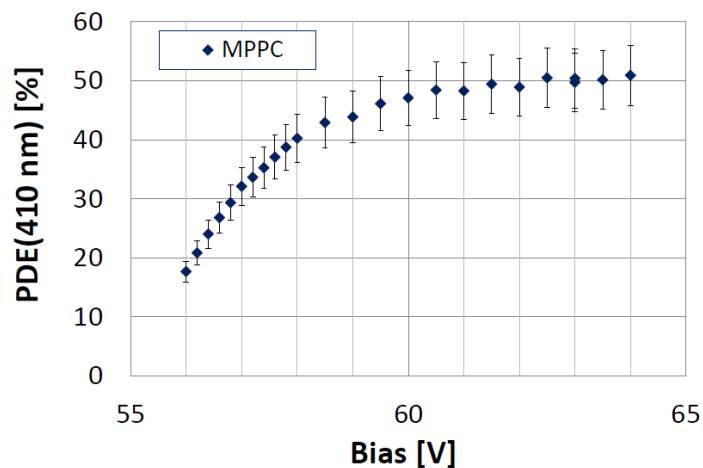
# New High PDE SiPMs

Recently KETEK and Hamamatsu developed 50  $\mu\text{m}$  cell pitch SiPMs with high  $G_f > 80\%$  and  $\text{PDE} = 50\text{-}65\%$  for blue/UV light !!

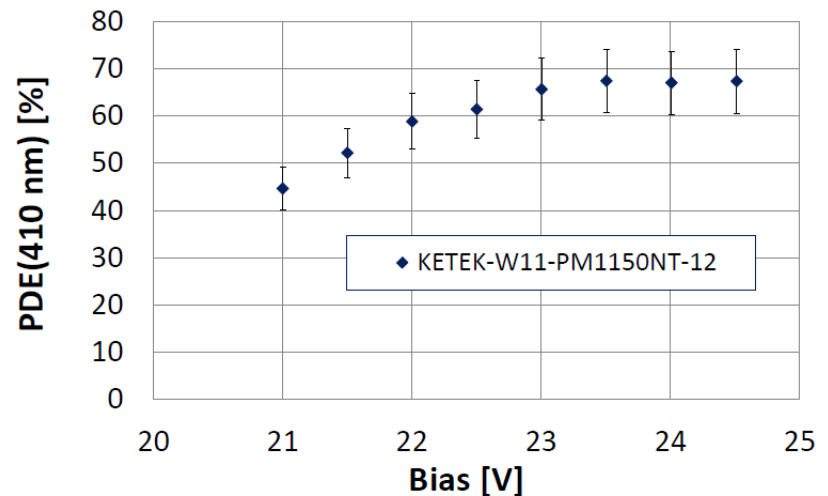
KETEK-50D-adv SiPM, T=23 C



New MPPC, 50  $\mu\text{m}$  cell pitch, T=23 C

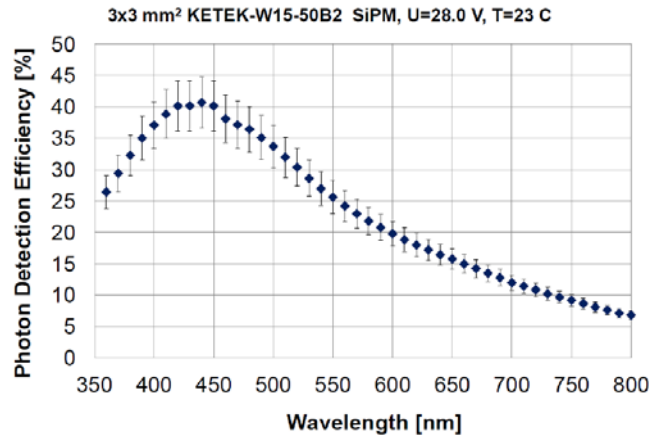


T=22 C

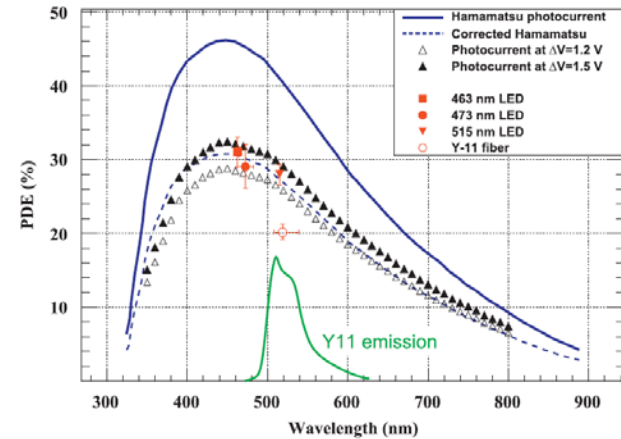


# SiPM spectral response

KETEK 2011 SiPM (50  $\mu\text{m}$  cell pitch)

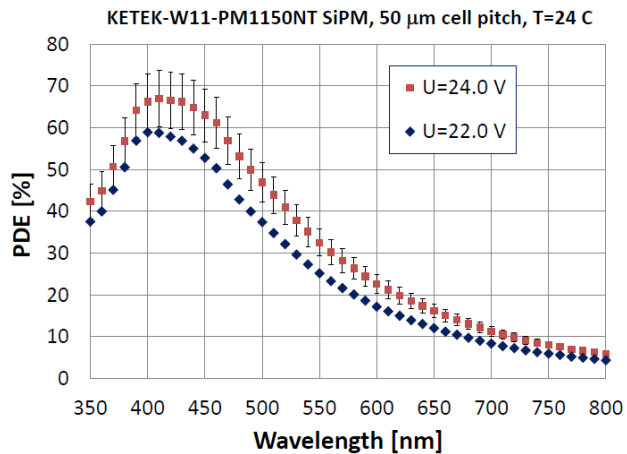


Hamamatsu-2010 MPPC (50  $\mu\text{m}$  cell pitch)

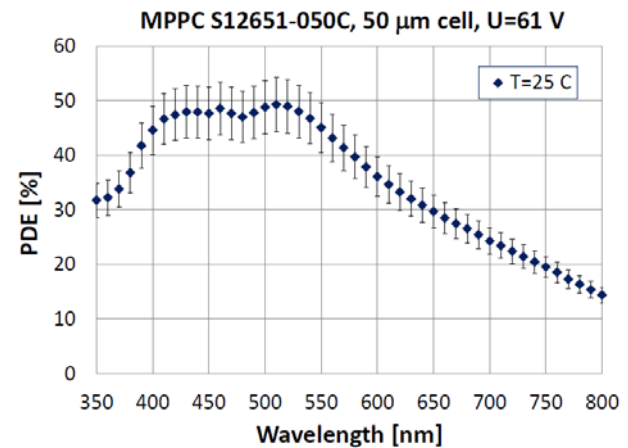


A. Vacheret et al. / Nuclear Instruments and Methods in Physics Research A 656 (2011) 69–83

KETEK 2013 SiPM (50  $\mu\text{m}$  cell pitch)



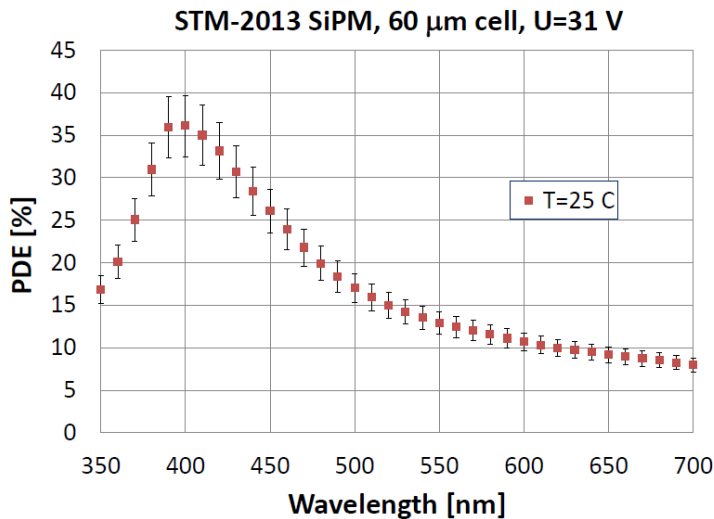
Hamamatsu-2013 MPPC (50  $\mu\text{m}$  cell pitch)



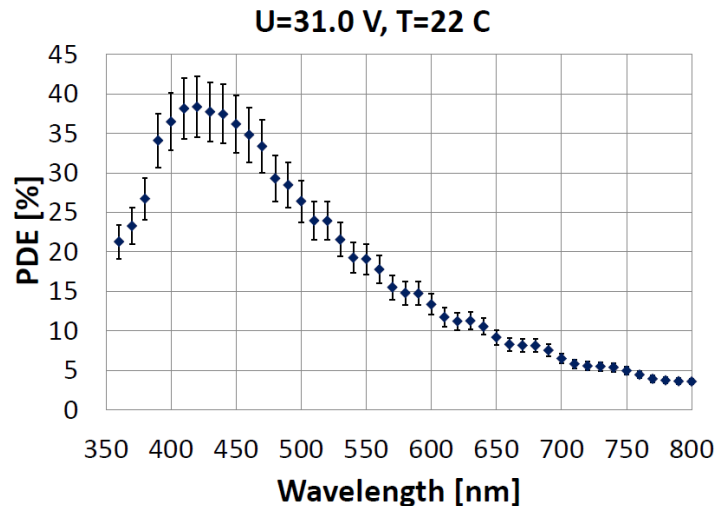


# Blue/UV light sensitive SiPMs (P on N)

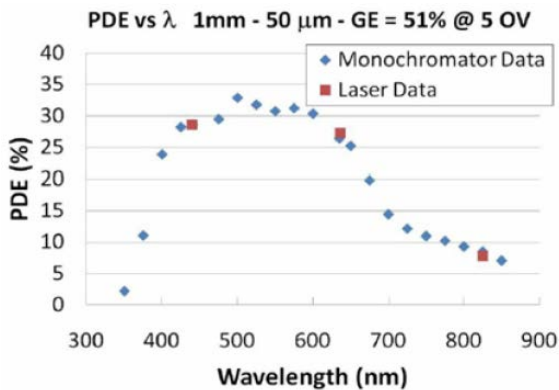
ST Misro-2013 SiPM (60  $\mu\text{m}$  cell pitch)



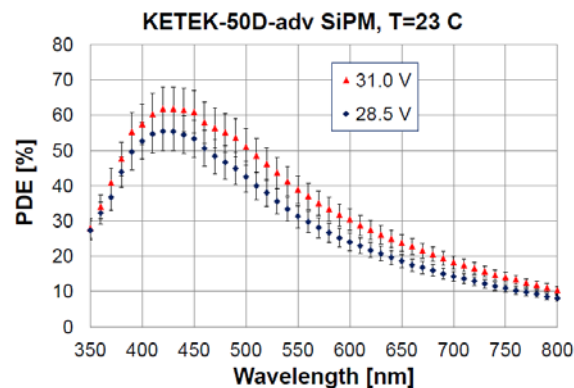
SensL Micro-FB-10035-X18 SiPM (45  $\mu\text{m}$  cell pitch)



Excelitas SiPM (50  $\mu\text{m}$  cell pitch) – NDIP-11



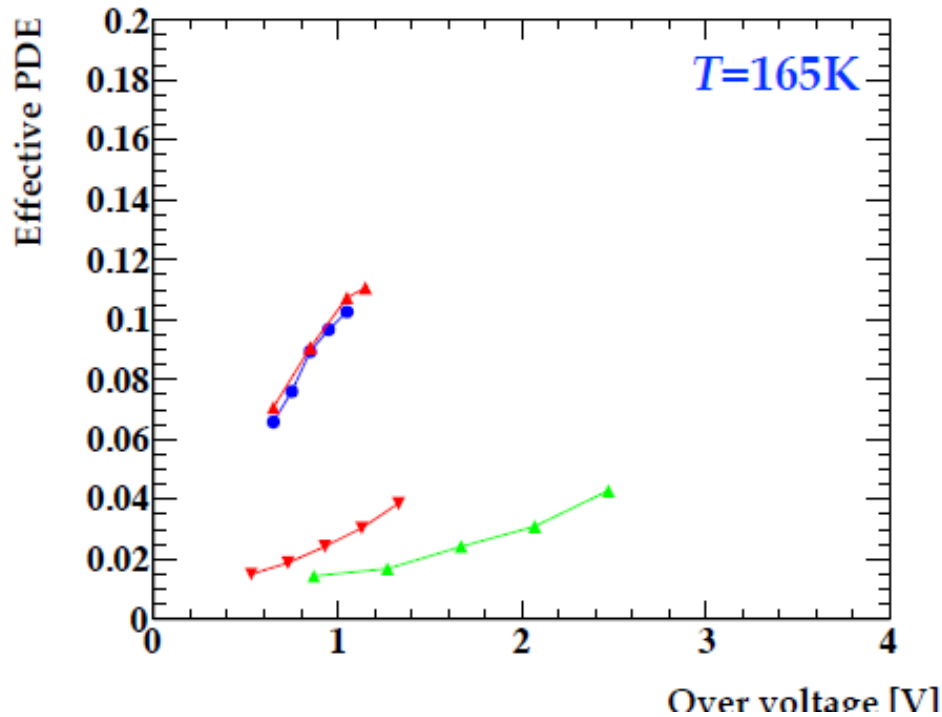
KETEK 2012 SiPM



Ubreakdown 90-140V

# UV-enhanced SiPMs (for MEG LXe Sci. Detector)

UV-enhanced MPPC is under development by Hamamatsu in collaboration with KEK



- \* Remove protection coating
- \* Optimize MPPC parameters
  - \* Thinner p<sup>+</sup> contact layer
  - \* Anti-reflection coating
  - \* Refractive index of surface material
  - \* Quench resistor
  - \* Pixel size

PDE~10 % achieved for 175 nm light (best samples)

# SiPM Noise Sources

Noise sources:

Dark counts

pulses triggered by non-photo-generated carriers (**thermal / tunneling generation** in the bulk or in the surface depleted region around the junction)

After-pulsing

**carriers can be trapped** during an avalanche and then released triggering another avalanche

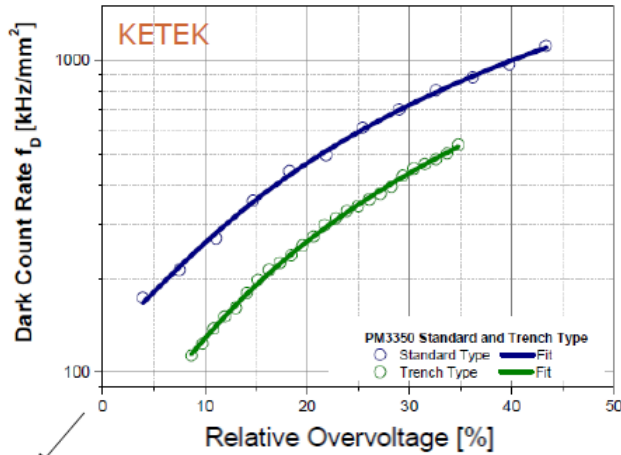
Cross-Talk

"optical"

**photo-generation during the avalanche discharge.** Some of the photons can be absorbed in the adjacent cell possibly triggering new discharges

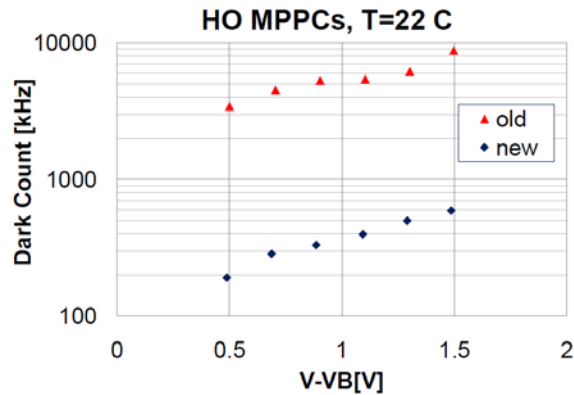
# Dark Count Rate

KETEK PM 3350 (p<sup>+</sup>-on-n, shallow junction)  
3x3mm<sup>2</sup> active area pixel size 50x50 μm<sup>2</sup>

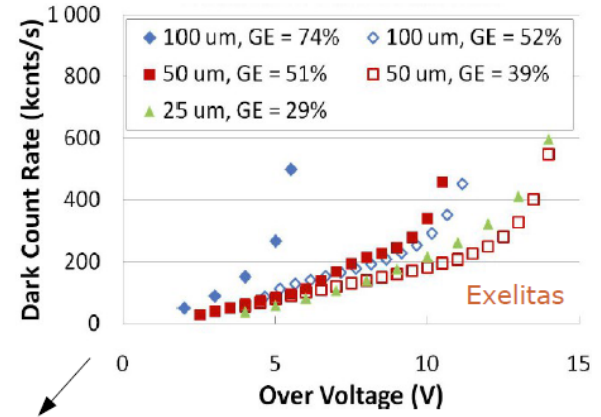


$V_{bd} \sim 25V$

*F. Wiest – AIDA 2012 at DESY*

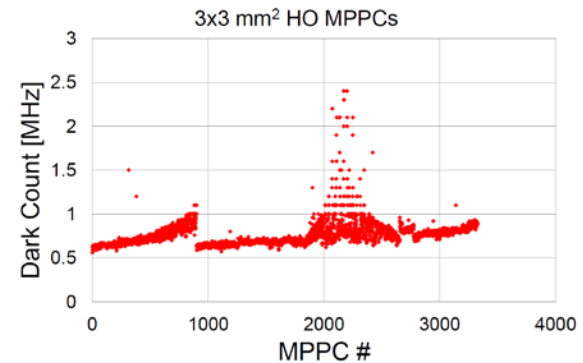


Exelitas 1<sup>st</sup> generation SiPM 2011  
(p<sup>+</sup>-on-n) 1x1mm<sup>2</sup>



$V_{bd} \sim 140V$

*P. Berard – NDIP 2011*



Latest MPPCs reached DCR < 100 kHz/mm<sup>2</sup> at RT and dVB = 1.1 V (PDE(450nm) ~ 30%)

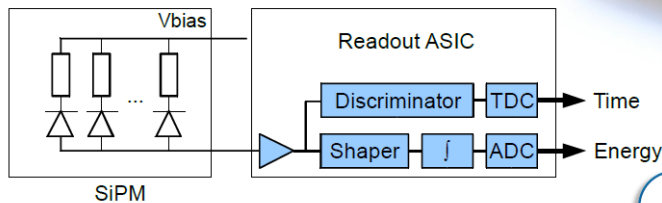
# Low Dark Count Rate dSiPM (Philips)

dSiPM - array of SPADs integrated in a standard CMOS process. Photons are detected and counted as digital signals using a dedicated cell electronics block next to each diode. This block also contains active quenching and recharge circuits, one bit memory for the selective inhibit of detector cells. A trigger network is used to propagate the trigger signal from all cells to the TDC.

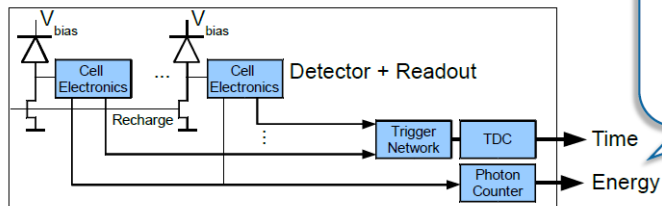
## Digital SiPM – Test Chip Architecture

### Digital SiPMs

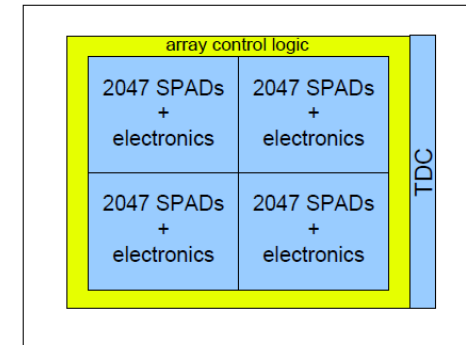
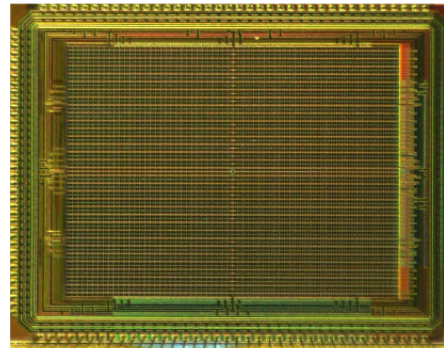
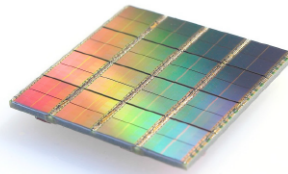
#### Analog Silicon Photomultiplier



#### Digital Silicon Photomultiplier



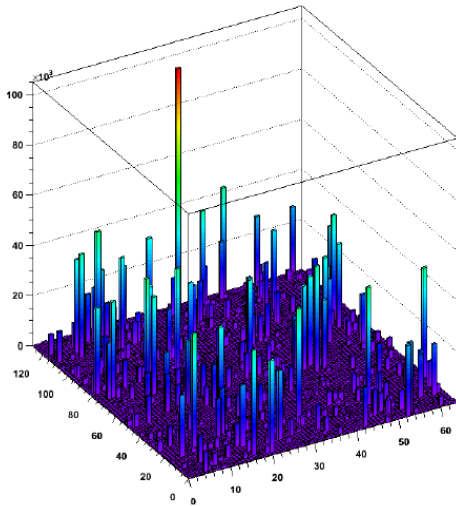
dSiPM provides a digital timestamp and the photon count for each light pulse, without the need of any analog front-end electronics



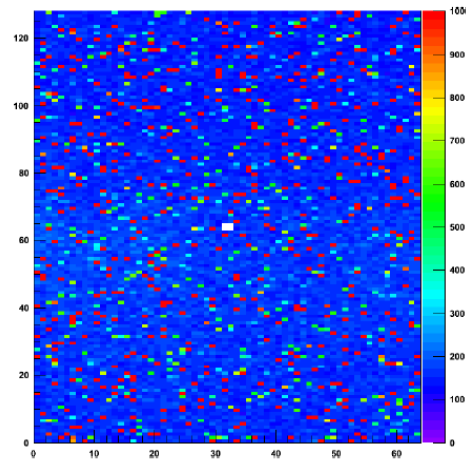
- Pixel composed of 4 identical sub-pixels with 2047 microcells each
- Microcell size  $30\mu\text{m} \times 52\mu\text{m}$ , 50% fill factor including electronics
- A 1 bit inhibit memory in each microcell to enable/disable faulty diodes
- Active quench & recharge, on-chip memory and array controllers
- Integrated time-to-digital converter with  $\sigma = 8\text{ps}$  time resolution
- Variable trigger (1-4 photons) and energy (1-64 photons) thresholds
- Acquisition controller implemented in FPGA for flexibility and testing

(T. Frach, IEEE-NSS/MIC, Orlando, Oct. 2009)

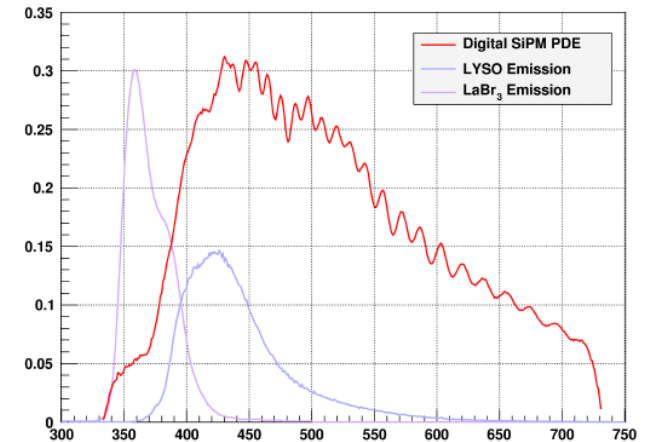
# dSiPM – dark count rate, PDE



Dark Count Rate Map



Photon Detection Efficiency



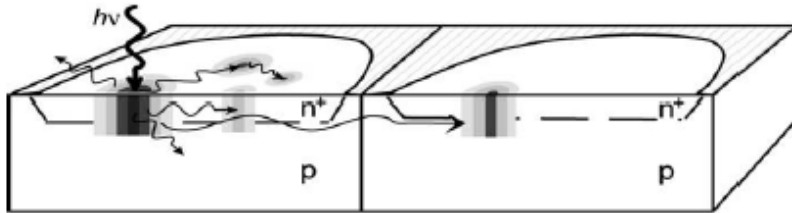
Only 5 to 10% of the diodes show abnormally high dark count rates due to defects. These diodes can be switched off. The average dark count rate of a good diode at 20 °C is approximately 150 cps (or  $\sim 100$  kHz/mm<sup>2</sup>).

Digital signal – only PDE varies with the temperature  $\rightarrow$  low temperature sensitivity  $\sim 0.33\%/C$

(T. Frach, IEEE-NSS/MIC, Orlando, Oct. 2009)

# Optical cross-talk

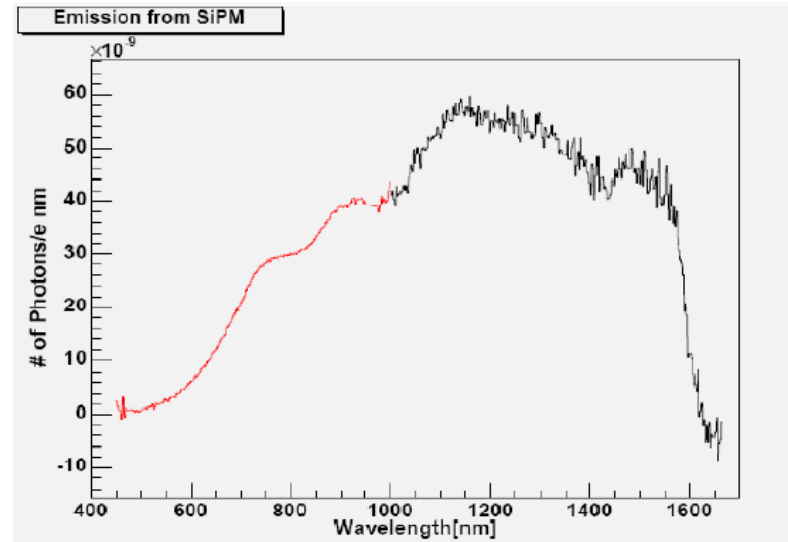
SiPM is not an ideal multiplier!



A. Lacaita et al, IEEE TED (1993)

Light is produced during cell discharge. Effect is known as a hot-carrier luminescence:  $10^5$  carriers produce  $\sim 3$  photons with an wavelength less than  $1 \mu\text{m}$

Light emission spectrum from SiPM

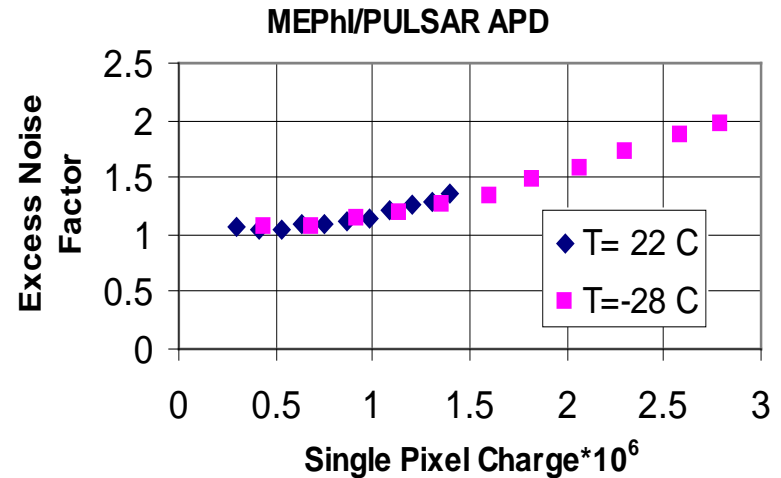
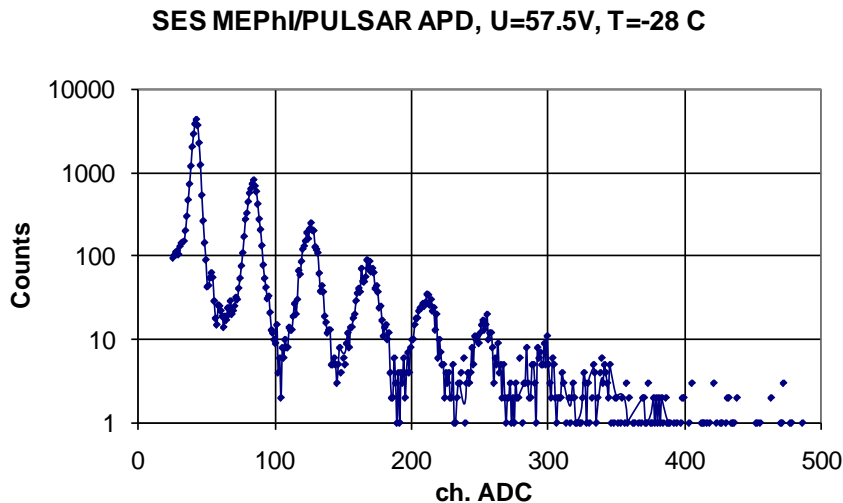


(R. Mirzoyan, NDIP08, Aix-les-Bains)

Light emitted in one cell can be absorbed by another cell. Optical cross-talk between cells causes adjacent pixels to be fired  $\rightarrow$  increases gain fluctuations  $\rightarrow$  increases noise and excess noise factor !

# Single electron spectrum and ENF

When  $V - V_b \gg 1$  V typical single pixel signal resolution is better than 10% (FWHM). However an optical cross-talk results in more than one pixel fired by a single photoelectron. Single electron spectrum can be significantly deteriorated and the excess noise factor can be  $\gg 1$

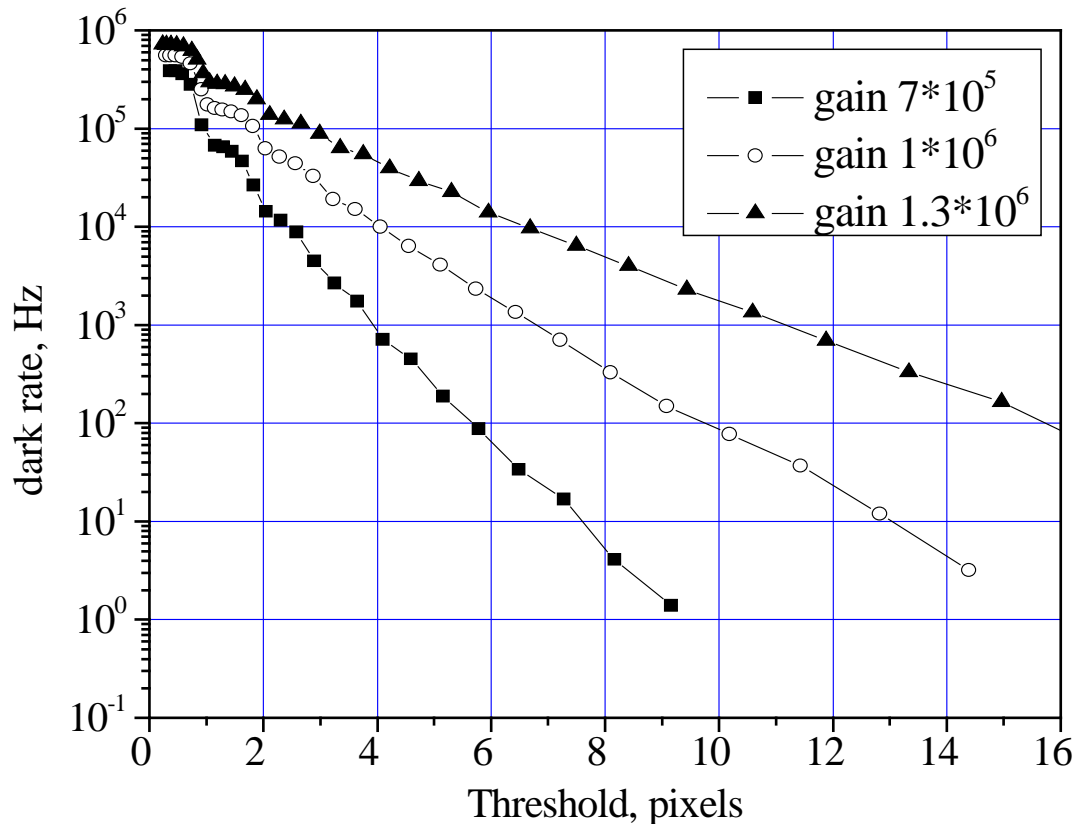


(Y. Musienko, NDIP-05, Beaune)

$$F = 1 + \frac{\sigma_M^2}{M^2}$$



# Dark count rate vs. electronics threshold



Optical cross-talk also increases the dark count at high electronics thresholds

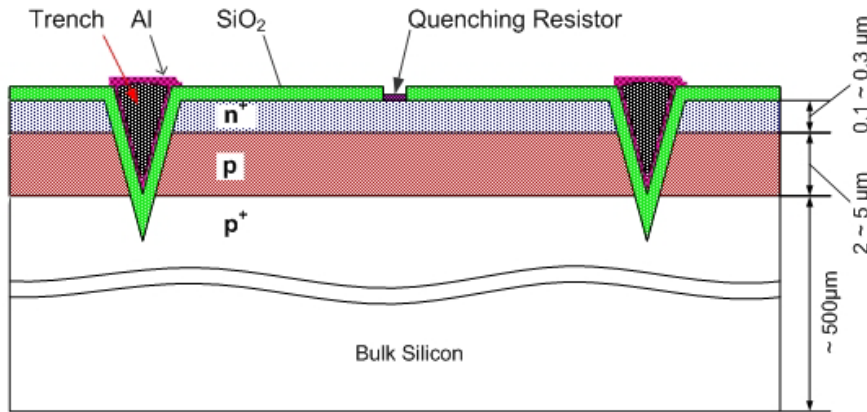
(E.Popova, CALICE meeting)

This effect is more pronounced at high SiPM gain!

# Optical cross-talk reduction

Solution: optically separate cells trenches filled with optically non-transparent material

CPTA structure



STM structure

**Schematic cross section**

ARC N<sup>+</sup> Poly Poly-silicon Quenching Resistor

P Enrichment P Epitaxy P<sup>+</sup> Substrate N<sup>+</sup> Cathode P<sup>+</sup> Anode Optical Trench

**SEM cross sections**

Active Area Poly-silicon Quenching Resistor ARC

Optical Trench N<sup>+</sup> Poly

1 μm

- Shallow junction
- In-situ doped poly-silicon cathode layer
- Integrated poly-silicon resistors
- Thin optical trench with metal filling
- Tunable Anti-reflection coating
- Dedicated gettering techniques
- Double layer passivation

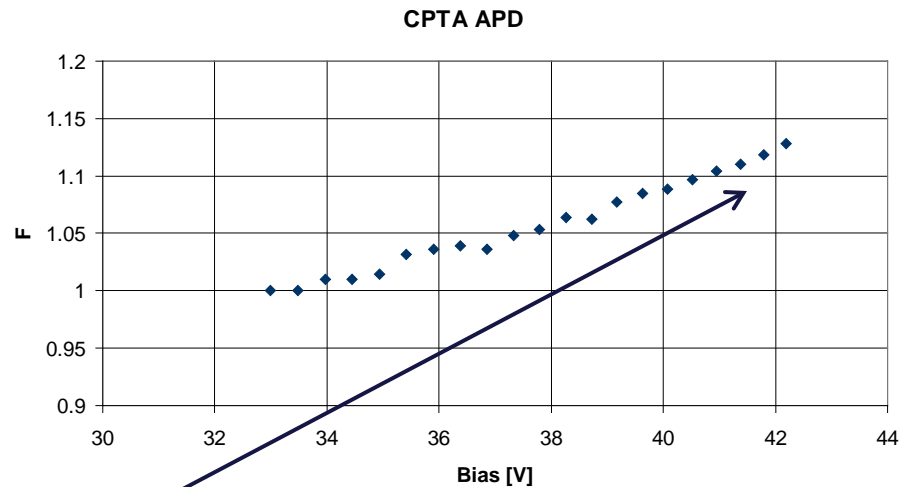
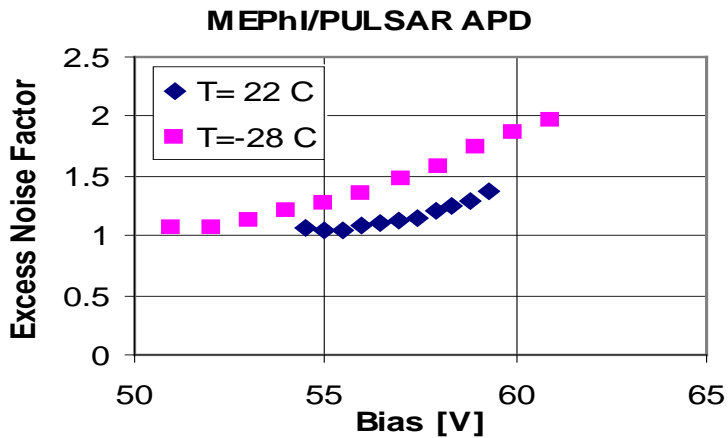
(D. McNally, G-APD workshop, GSI, Feb. 2009)

# SiPMs with reduced optical cross-talk

*Trenches really help ...*

*MEPhI/Pulsar SiPM without trenches*

*CPTA/Photonique SSPM with trenches*

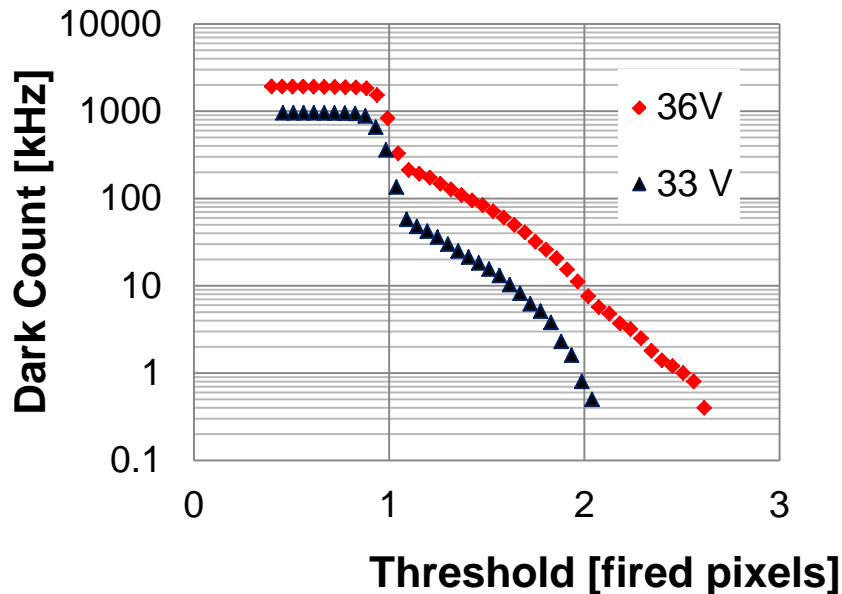


*The excess noise factor is small even at  $V-V_B \sim 10$  V!*

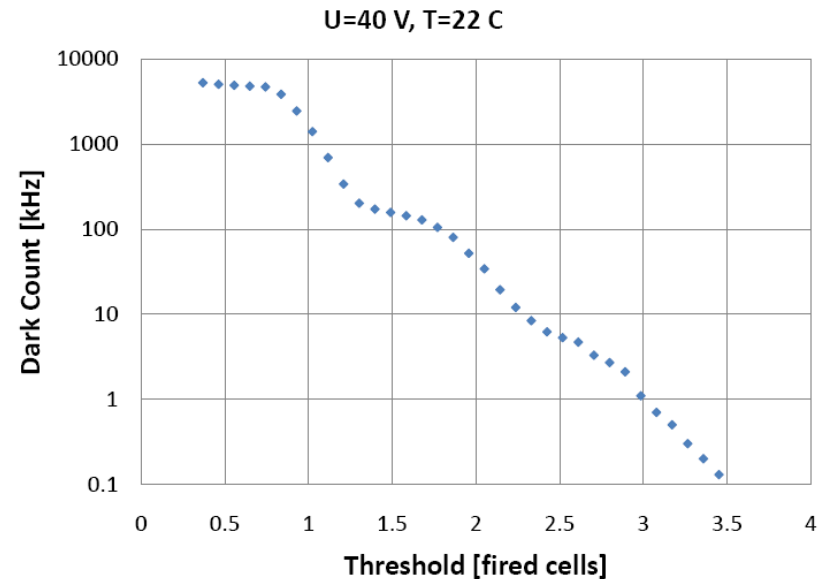
# Dark count rate of the SiPMs with trenches vs. electronics threshold

... and dark count at a few photoelectrons threshold level is significantly reduced

CPTA/Photonique SSPM with trenches



ST-Micro SiPM with trenches



SiPMs with trenches can have an optical cross-talk <2%

# Very low X-talk SiPMs (MEPhI)

SiPM:  $1 \times 1 \text{ mm}^2$ ,  $100 \times 100 \mu\text{m}^2$ , Geometrical Efficiency  $\sim 80\%$ ,  $T = +25^\circ\text{C}$ ,  $\lambda = 435 \text{ nm}$   
Same light impinging on both sensors

## 3+ -fold X-talk suppression

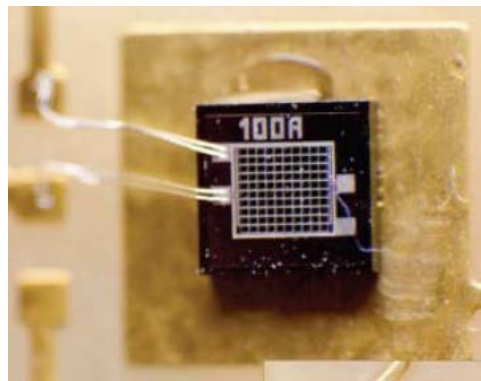
A known way to suppress X-talk:

1. Isolating trenches

New ways:

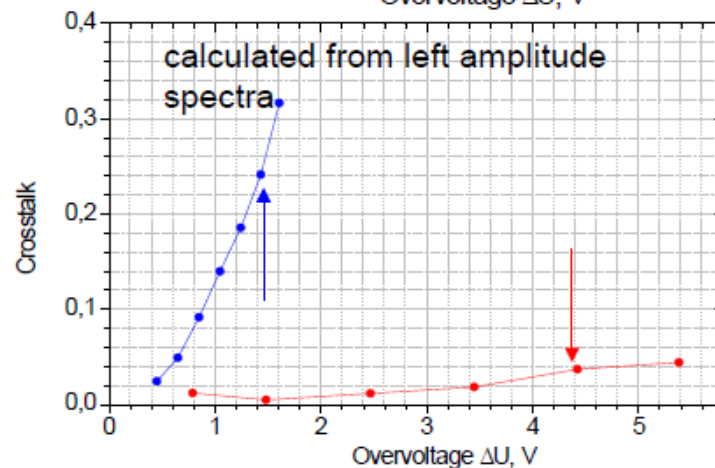
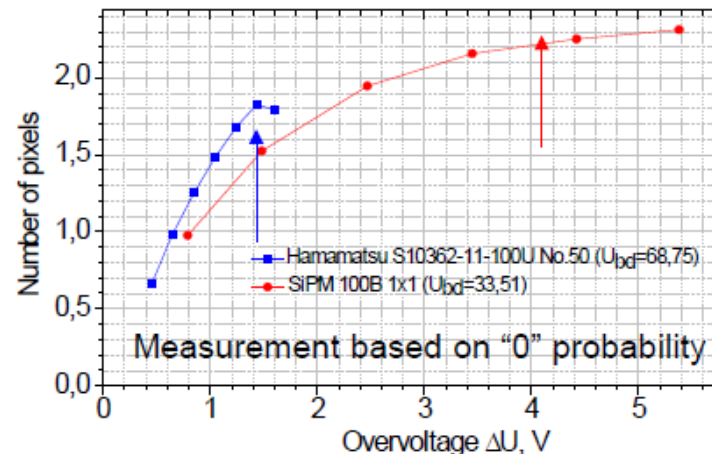
2. 2<sup>nd</sup> p-n junction for isolating the bulk from the active region (patented)

3. OC suppression by ion implantation (patent pending)



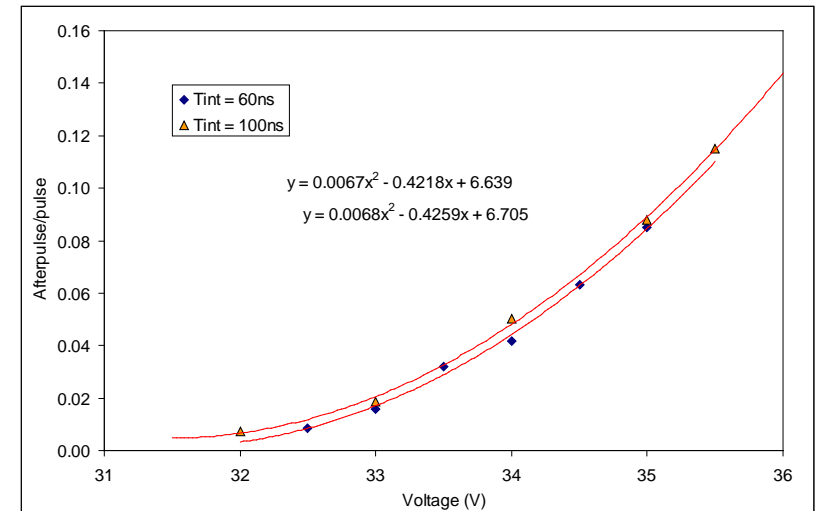
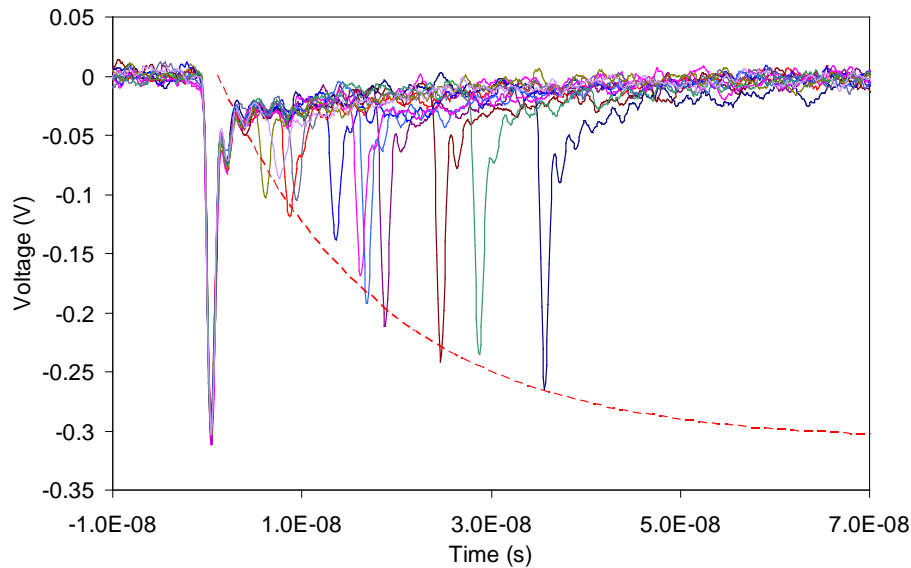
E. Popova: Large area SiPM with very high PDE and very low X-talk

4th July 2011, NDIP-11, Lyon, France



# After-pulsing

Another problem: carriers trapped during the avalanche discharge and then released trigger a new avalanche during a period of several 100 ns after the breakdown



*Events with after-pulse measured on a single micropixel.*

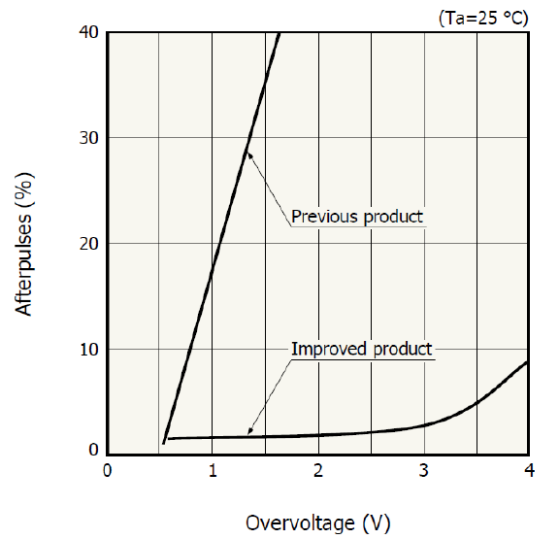
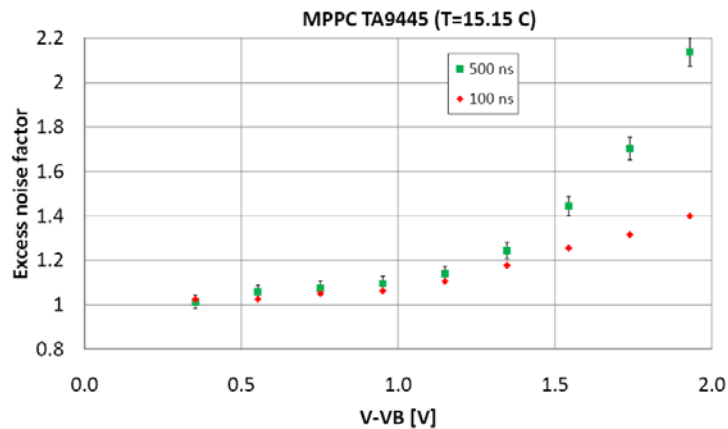
*After-pulse probability increases with the bias*

(C. Piemonte: June 13<sup>th</sup>, 2007, Perugia)

Solutions: “cleaner” technology, longer pixel recovery time and smaller gain

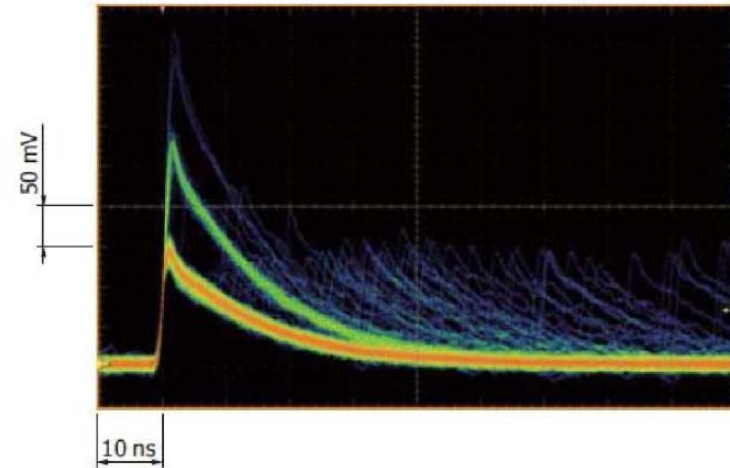
# After-pulses in MPPCs (old and new)

**After-pulses cause an increase of the SiPM dark count rate. They also increase the excess noise factor if the signal integration time is long**



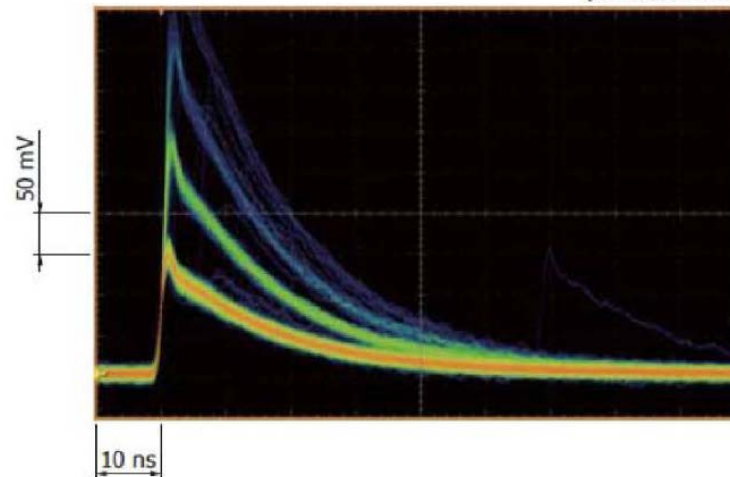
(a) S10362-11-050C (previous product)

(M=1.25 × 10<sup>6</sup>)



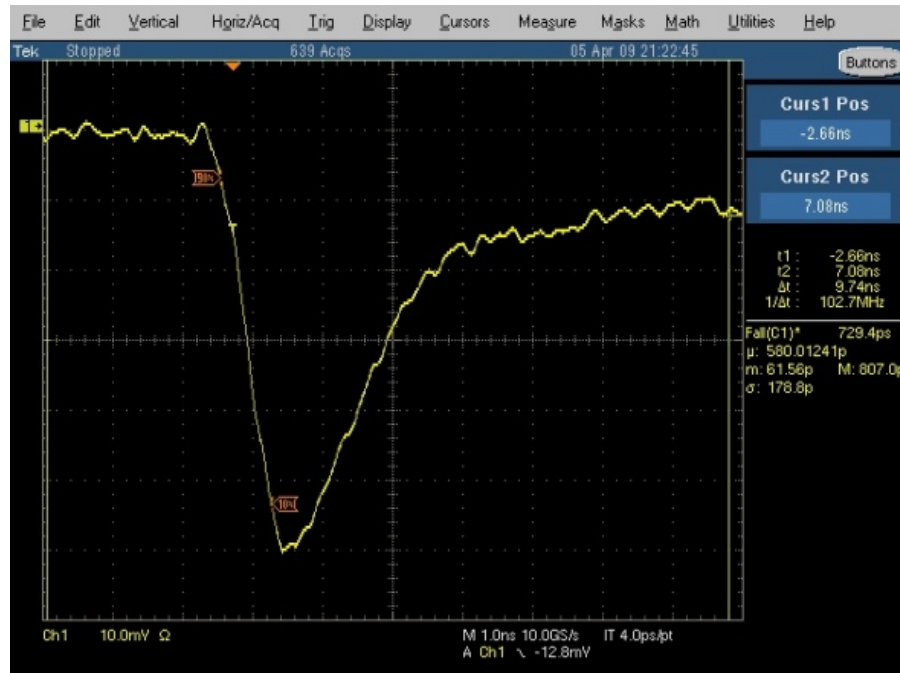
(b) S12571-050C (improved product)

(M=1.25 × 10<sup>6</sup>)

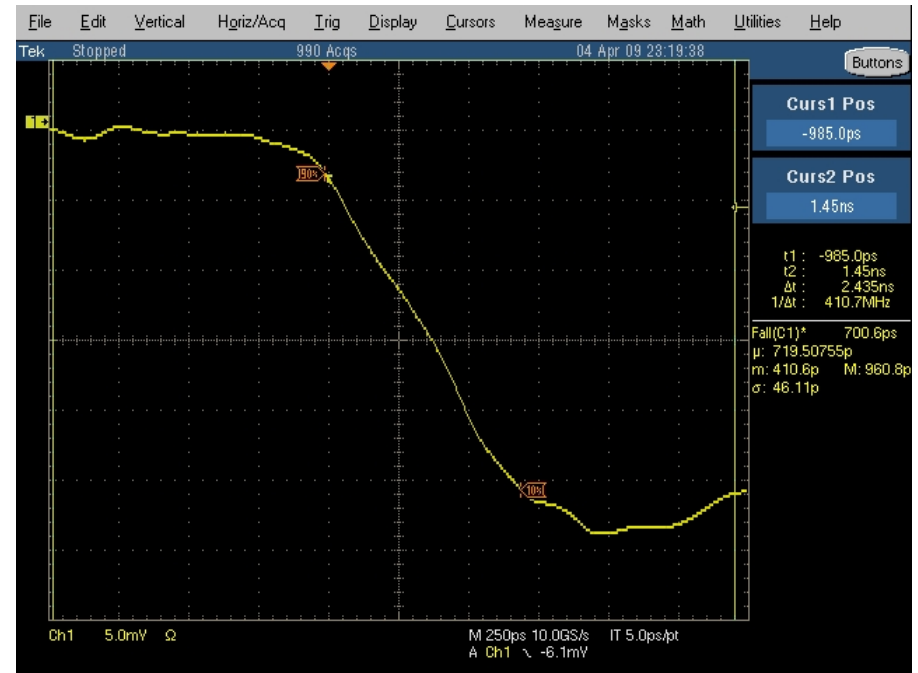


# Signal rise time

CPTA/Photonique 1 mm<sup>2</sup> SSPM response to a 35 psec FWHM laser pulse ( $\lambda=635$  nm)



Zecotek 3x3 mm<sup>2</sup> MAPD response to a 35 psec FWHM laser pulse ( $\lambda=635$  nm)

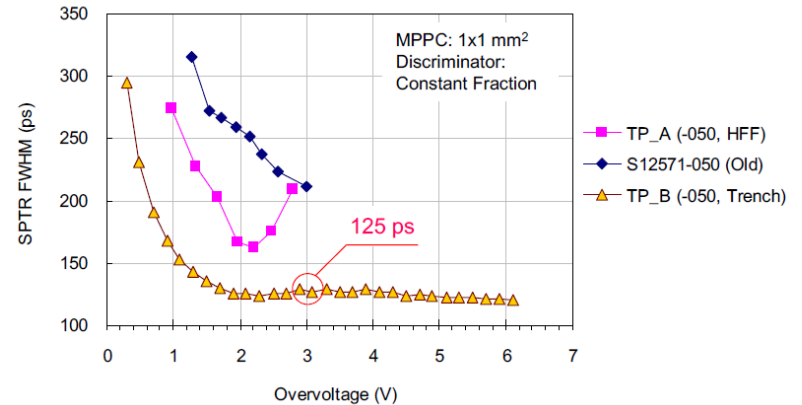
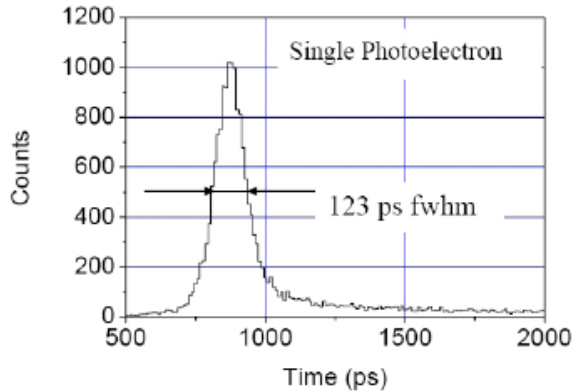


~700 psec rise time was measured (limited by circuitry)

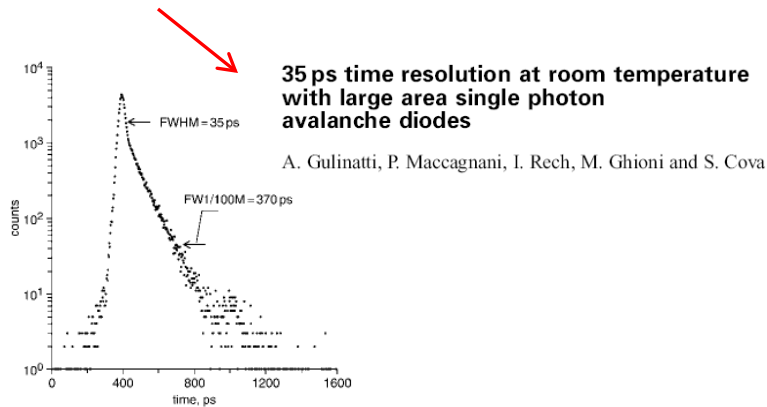


# Single photon time resolution

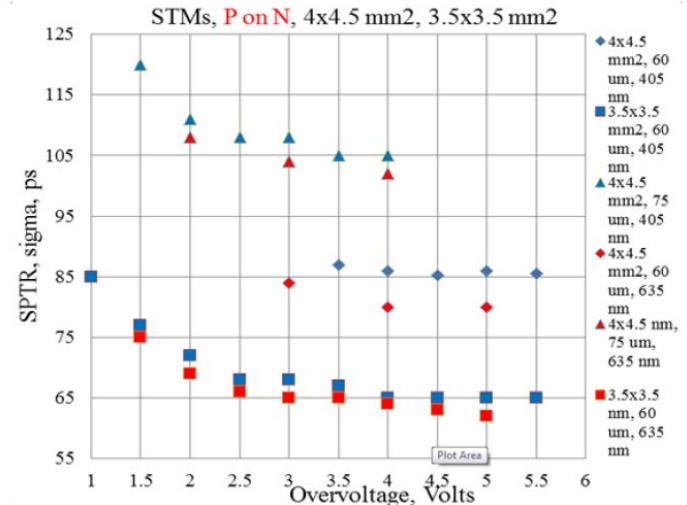
SiPMs have excellent timing properties



123 psec FWHM time resolution was measured with MEPhI/Pulsar SiPM using single photons (B. Dolgoshein, Beane-02 and T.Nagano et. al, IEEE NSS-MIC 2013 ). And this can be improved ...



35 ps FWHM timing resolution was measured with 100  $\mu$ m SPAD using single photons



(A.Ronzhin et. al, IEEE NSS-MIC 2013) 25

# Linearity and dynamic range

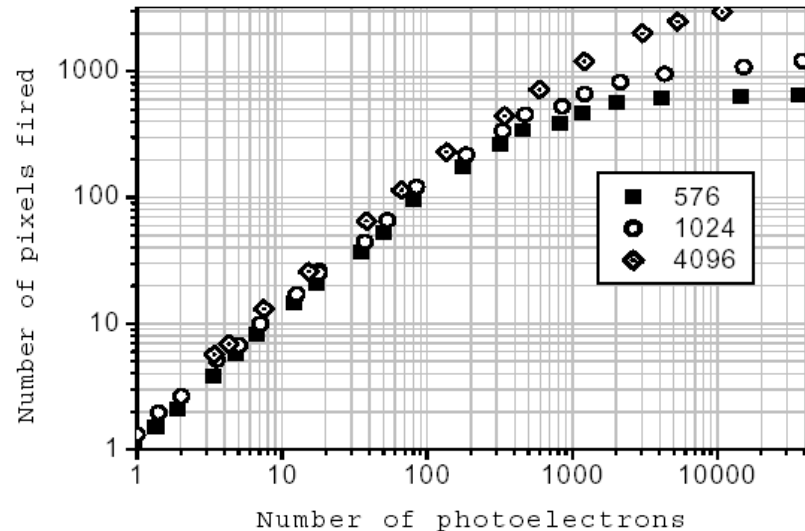
SiPM linearity is determined by its total number of cells

In the case of uniform illumination:

$$N_{\text{fired cells}} = N_{\text{total}} \cdot \left( 1 - e^{-\frac{N_{\text{photon}} \cdot \text{PDE}}{N_{\text{total}}}} \right)$$

This equation is correct for light pulses which are shorter than pixel recovery time, and for an “ideal” SiPM (no cross-talk and no after-pulsing)

Response functions for the SiPMs with different total pixel numbers measured for 40 ps laser pulses



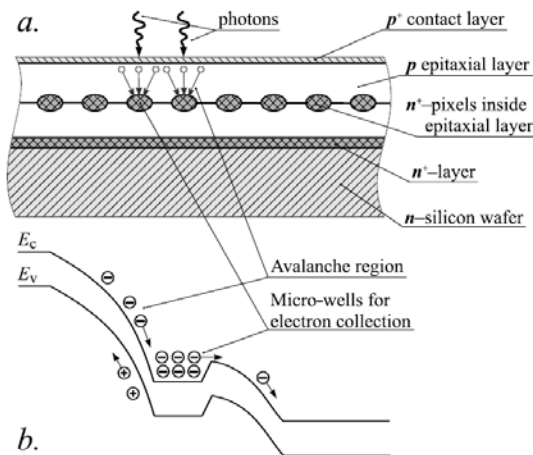
(B. Dolgoshein, TRD05, Bari)

More cells/area needed for large dynamic range

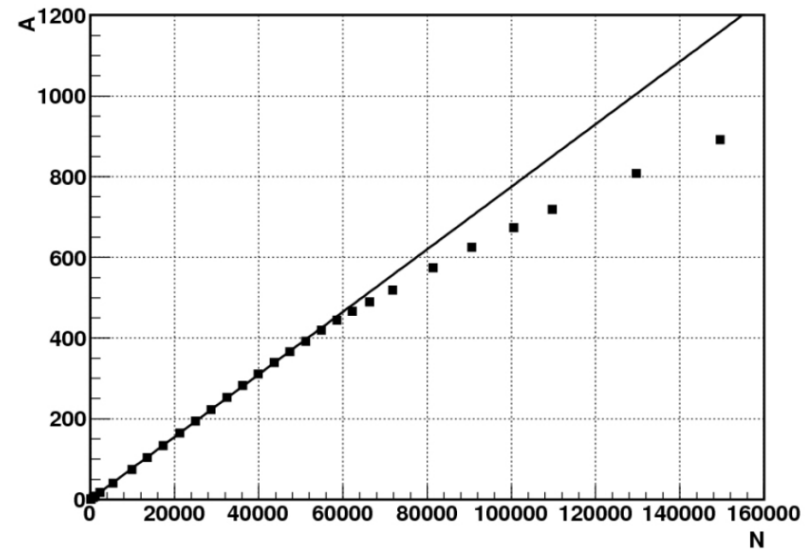
# Large dynamic range Micro-pixel APDs from Zecotek

Micro-well structure with multiplication regions located in front of the wells at 2-3  $\mu\text{m}$  depth was developed by Z. Sadygov. MAPDs with 10 000 – 40 000 cells/ $\text{mm}^2$  and up to  $3 \times 3 \text{ mm}^2$  in area were produced by Zecotek (Singapore).

Schematic structure (a) and zone diagram (b) of Micro-pixel APD (MAPD)



Dependence of the MAPD (135 000 cells,  $3 \times 3 \text{ mm}^2$  area) signal amplitude  $A$  (in relative units) on a number of incident photons  $N$



This structure doesn't contain quenching resistors. Specially designed potential barriers are used to quench the avalanches.

(Z. Sadygov et al, arXiv;1001.3050)

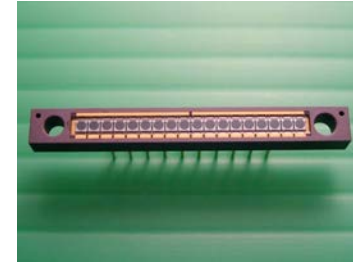
# Micro-pixel APDs for the CMS HCAL Upgrade

MAPD (3N type) with 15 000 cells/mm<sup>2</sup> and 3x3 mm<sup>2</sup> in area produced by Zecotek for the CMS HCAL Upgrade project.

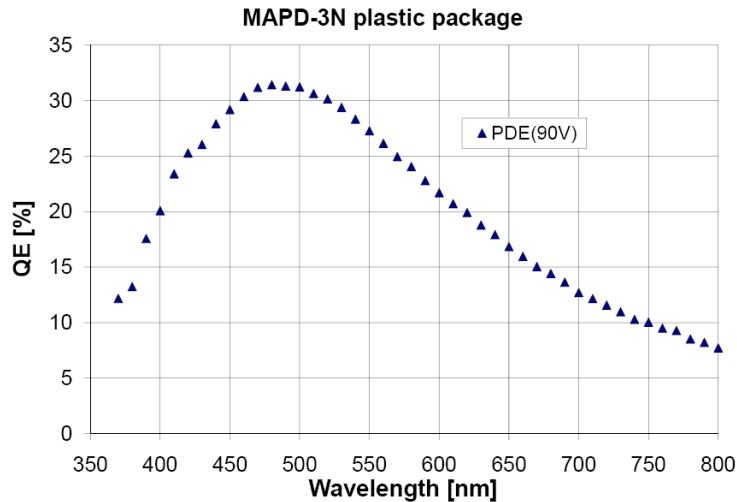


Dark count rate is ~300-500 kHz/mm<sup>2</sup> at T=22 C

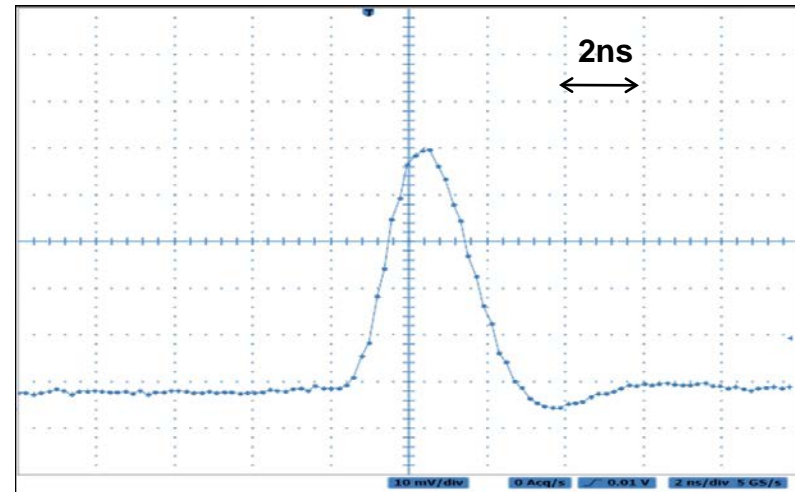
Linear array of MAPDs (18x1 mm<sup>2</sup>, 15 000 cells/mm<sup>2</sup>) produced by Zecotek for the CMS HCAL Upgrade project.



PDE vs. wavelength



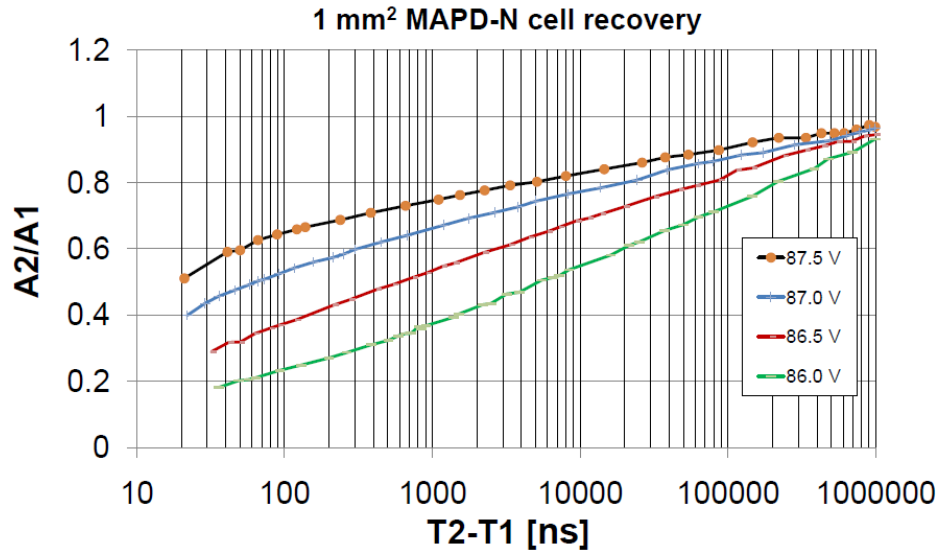
1 mm<sup>2</sup> MAPD response to a 35 psec (FWHM) laser pulse



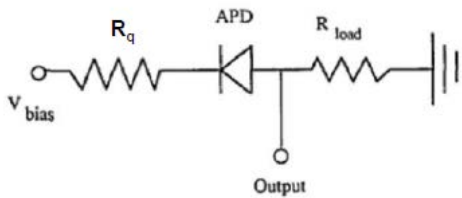
# MAPD cell recovery

MAPD cell recovery is not exponential

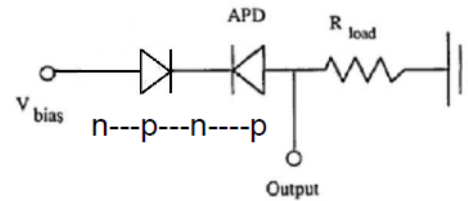
MAPD (3N type) cell recovery (measured using 2 LED technique)



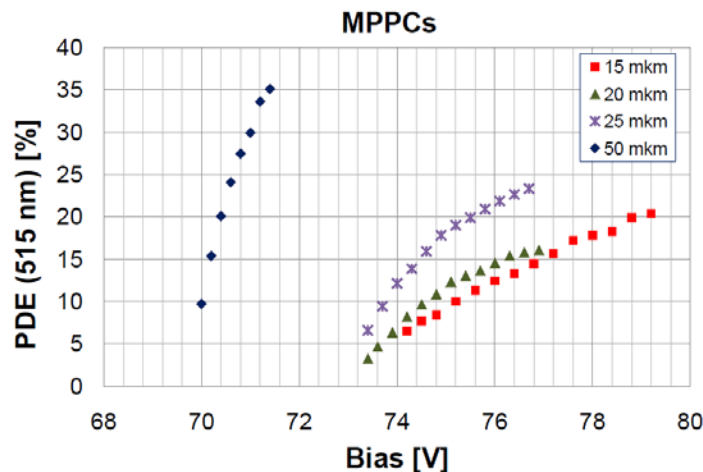
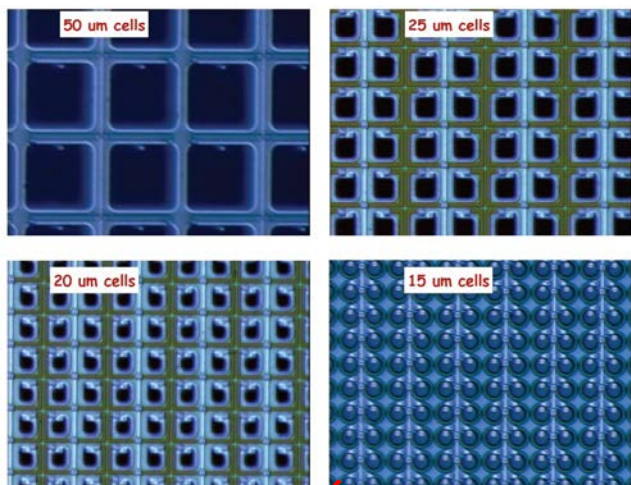
SiPM cell equivalent circuit



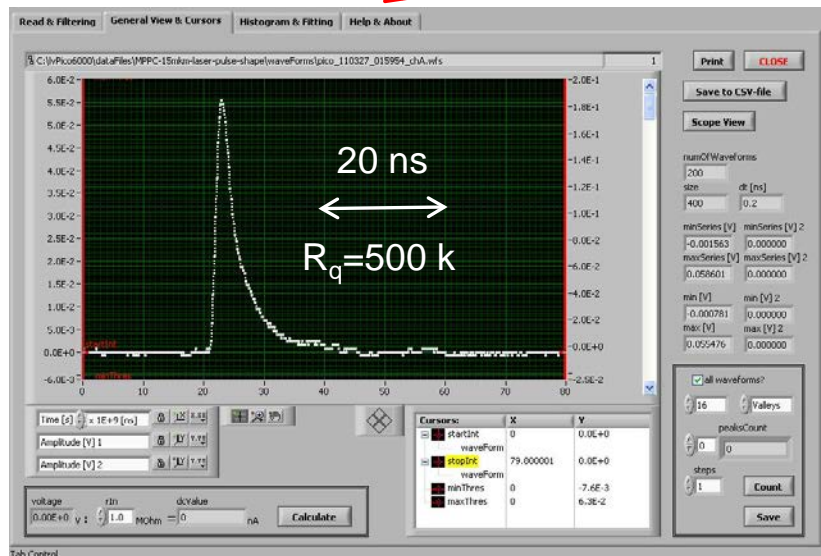
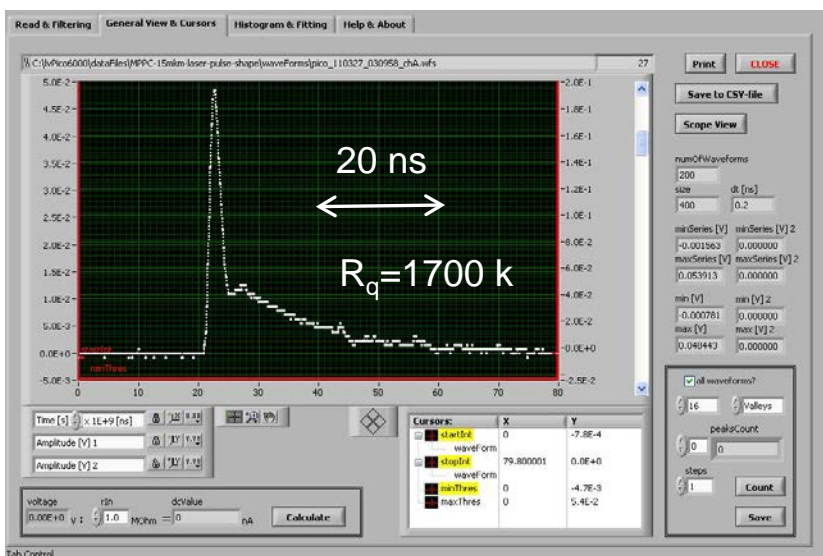
MAPD cell equivalent circuit



# Large dynamic range MPPCs (Hamamatsu)



MPPC (15 μm cell pitch) responds to a fast (35 psec FWHM) laser pulse

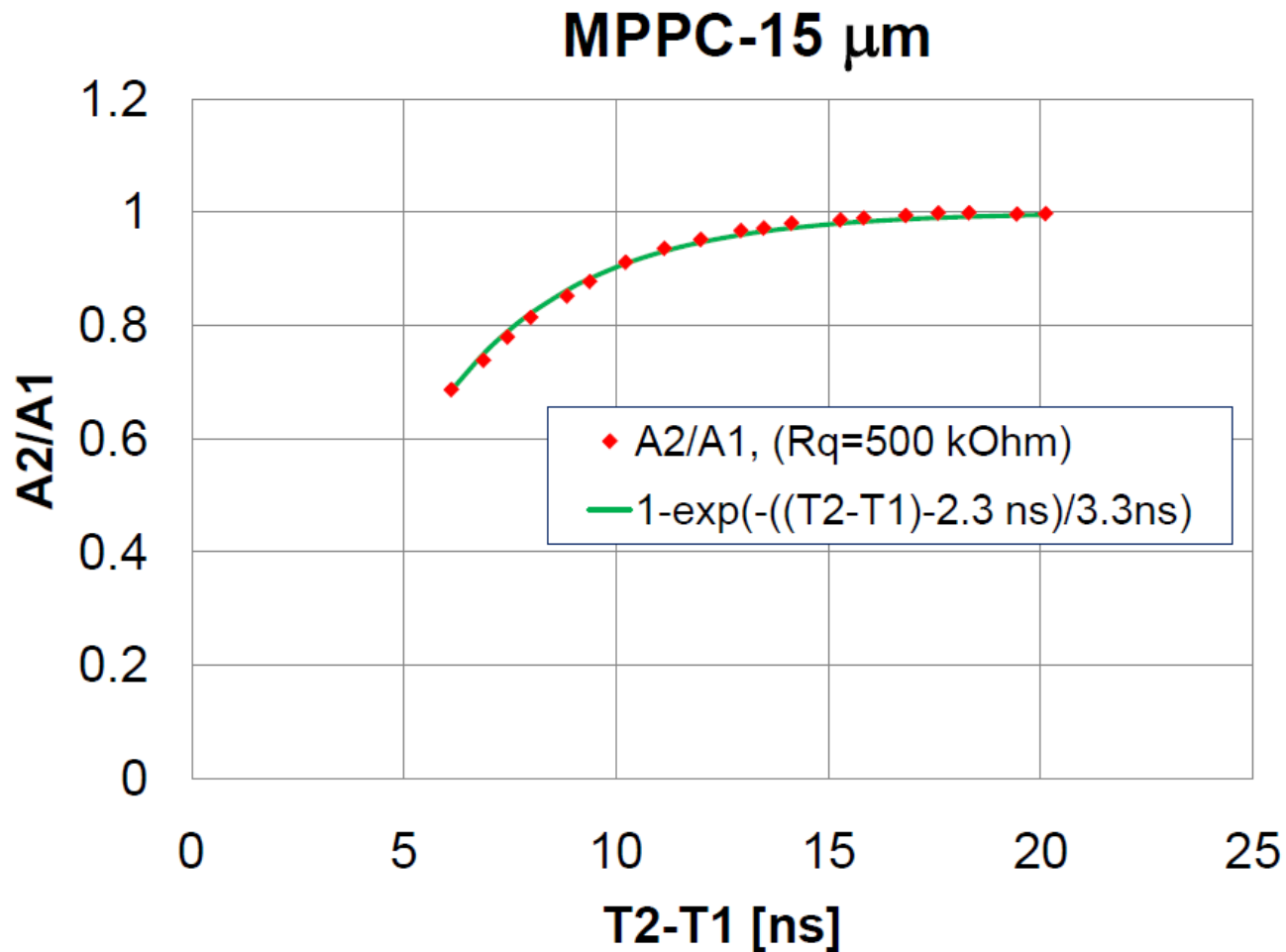


# New MPPC parameters

MPPC type	# cells 1/mm <sup>2</sup>	C, pF	R <sub>cell</sub> , kOhm	C <sub>cell</sub> , fF	$\tau=R_c \times C_c$ , ns	V <sub>B</sub> , V T=23 C	V <sub>op</sub> , V T=23 C	Gain(at V <sub>op</sub> ), X10 <sup>5</sup>
15 $\mu$ m pitch	4489	30	1700	7	11.9	72.75	76.4	2.0
15 $\mu$ m pitch	4489	30	500	7	3.5	73.05	76.7	2.0
25 $\mu$ m pitch	1600	32	301	20	6.0	72.95	74.75	2.75
50 $\mu$ m pitch	400	36	141	90	12.7	69.6	70.75	7.5

Fast cell recovery time improves SiPM's dynamic range in case of slow signals

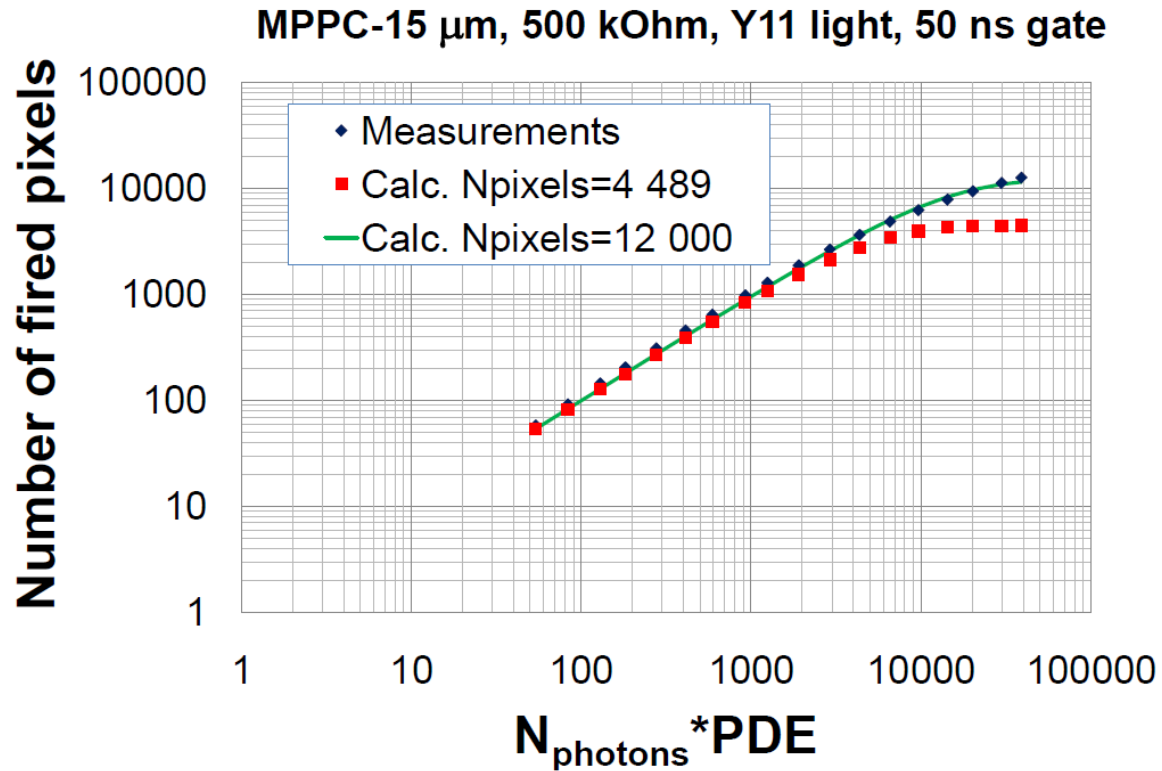
# $R_q=500$ kOhm cell recovery



99% cell recovery after  $\sim 15$  ns



# SiPM linearity measurements (MPPC with 4 500 cells)

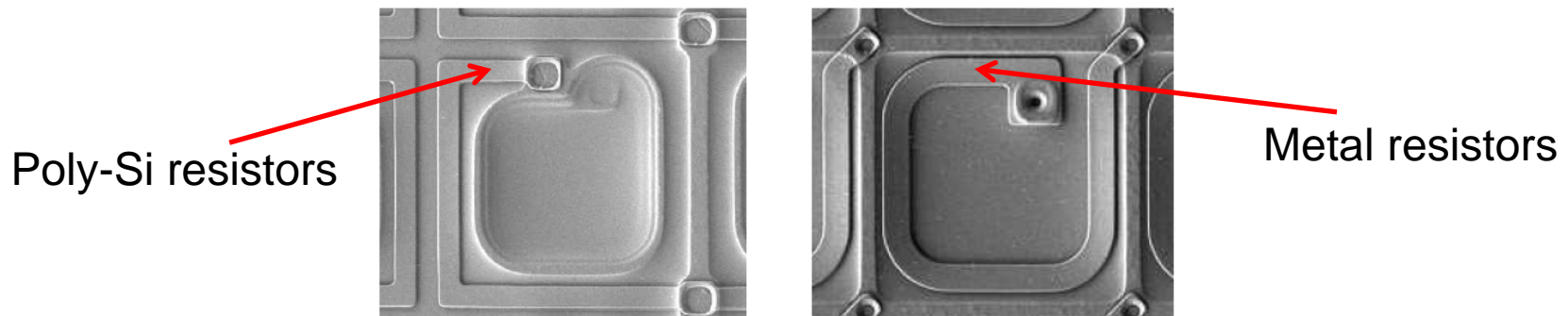


For Y11 light (emission time  $\sim 10$  ns) MPPC works as a SiPM with 12 000 cells. Pixel recovery time constant:  $\tau \sim 3.3$  ns.

# MPPCs with Metal Quenching Resistors

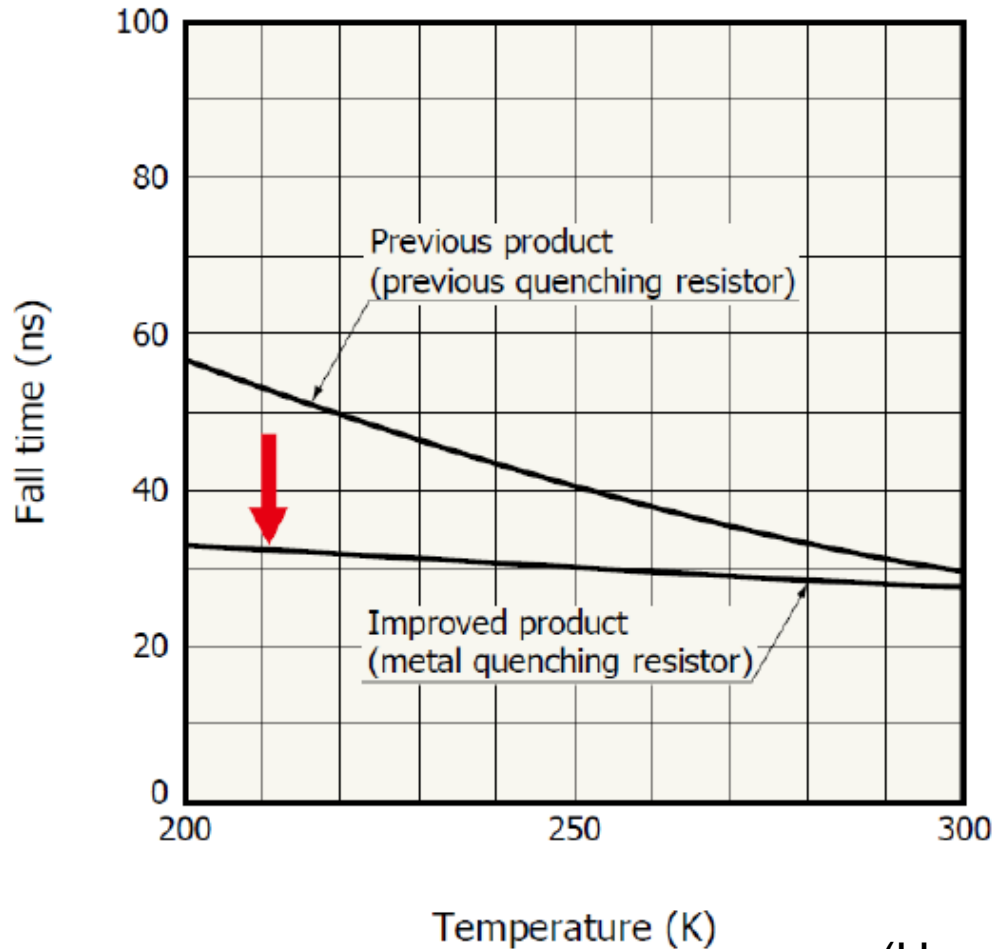
In the newly developed line of MPPCs, MQRs are used instead of poly-Si for quenching. MQR has a high transmittance which allows for it to be put directly on the photosensitive surface to achieve a higher fill factor without reducing the sensitivity of the MPPC

SEM images of a MPPC which has 25  $\mu\text{m}$  micro-cell pitches.



(K.Sato et. al, IEEE NSS-MIC 2013 Conf. record)

# Recovery time vs. temperature dependence



(Hamamatsu Technical info.)

Metal resistor has small temperature dependence → weak recovery time vs. temperature dependence

# Hamamastu SiPM development in 2012

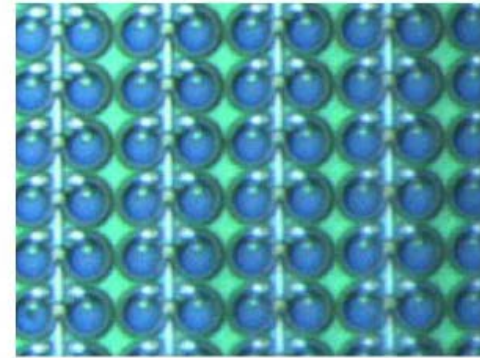
- New 15  $\mu\text{m}$  cell pitch MPPCs with MQR were developed for the CMS HCAL Upgrade project. Types B/C have standard structure (similar to 2011). Types A has a modified structure (MQRs).

Atype-15 Micron

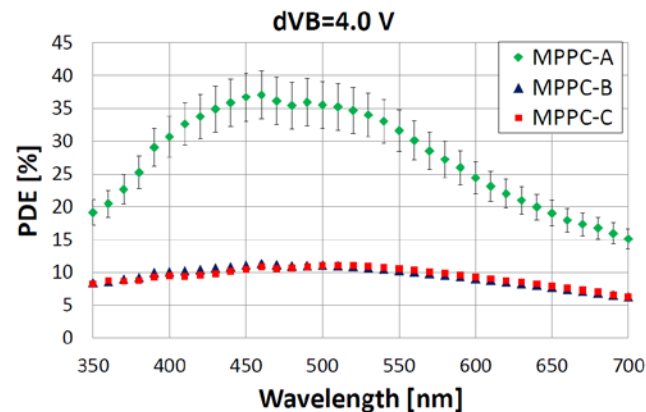
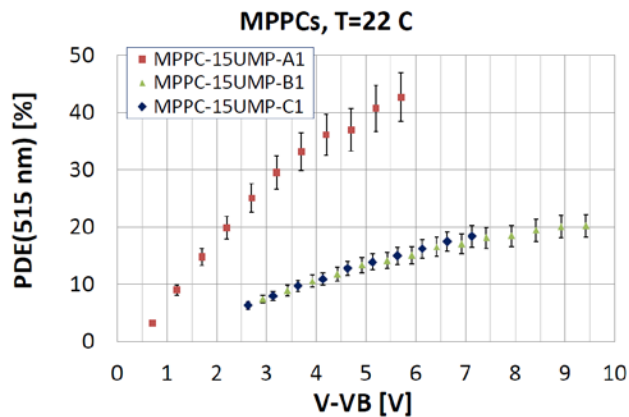


Metal resistors

B/Ctype-15 Micron

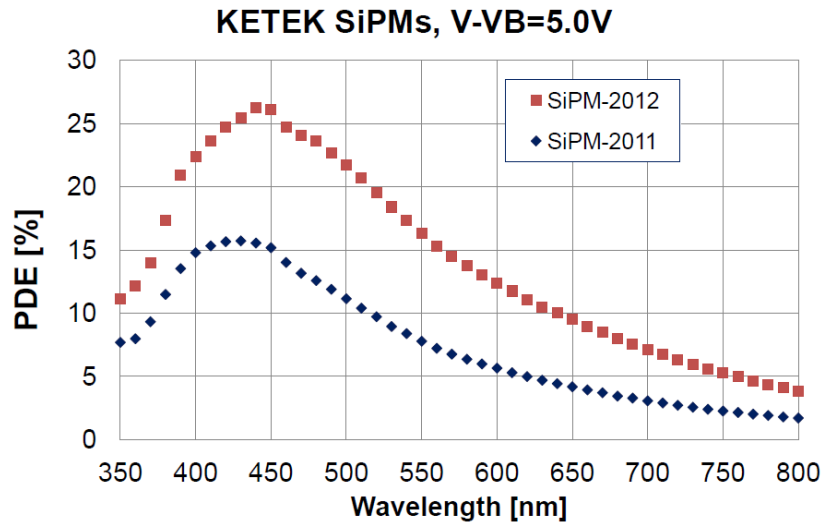


Poly-Si resistors

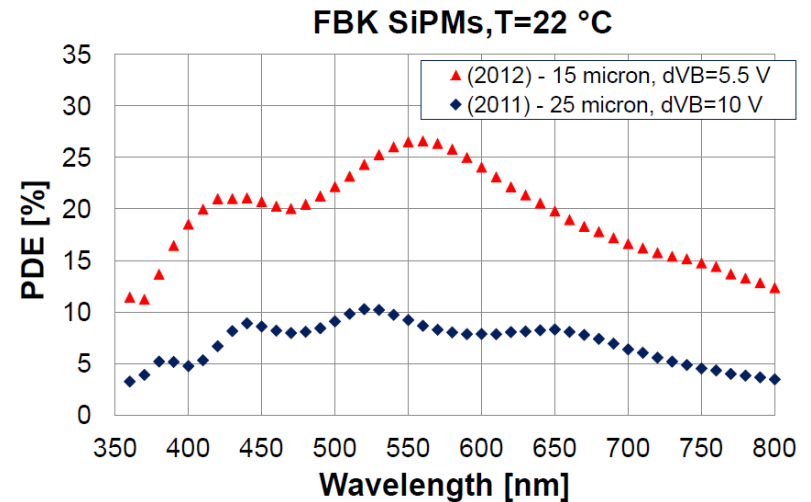


PDE(515 nm) > 30% for 2012 15  $\mu\text{m}$  cell pitch MPPCs (with MQRs). It was improved by a factor of >3 in comparison to the 2011 15  $\mu\text{m}$  cell pitch MPPCs.

# KETEK and FBK large dynamic range SiPM development for the CMS HCAL Upgrade



PDE(515 nm) for 15 cell pitch SiPMs was improved by a factor of 2 (SiPM with additional 0.8  $\mu\text{m}$  epi-layer and deep p-n junction)



PDE(515 nm) > 20% for 2012 15  $\mu\text{m}$  cell pitch SiPMs. It was improved by a factor of >2 in comparison to the 2011 25  $\mu\text{m}$  cell pitch SiPM.

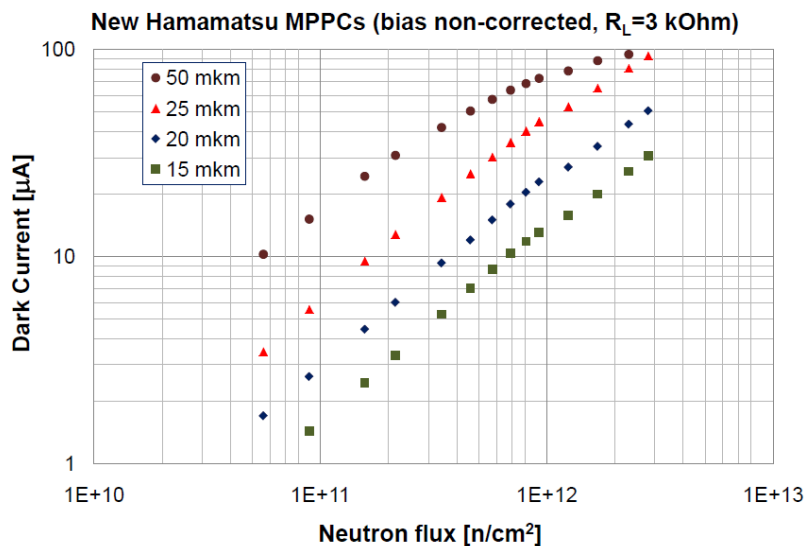
# Radiation hardness studies

Motivation: SiPMs will be used in HEP experiments

Radiation may cause:

- Fatal SiPMs damage (SiPMs can't be used after certain absorbed dose)
- Dark current and dark count increase (silicon ...)
- Change of the gain and PDE vs. voltage dependence (SiPMs blocking effects due to high induced dark carriers generation-recombination rate)
- Breakdown voltage change

# Dark current vs. exposure to neutrons ( $E_{eq} \sim 1$ MeV) for different SiPMs



High energy neutrons/protons produce silicon defects which cause an increase in dark count and leakage current in SiPMs:

$$I_d \sim \alpha \cdot \Phi \cdot V \cdot M \cdot k,$$

$\alpha$  – dark current damage constant [A/cm];  
 $\Phi$  – particle flux [1/cm²];  
 $V$  – silicon active volume [cm³]  
 $M$  – SiPM gain  
 $k$  – NIEL coefficient

$\alpha_{Si} \sim 4 \cdot 10^{-17}$  A\*cm after 80 min annealing at T=60 C (measured at T=20 C)

- No change of  $V_B$  (within 50 mV accuracy)
- No change of  $R_{cell}$  (within 5% accuracy)
- Dark current and dark count significantly increased for all the devices

$$V \sim S \cdot G_f \cdot d_{eff},$$

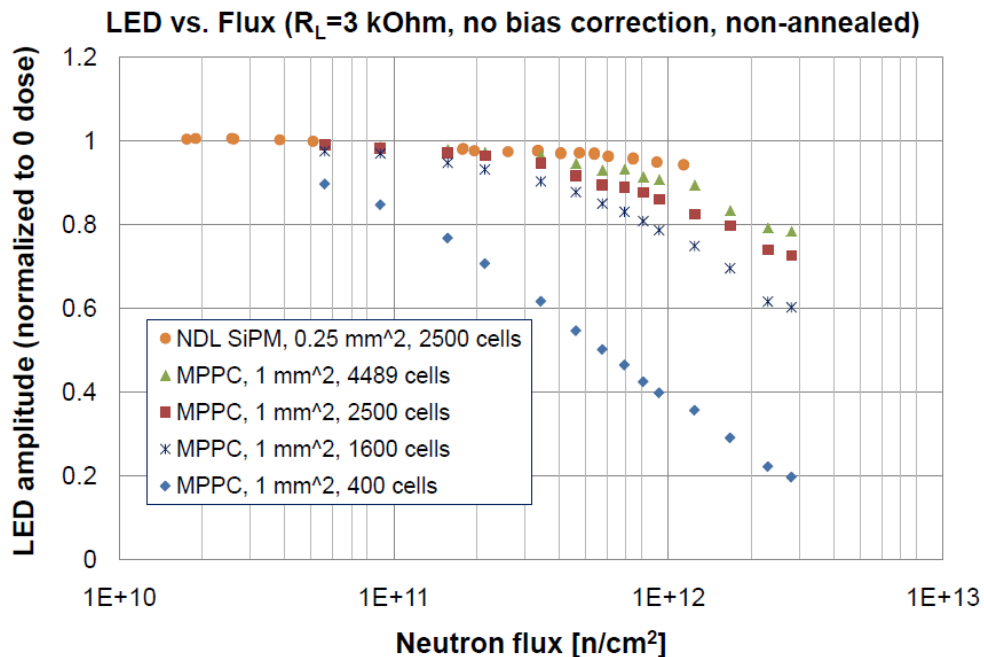
$S$  - area

$G_f$  - geometric factor

$d_{eff}$  - effective thickness

For Hamamatsu MPPCs :  $d_{eff} \sim 4 - 8 \mu m$

# Relative response to LED pulse vs. exposure to neutrons ( $E_{eq} \sim 1$ MeV) for different SiPMs



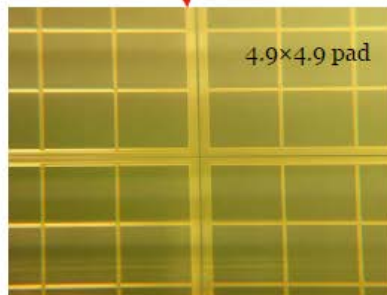
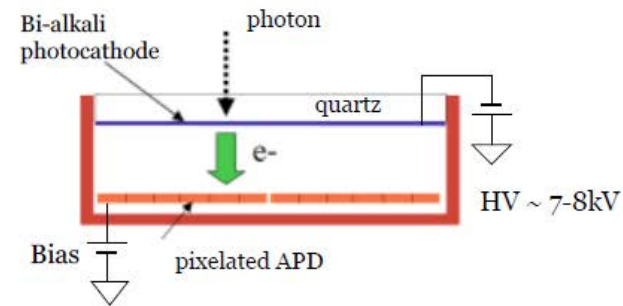
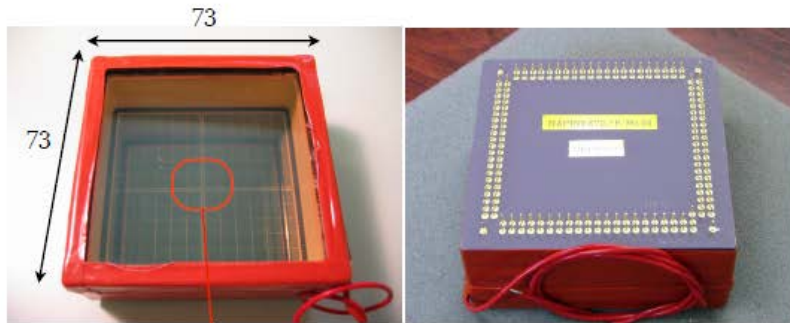
SiPMs with high cell density and fast recovery time can operate up to  $3 \cdot 10^{12}$  neutrons/cm<sup>2</sup> (gain change is < 25%).



# HPDs/HAPDs

# Hybrid Avalanche Photo-detector (HAPD)

144 ch. HAPD developed by Hamamatsu for Belle II proximity focusing RICH counter with silica aerogel radiator

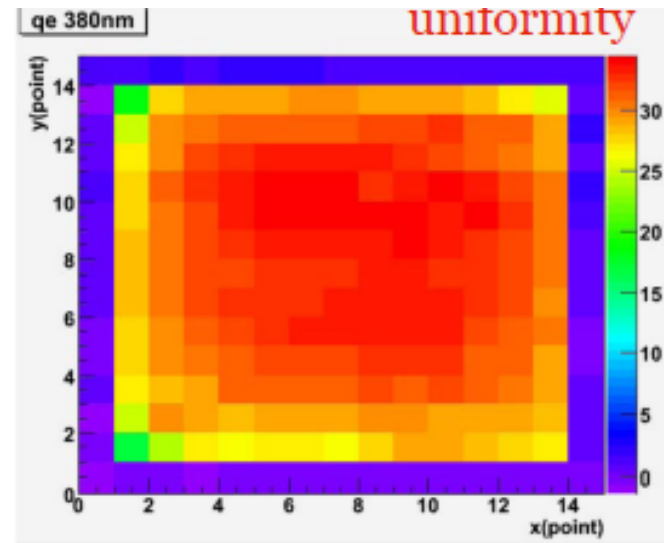
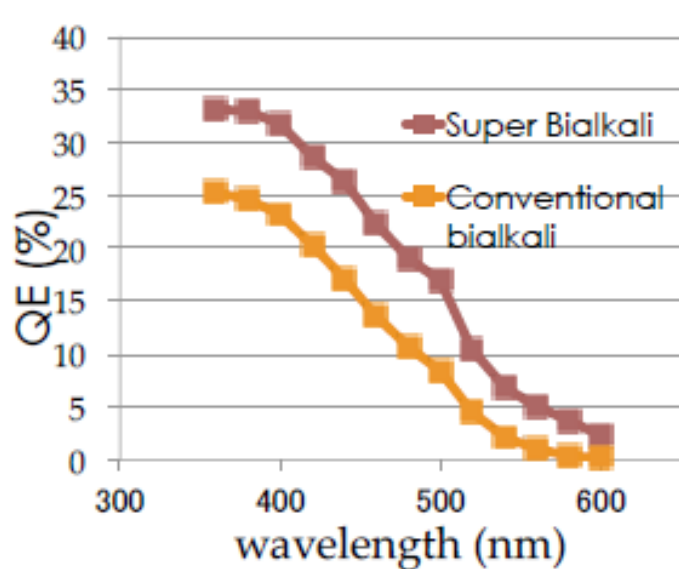


4 pixelated APDs are housed

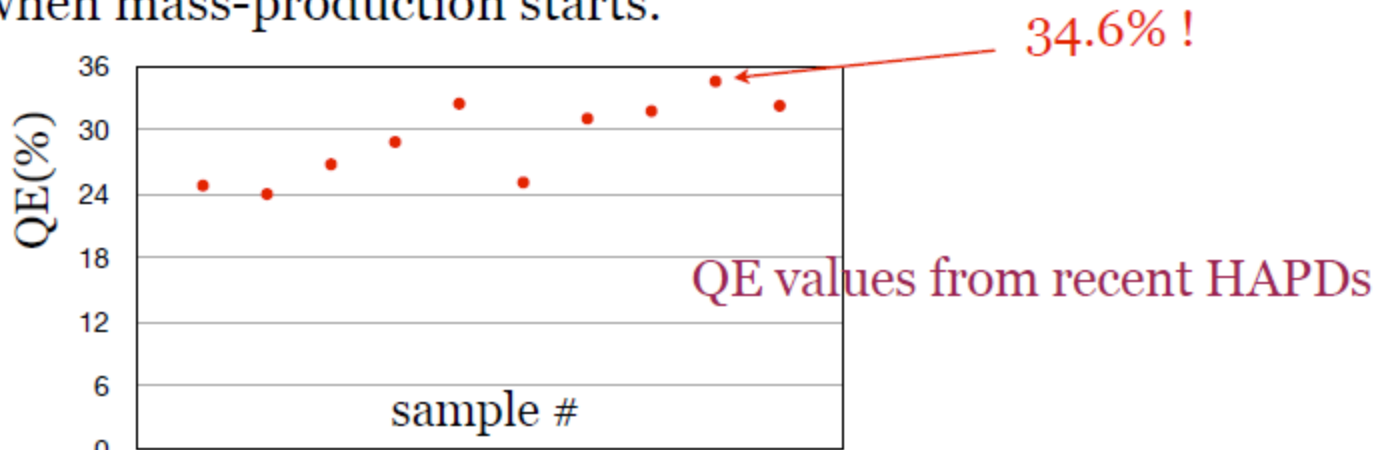
## Specifications

package	73×73mm <sup>2</sup>
sensitive area	64%
# of pixels	144(36×4chips)
capacitance	80pF
weight	220g
peak QE	27~31%
bombardment gain	1300~1500
avalanche gain	~50
total gain	~10 <sup>5</sup>

# HAPD Quantum Efficiency

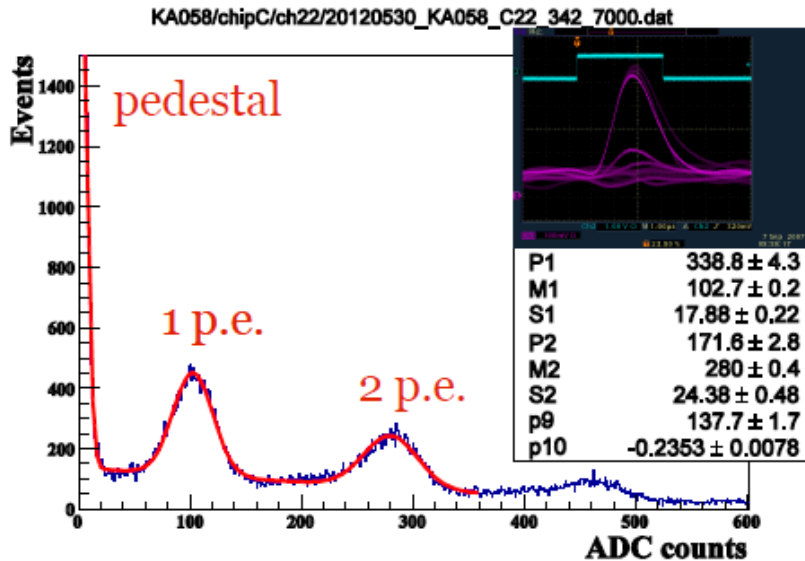


HAPD samples show ~35 % at the best. Expect more stable and high values when mass-production starts.



# HAPD Single Photon Response

pulse height distribution



$$\sigma_{\text{pedestal}} = 2.9 \times 10^3 \text{ electrons}$$

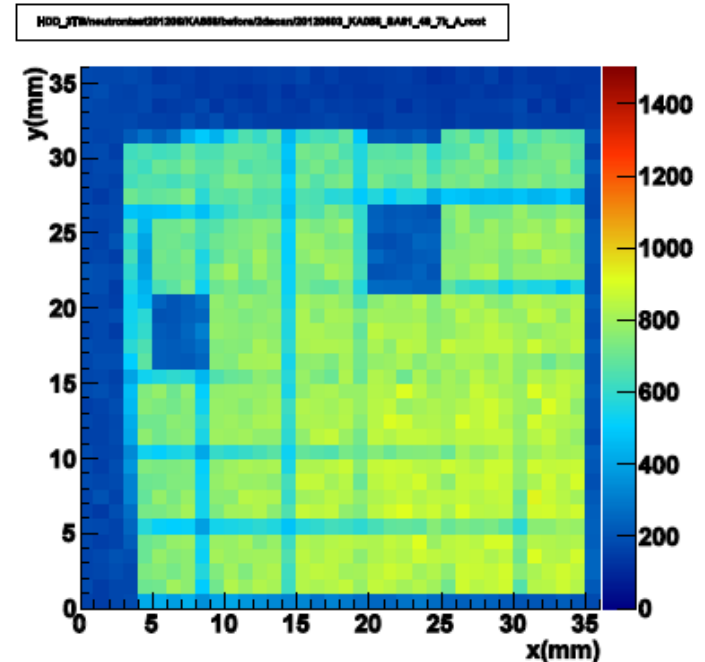
$$\text{Gain} = 8.2 \times 10^4$$

from 1 and 2 p.e. peaks

$$S/N = G/\sigma_{\text{pedestal}} \sim 28$$

blue LED illuminated  
HV: -7kV bias: 342V

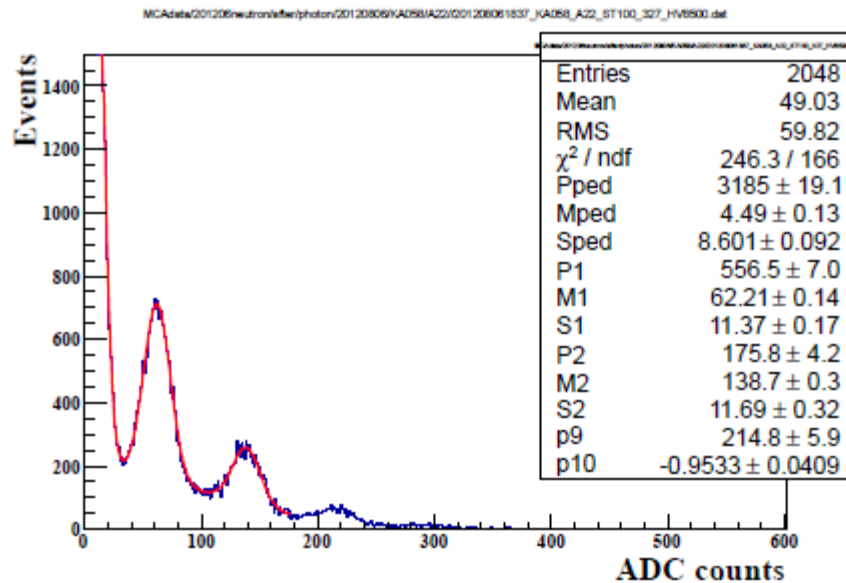
1 APD uniformity scan



Clear single photon signal observed !

# Neutron radiation damage

HAPD samples were irradiated up to  $10^{12}$  n/cm<sup>2</sup> at the JPARC MLF BL10 beam facility



(I.Adachi, PhotoDet 2012)

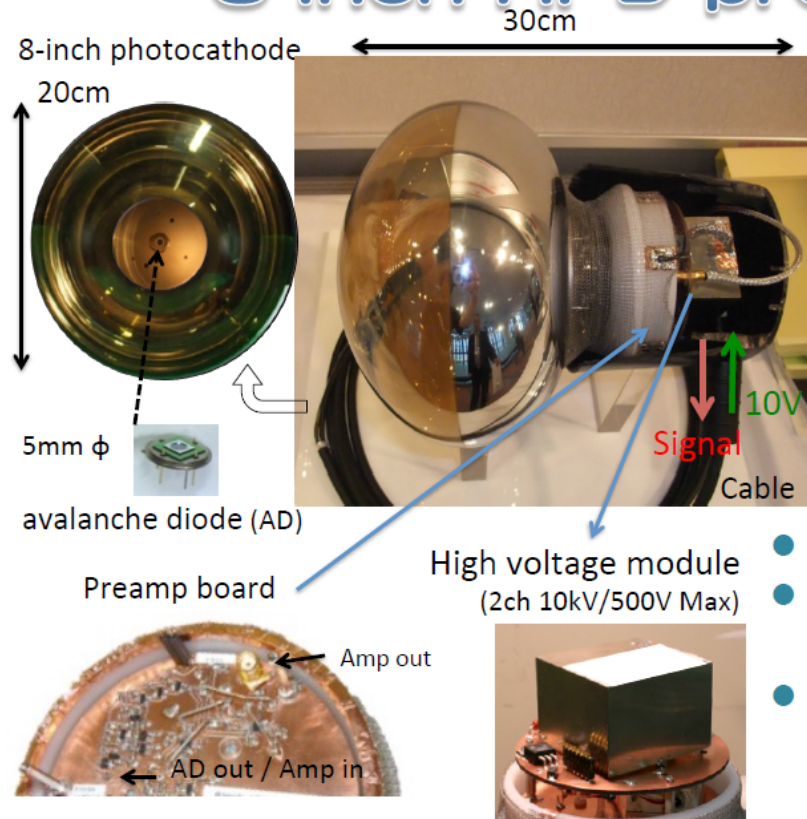
Single-photon signal 30 days after neutron irradiation test.

Sufficient single-photon sensitivity is still retained after  $10^{12}$  n/cm<sup>2</sup>

# Large-Aperture HAPD for Hyper-Kamiokande

Hyper-Kamiokande ~1 Mton water Cherenkov detector needs low cost, high performance large aperture photodetector

## 8-inch HPD prototype

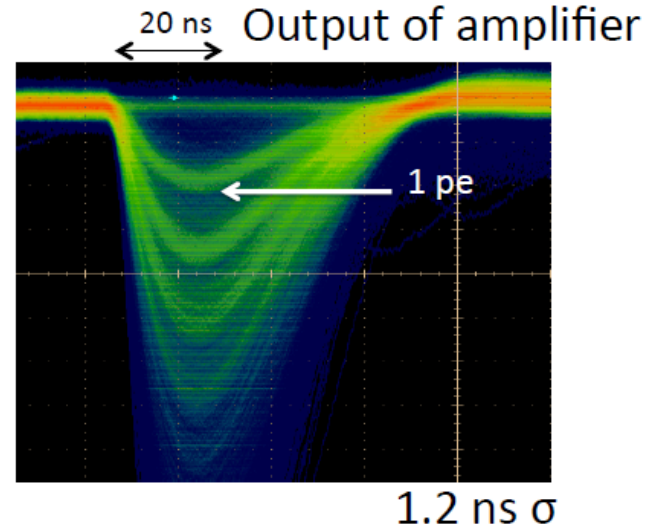
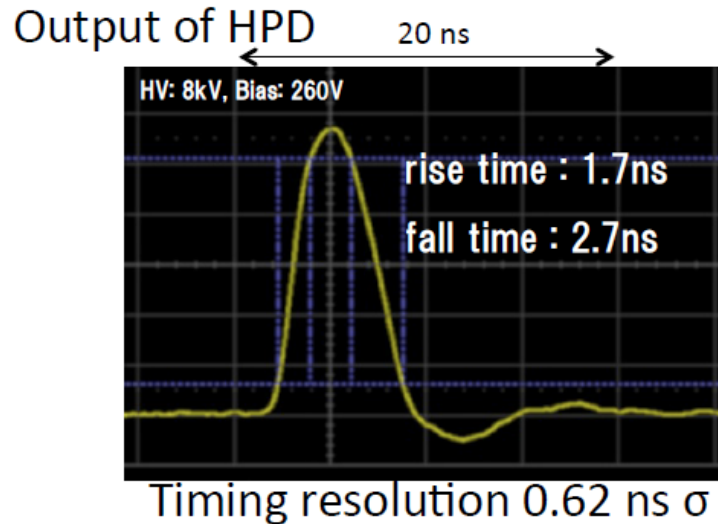


### Specification

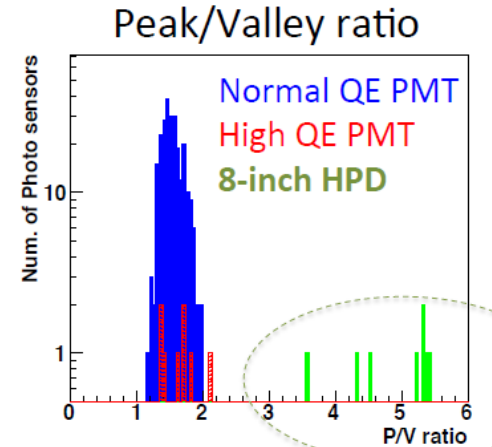
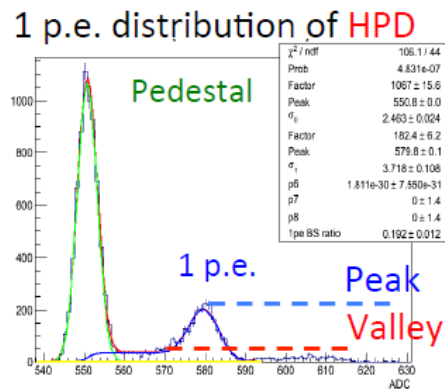
Spectral response	300 - 650 (420 max.) nm	
Photocathode	Bialkali	
Window material	Borosilicate glass	
Gain	4 - 9 × 10 <sup>4</sup>	
Time	Rise	1.7 ns
	Fall	2.7 ns
	T.T.S.	0.62 ns (σ)
Dynamic range	100 pC (1.5 × 10 <sup>4</sup> p.e.)	

- By Hamamatsu Photonics
- Use in water without high voltage line.
- HV module and preamplifier are packed and waterproofed.

# Single Photon Response



(Y. Nishimura, IEEE NSS-MIC 2013)



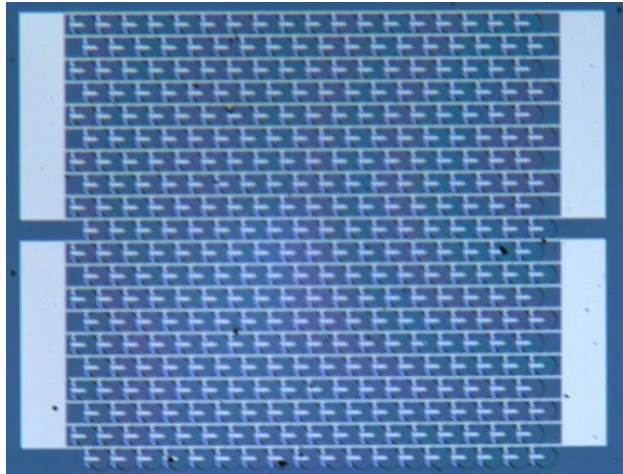
Results are very encouraging. 20 inch HAPD is under development!

# GaAs SSPMs



# GaAs SSPM

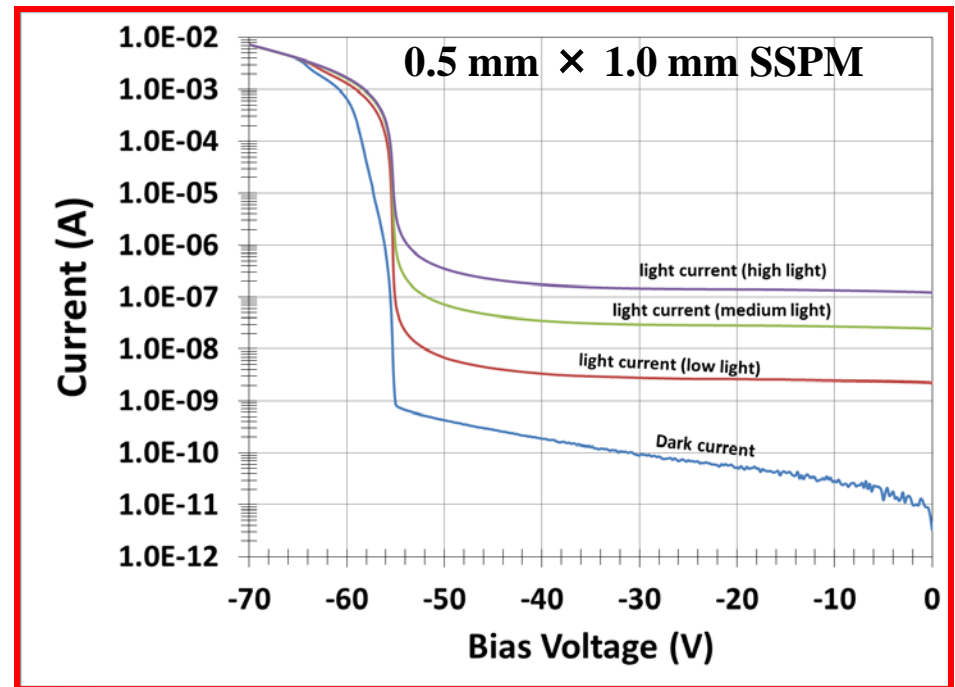
LightSpin's GaAs  
Photomultiplier Chip™



Developed for the CMS HCAL  
Upgrade Phase II Project:

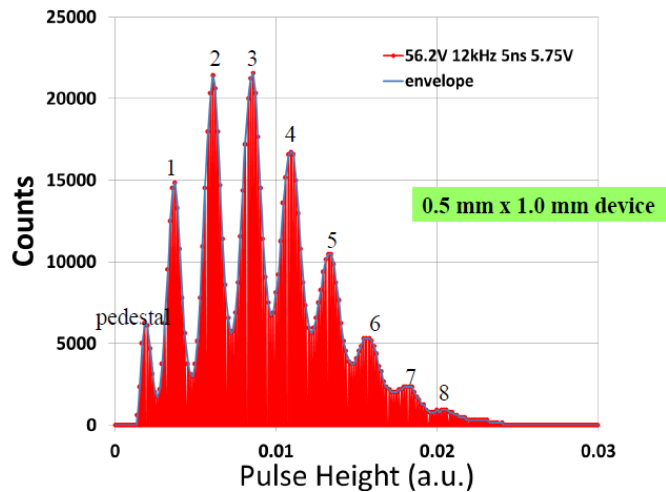
UNIVERSITY of VIRGINIA  
LightSpin Technologies, Inc.

Array of single-photon avalanche  
devices (SPADs): 2x0.5mmx1  
mm, 360 SPADs/mm<sup>2</sup>

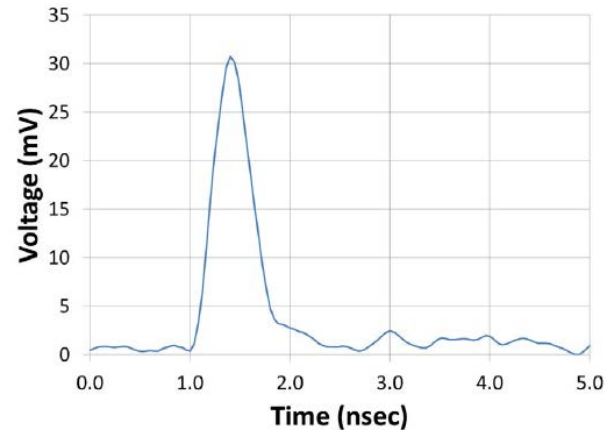


$E_g(\text{GaAs}) \sim 1.4 \text{ eV}$  ( $E_g(\text{Si}) \sim 1.1 \text{ eV}$ ) → potentially smaller DC after irradiation? Very high electron mobility → fast timing?

# GaAs SSPM parameters - I

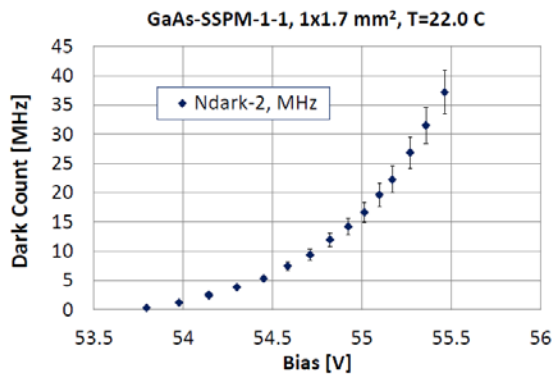


Pulse Height Spectrum

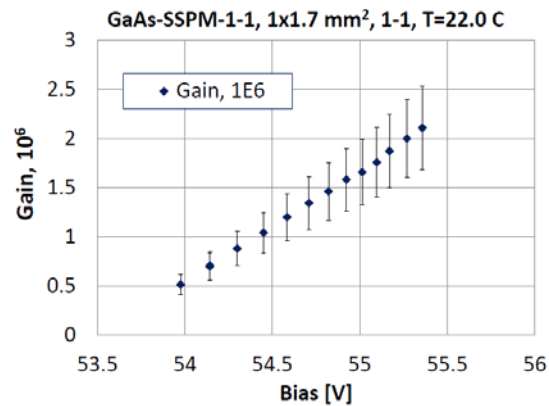


B. Cox  
May 24, 2012

Single Photon pulse from GaAs SPAD

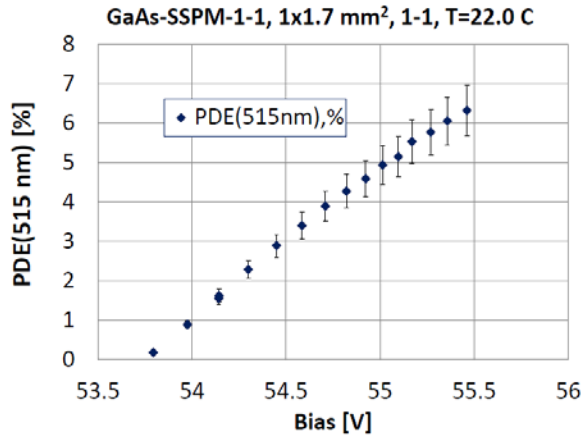


Dark Count vs. Bias

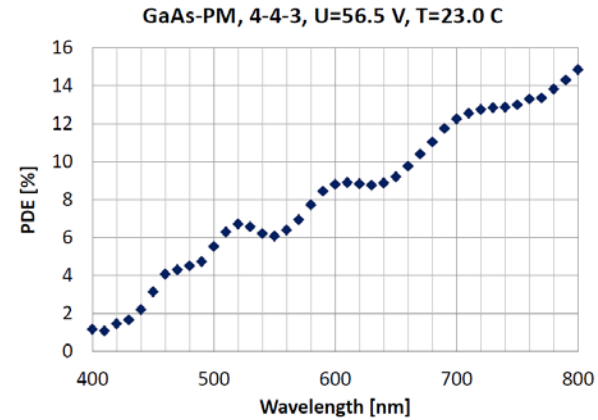


Gain vs. Bias

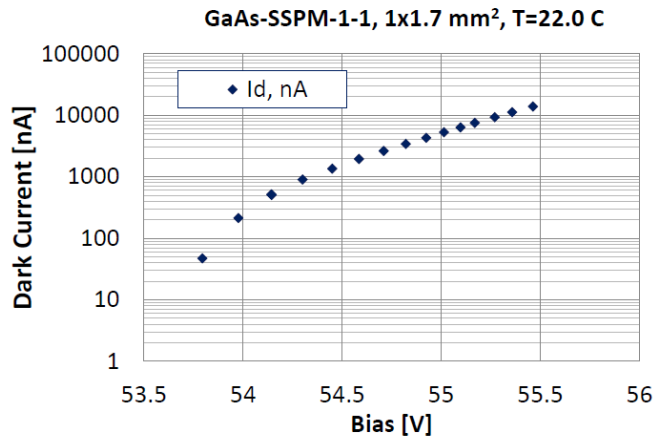
# GaAs SSPM 1x1.7 mm<sup>2</sup>



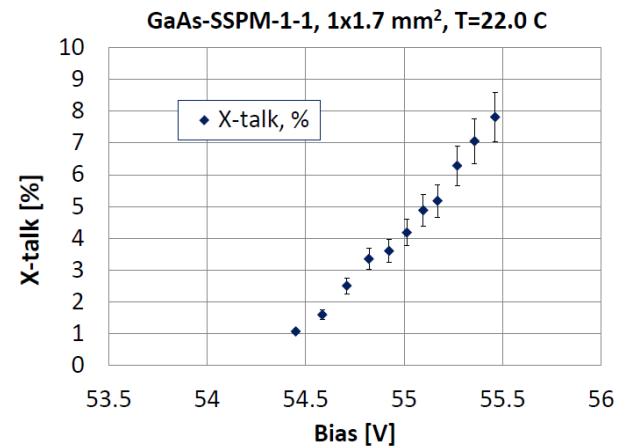
**PDE vs. Bias**



**PDE vs. wavelength (U=56.5 V)**



**Dark Current vs. Bias**



**X-talk vs. Bias**

# Summary

## ***Significant progress in development of SSPMs over last 2-3 years:***

- High PDE ~50-65% for blue-green light (KETEK and Hamamatsu)
- Reduction of dark count at room temperature ~50-100 kHz/mm<sup>2</sup>, (Hamamatsu, KETEK, Philips, Exelitas)
- Low cross-talk (<1-3%, CPTA/Photonique, STMicroelectronics, KETEK, Hamamatsu)
- Low temperature coefficient (~0.3-0.5%/C – CPTA, Philips, KETEK)
- Fast timing (~50 ps (RMS) for single photons)
- Large dynamic range (>4 000 pixels/mm<sup>2</sup>, Zecotek, NDL, KETEK, Hamamatsu)
- Large area (≥6x6 mm<sup>2</sup> - Hamamatsu, FBK, SensL, STMicroelectronics KETEK, Philips ...)
- SiPM arrays: 8x8, 0.25x128 ...
- GaAs SSPMs were developed. InGaP SSPMs will be produced soon

**All this (together with good understanding of radiation hardness issues) makes these devices excellent candidates for applications in HEP experiments, astroparticle physics and in medicine (PET, MRI/PET, CT ...)**

# Future of SiPM development

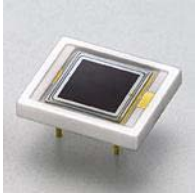
The development of SiPMs is accelerating. What can we expect in 2-4 years from now?

- PDE > 70% for 350-650 nm light
- dark count rate <30 kHz/mm<sup>2</sup> at room temperature
- single photon timing < 50 psec (FWHM)
- active area >100 mm<sup>2</sup>
- high DUV light sensitivity (PDE(128 nm~20-40%)
- radiation hard SiPMs - up to 10<sup>14</sup> n/cm<sup>2</sup>
- production cost <1 \$/mm<sup>2</sup>
- ....

Thank you for your attention!

# Back-up

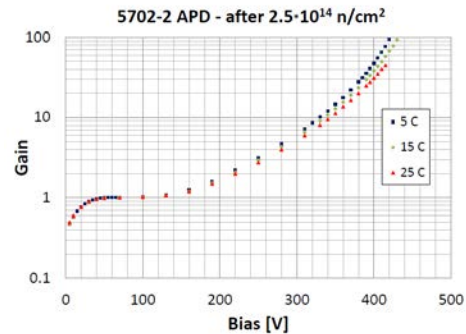
# APDs



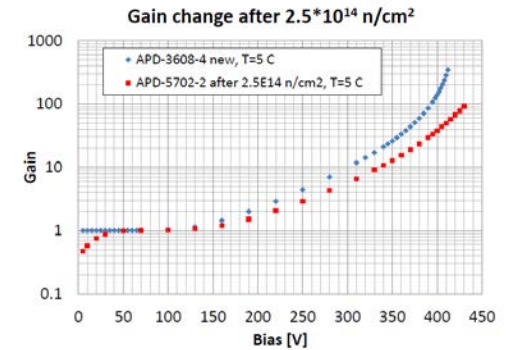
The CMS APD (produced by Hamamatsu) was irradiated up to  $2.5 \times 10^{14}$  n/cm<sup>2</sup> (1 MeV equivalent).

## S8148 APD

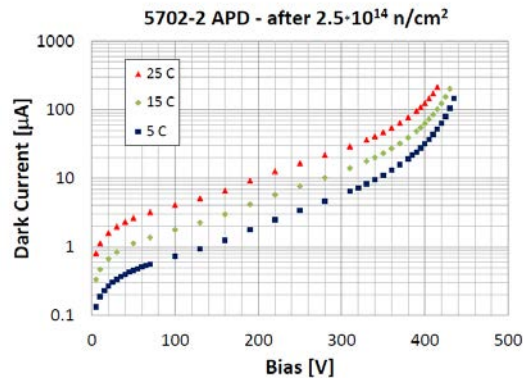
- Area: 5x5 mm<sup>2</sup>
- $V_{op}$ : 350-400 V
- Gain ( $V_{op}$ ): 50
- QE(420nm): 75%
- Capacitance: 80 pF
- ENF(M=50): 2.2



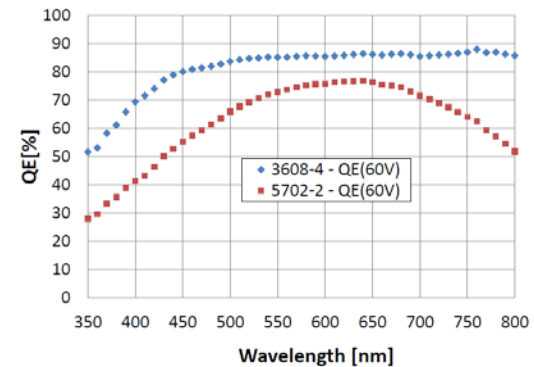
Gain vs. bias at T=25, 15 and 5 C



Gain vs. bias (new and irradiated)



Dark current vs. bias at T=25, 15 and 5 C

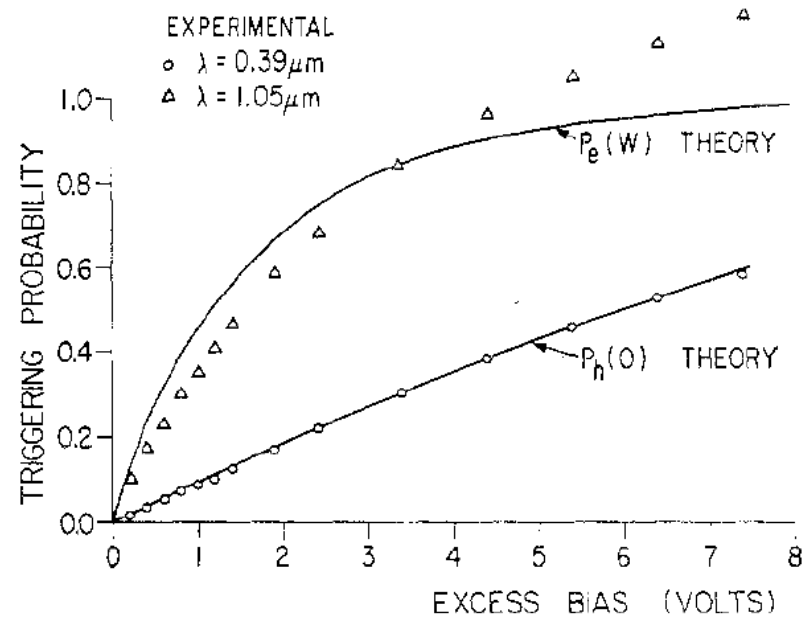
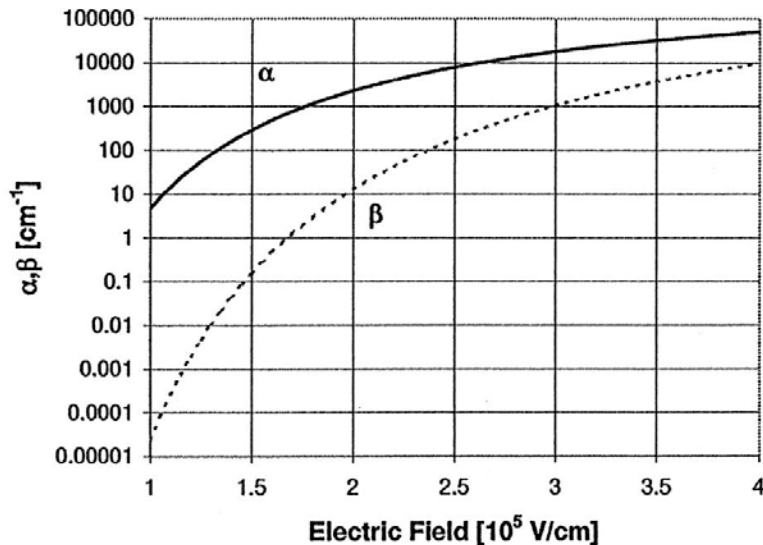


Quantum efficiency (new and after  $2.5 \cdot 10^{14}$  n/cm<sup>2</sup>, Gain=1)

APD irradiated with  $2.5 \cdot 10^{14}$  n/cm<sup>2</sup> is still operational as a light detector with gain > 50 at T < 15 C

# Breakdown initiation probability

Ionization coefficients for electrons and holes in silicon



IEEE TRANSACTIONS ON ELECTRON DEVICES, VOL. ED-19, NO. 9, SEPTEMBER 1972

## Triggering Phenomena in Avalanche Diodes

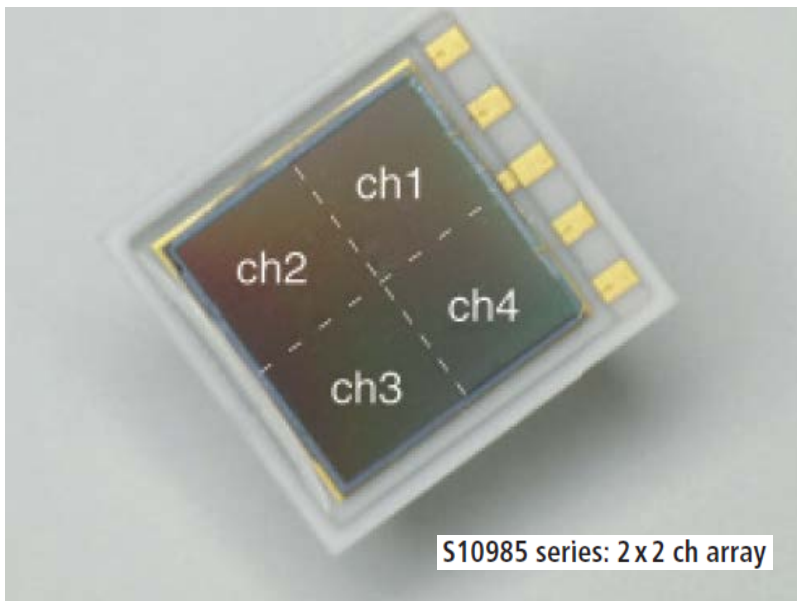
WILLIAM G. OLDHAM, MEMBER, IEEE, REID R. SAMUELSON, MEMBER, IEEE, AND PAOLO ANTOGNETTI, MEMBER, IEEE

Because of the higher ionization coefficient, the electron triggering probability is always higher than that for holes

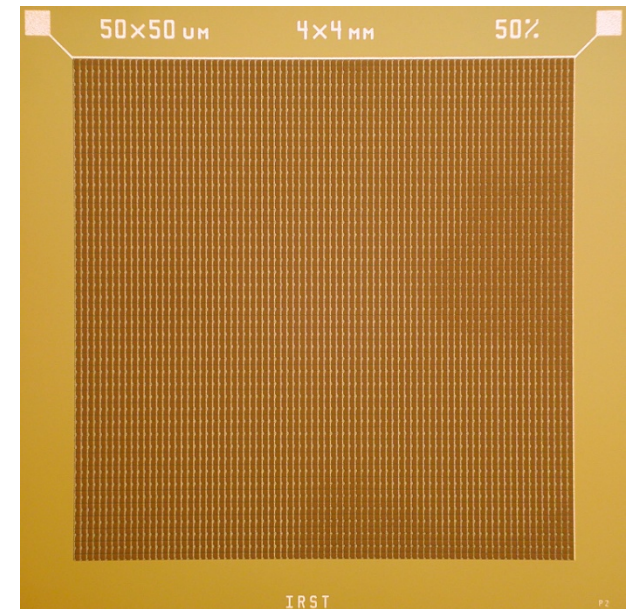


# Large area SiPMs

SiPMs with  $\geq 3 \times 3 \text{ mm}^2$  sensitive area produced by many companies: Hamamatsu, CPTA, Pulsar, Zecotek, SensL, FBK, STMicro ...



Hamamatsu MPPC,  $6 \times 6 \text{ mm}^2$ , 14 400 cells



FBK SiPM,  $4 \times 4 \text{ mm}^2$ , 6400 cells

# SiPM arrays

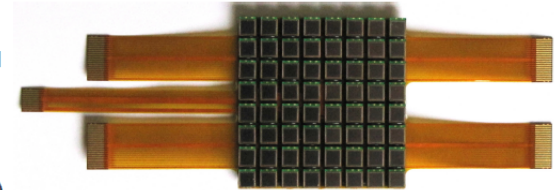
SensL array for PET/MRI (16x9 mm<sup>2</sup>)



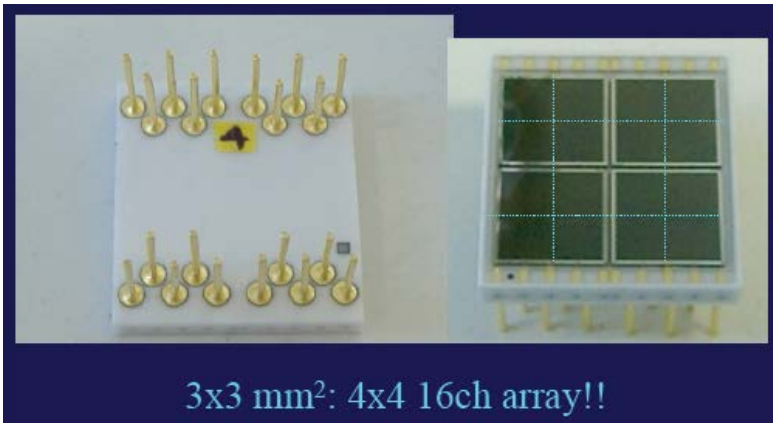
64 ch. MPPC array for RICH

## Array of SiPMs: Hamamatsu MPPC S11834-3388DF

- Multi-pixel Photon Counter (MPPC) is a novel 8x8 SiPM array, each SiPM representing one 5x5 mm<sup>2</sup> channel
- Active area is large (3x3 mm<sup>2</sup>)
- Pixel size: 50 μm
- Dark count rate is rather low (~10<sup>5</sup> Hz/mm<sup>2</sup>)
- Operating voltage: (70 ± 10) V

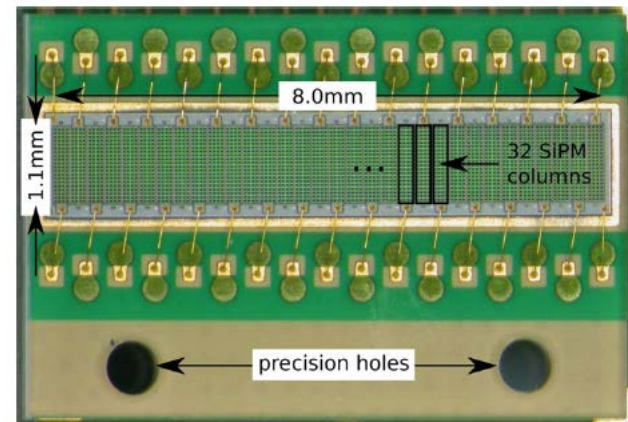


MPPC array for MAGIC telescope

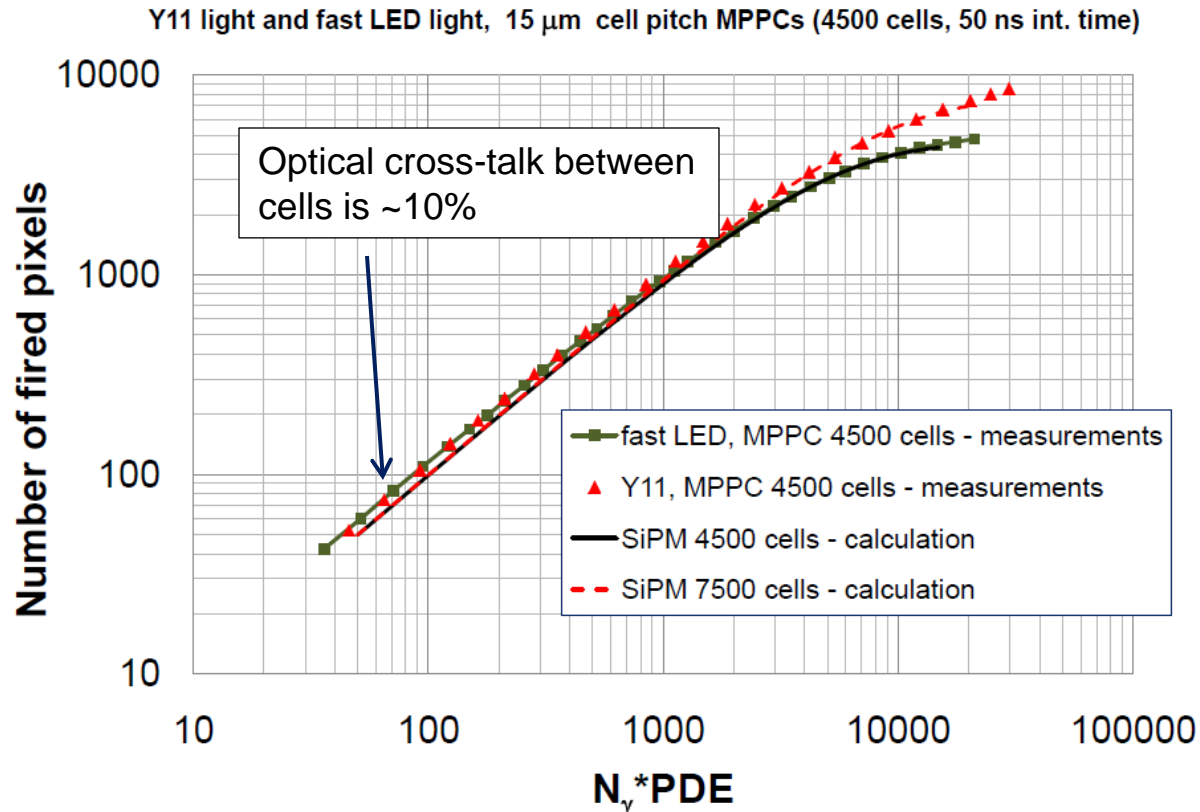


3x3 mm<sup>2</sup>: 4x4 16ch array!!

MPPC array for PEBS scintillating fiber (250 μm Ø) сцинт. tracker NIM A 622 (2010) 542



# SiPM linearity measurements (MPPC with 4 500 cells)



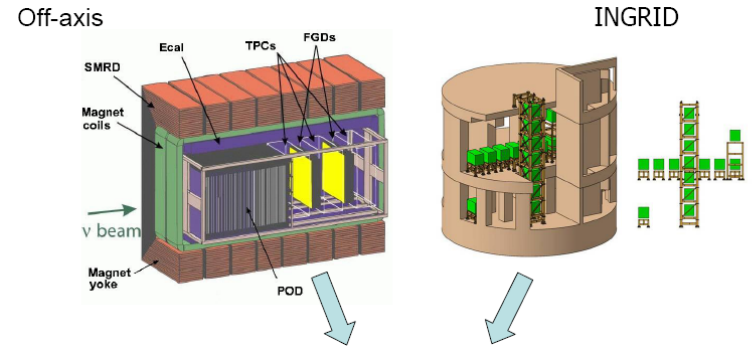
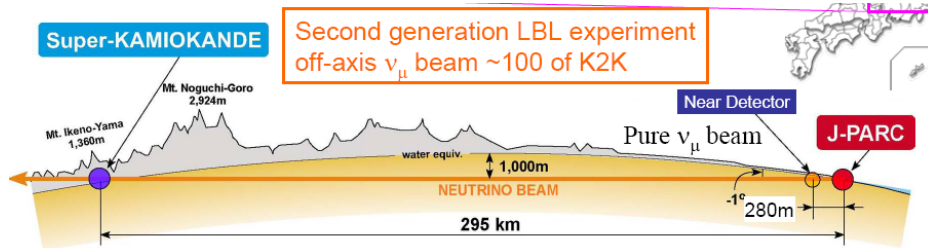
Fast LED light: the MPPC with 4 500 cells is equivalent to a SiPM with 4 500 cells.

Y11 light (emission time ~10 ns): the same MPPC works as a SiPM with 7 500 cells. Pixel recovery time constant:  $\tau \sim 12$  ns.

# SiPMs for HEP experiments

(SiPMs are used in large quantities now!)

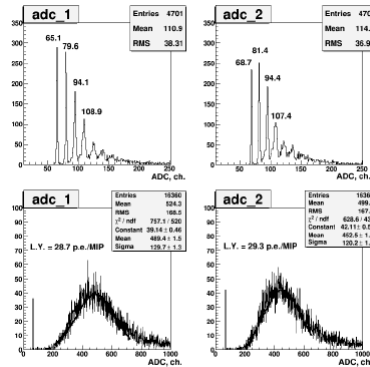
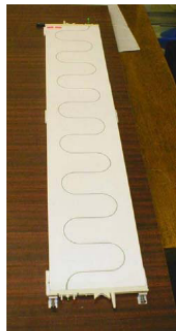
# T2K neutrino experiment



## SMRD detectors

## Light yield

Extruded plastics  $\sim 7 \times 170 \times 870 \text{ mm}^3$   
Y11 fibers embedded in S-grooves



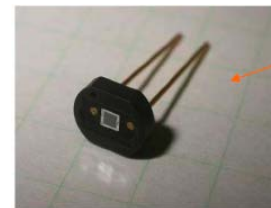
$l.y. (\text{sum of 2 ends}) = 58 \text{ p.e./MIP}$

MIP detection efficiency > 99.9%  
 $\sigma_t$  (MIP)  $\sim 0.7 \text{ ns}$   
Spatial resolution  $\sim 7 \text{ cm}$

## Scintillator detectors with WLS fibers

- Individual fiber readout
- FGD, POD, Ecal, SMRD, INGRID:  $\sim 60000$  readout channels
- Limited space for photosensors
- Magnetic field

## Hamamatsu MPPC: active area $1.3 \times 1.3 \text{ mm}^2$

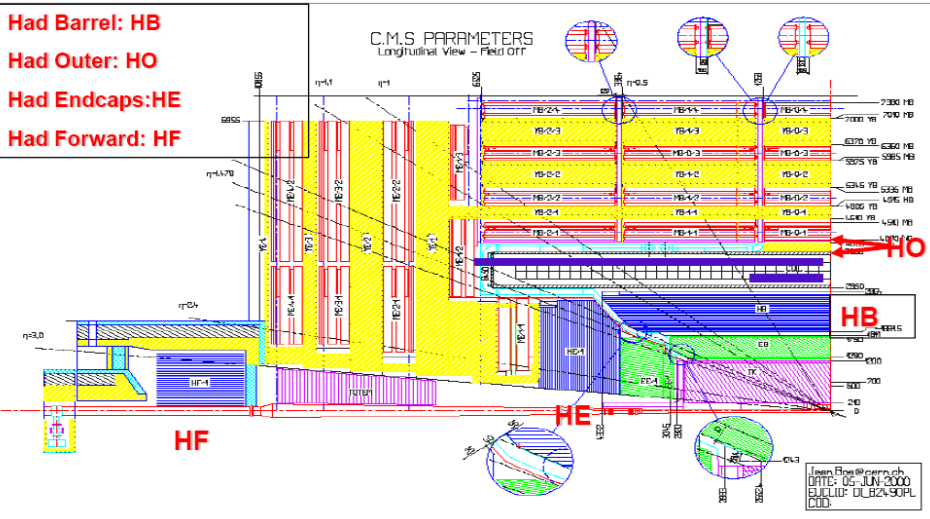


Number of pixels	667
Pixel size	$50 \times 50 \text{ }\mu\text{m}$
Gain	$\sim 0.7 \times 10^6$
PDE at 525 nm	25-30%
Dark rate, $th = 0.5 \text{ p.e.}, 22C$	$\leq 1000 \text{ kHz}$
Pulse width	$< 100 \text{ ns}$
Cross-talk	10-15%
After pulses	10-15%

(Yu. Kudenko, G-APD workshop, GSI, Feb. 2009)

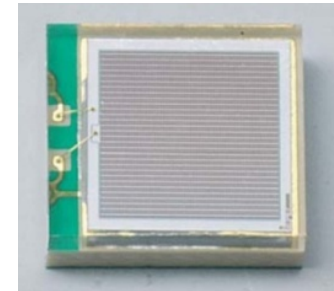
Y. Musienko (louri.Musienko@cern.ch)

# MPPCs for the CMS HO HCAL



HO HPDs will be replaced with the MPPCs (3x3 mm<sup>2</sup>, ~3 000 channels)

Hamamatsu 3x3 mm<sup>2</sup> MPPC



HO SiPM readout module – 18 channels

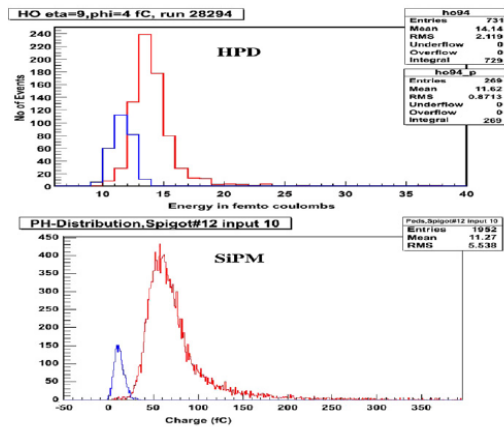
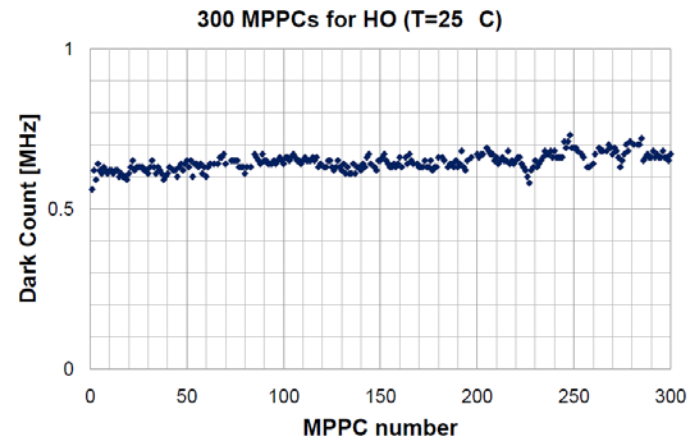
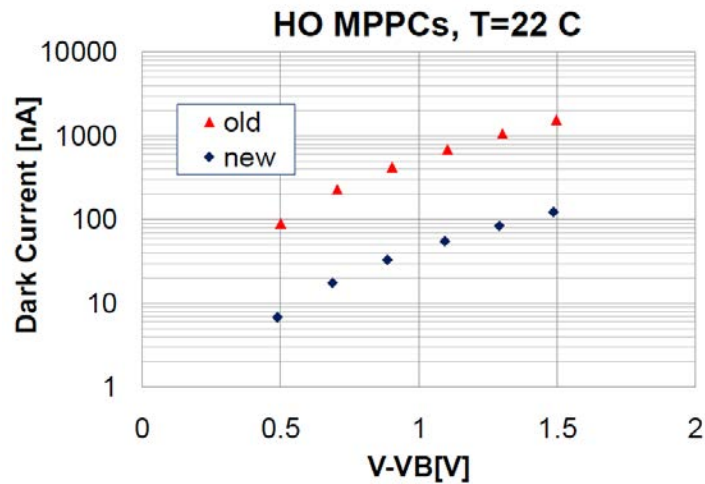
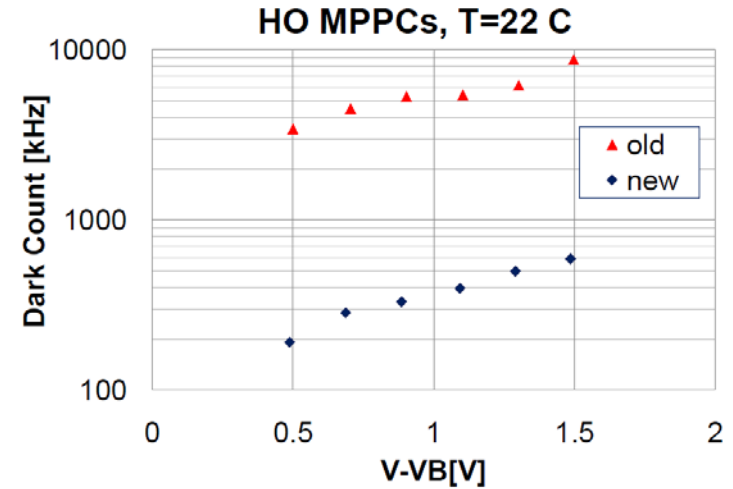
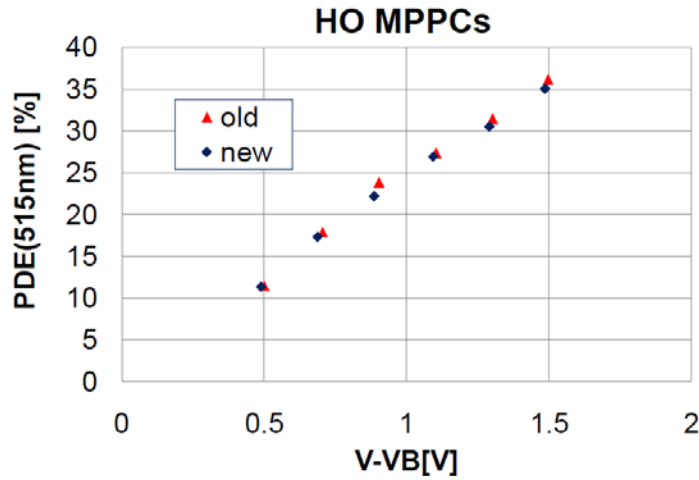


Fig. 3. Pedestal and muon signal distributions for HPD and SiPM [3].



# Some properties of the CMS HO MPPC's

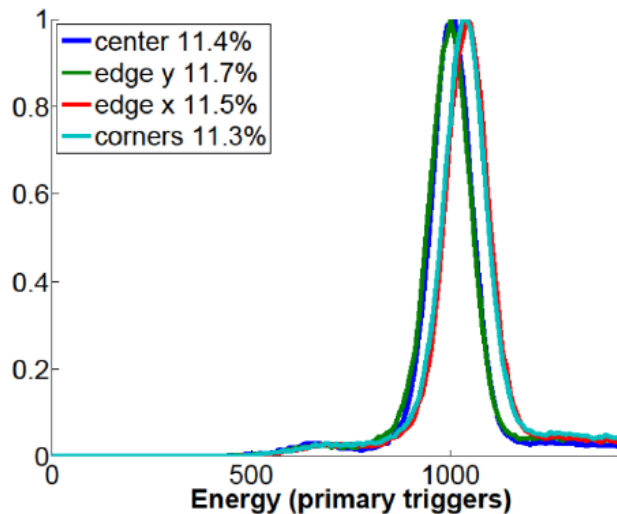


Dark count of new 3x3 mm<sup>2</sup> MPPCs is ~ 600 kHz (or ~70 kHz/mm<sup>2</sup>) at T=25 C !

# dSiPM for PET application

## Energy resolution

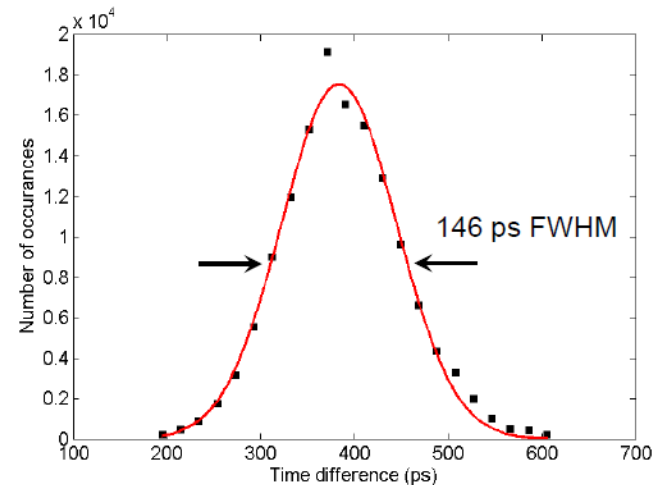
- 24 mm x 24 mm x 10 mm Ca-codoped LSO:Ce
- PDPC DPC-6400-44-22 dSiPM array
- Average energy resolution: ~11.5% FWHM
- Negligible saturation



Measured using  $^{22}\text{Na}$   $\gamma$ -source

## Coincidence resolving time

**CRT for 2 detectors: 167 ps FWHM**



Timing measurement against 85 ps FWHM reference detector



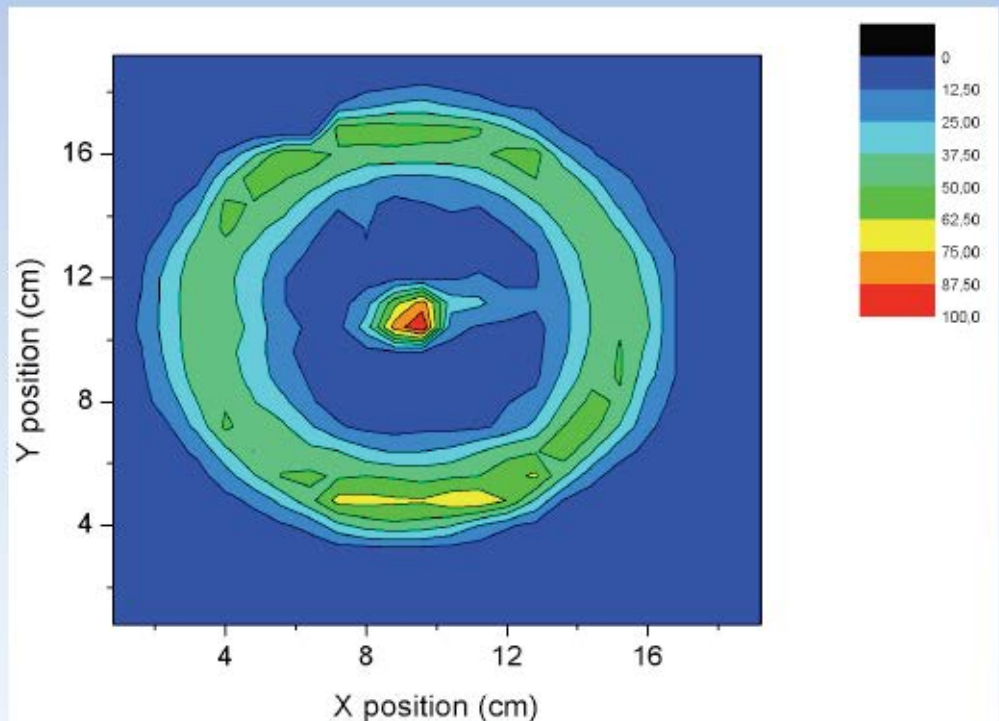
# Use of dSiPM with aerogel RICH detector

- Philips dSiPM looks very promising for large scale applications
- FARICH prototype with  $\sim 20 \times 20$  cm array of Philips dSiPM is being tested now in CERN at T10 test beam from PS:



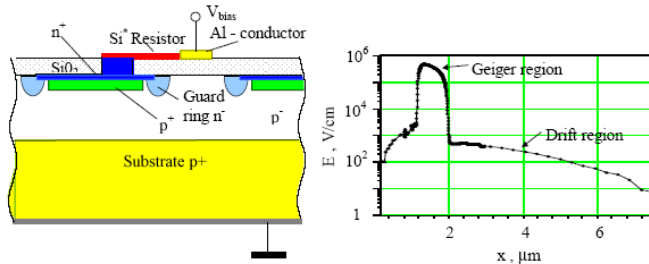
Test beam experiment with FARICH prototype

A.Yu.Barnyakov, M.Yu.Barnyakov, I.Yu.Basok, V.E.Blinov, V.S.Bobrovnikov, A.A.Borodenko, A.R.Buzykaev, A.F.Danilyuk, V.V.Gulevich, S.A.Kononov, E.A.Kravchenko, I.A.Kuyanov, A.P.Onuchin, I.V.Ovtin, A.A.Talyshev

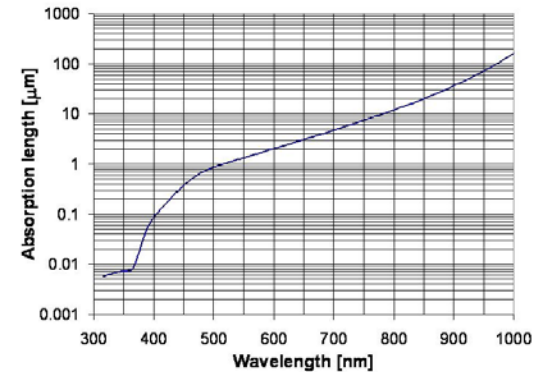


# Structure for green/red light (n on p)

Sensitivity for blue light is low. Blue light is absorbed close to the SiPM surface – holes initiate an avalanche

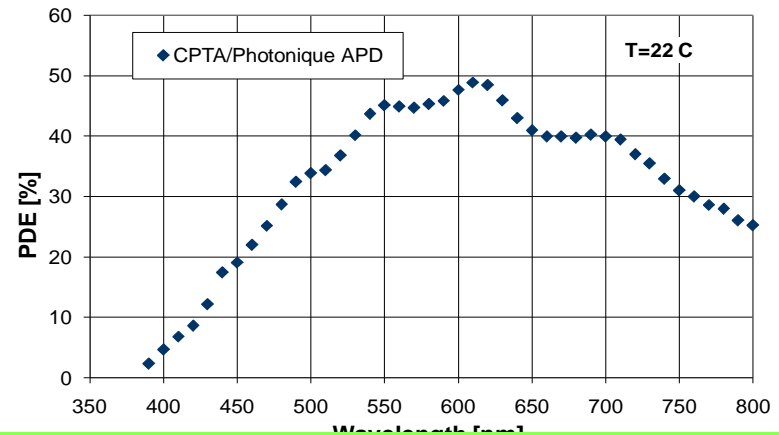
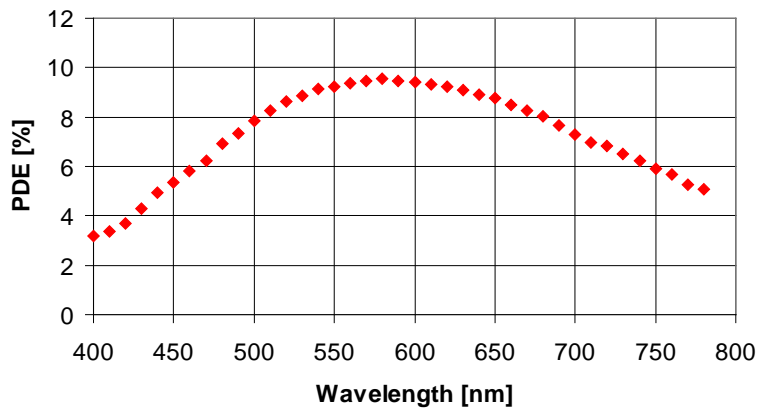


## Absorption length for light in silicon



B. Dolgoshein et. al., “An advanced study of silicon photomultiplier”, ICFA-2001

MEPh/PULSAR APD, T=22C, U=59 V



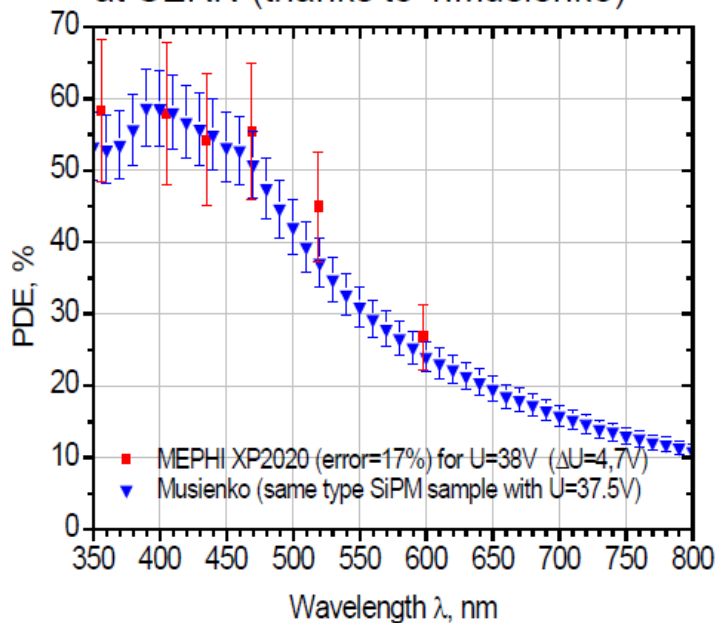
SiPMs with ~60-70% GF (for 50 $\mu$ m cell pitch) were produced: PDE=40-50% (red light)

(Y. Musienko, PD-07, Kobe)

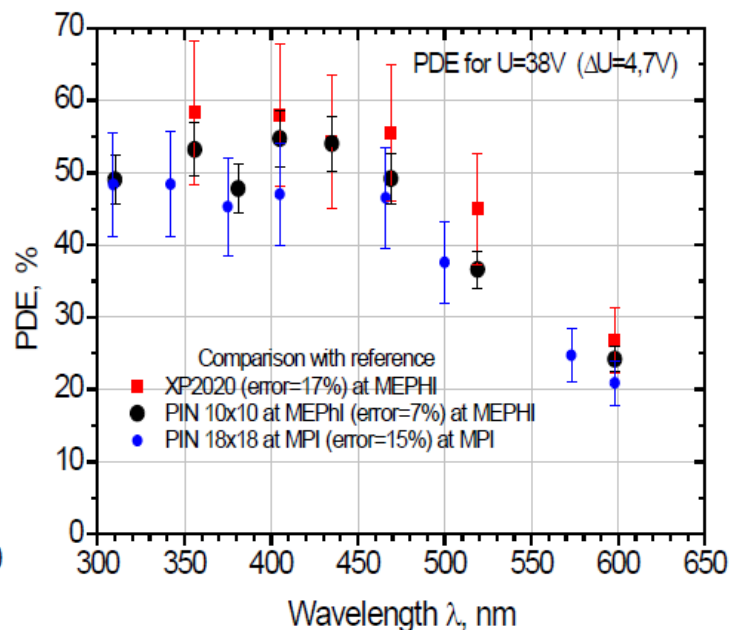
# UV-enhanced SiPMs

MEPHI SiPM (100  $\mu\text{m}$  cell pitch)

Measurements at MEPHI and  
at CERN (thanks to Y.Musienko)



Measurements at MEPHI and at MPI

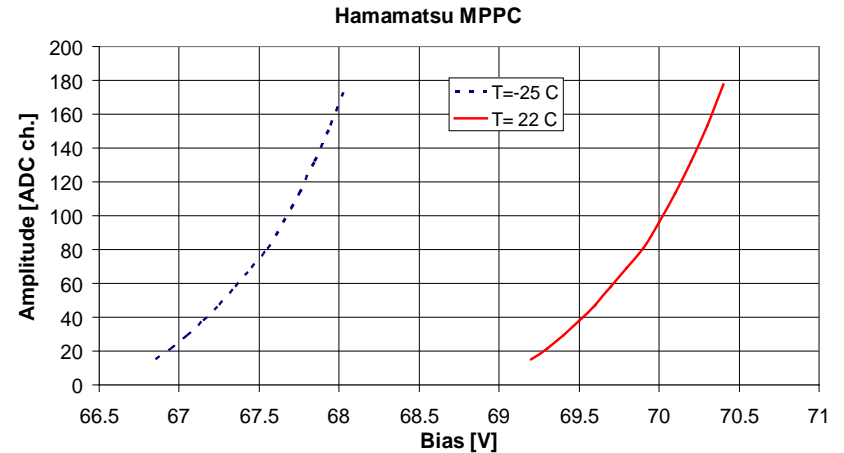
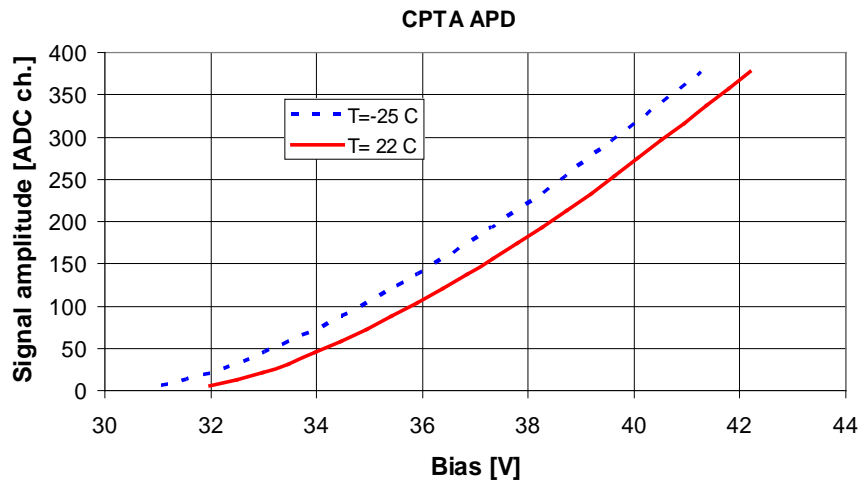


4th July 2011, NDIP-11,  
Lyon, France

E.Popova: Large area SiPM with  
very high PDE and very low X-talk

# SiPM response vs. temperature

SiPM gain and PDE depend on the temperature

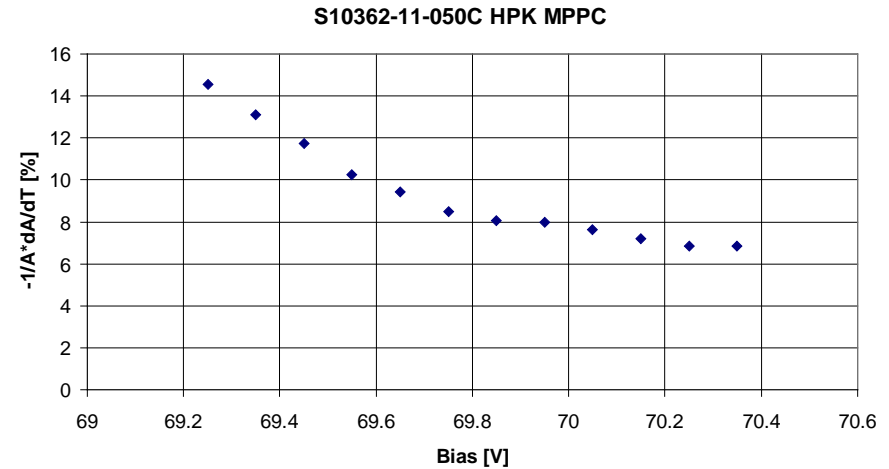
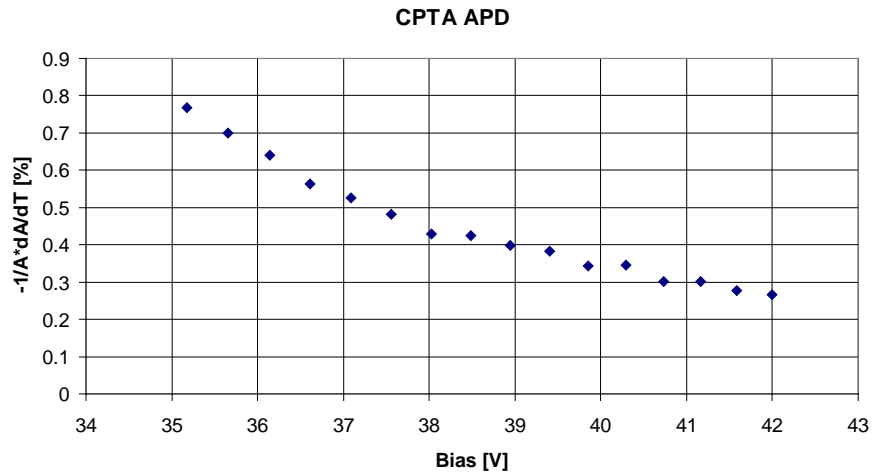


LED signal was measured in dependence on bias at 2 temperatures for SiPMs from 2 producers

**CPTA/Photonique SSPM:**  
 $dVB/dT = -20 \text{ mV/C}$   
**Hamamatsu MPPC:**  
 $dVB/dT = -55 \text{ mV/C}$

(Y. Musienko, PD-07, Kobe)

# Temperature coefficient



$$k_T = dA/dT * 1/A, \quad [%/^{\circ}\text{C}]$$

SiPMs operated at high V-VB have  $k_T \sim 0.3\%/^{\circ}\text{C}$

(Y. Musienko, PD-07, Kobe)

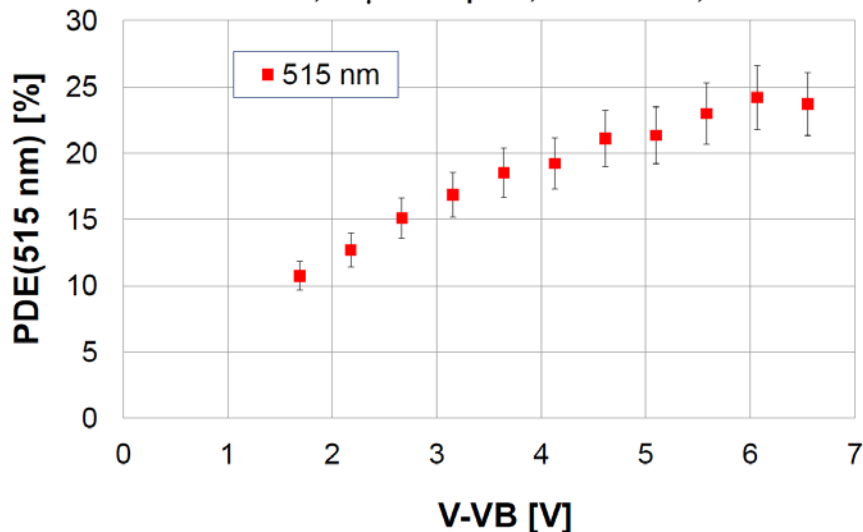
# FBK SiPM development in 2012

In 2012 FBK developed large dynamic range N-on-P SiPMs for the CMS HCAL project.

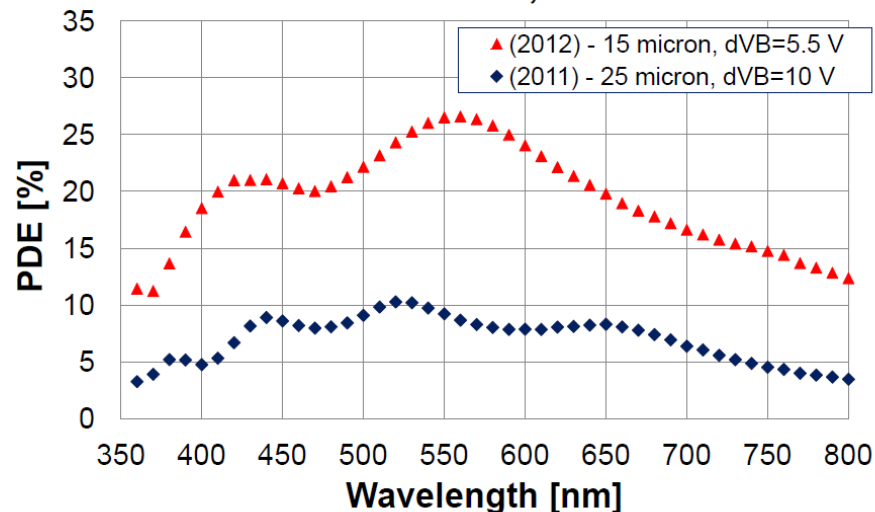
The main goals of the R&D were:

- Reduce cell pitch from 25 to 15 micron
- Produce 2.5 mm dia. SiPM with 15 micron cell pitch
- Improve the PDE of the FBK SiPMs for green light (515 nm)
- Improve radiation hardness of the KETEK SiPMs

FBK SiPM, 15  $\mu\text{m}$  cell pitch, 2.2x2.2 mm<sup>2</sup>, T=24 C

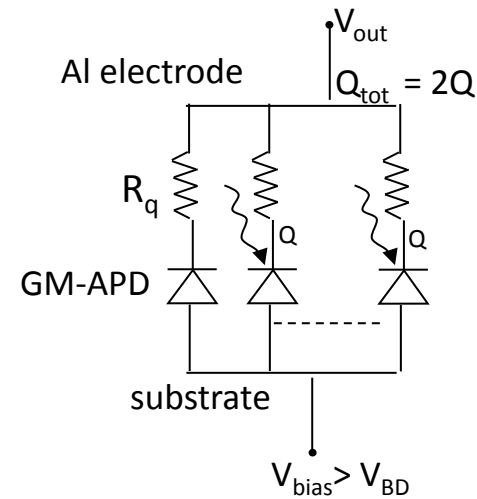
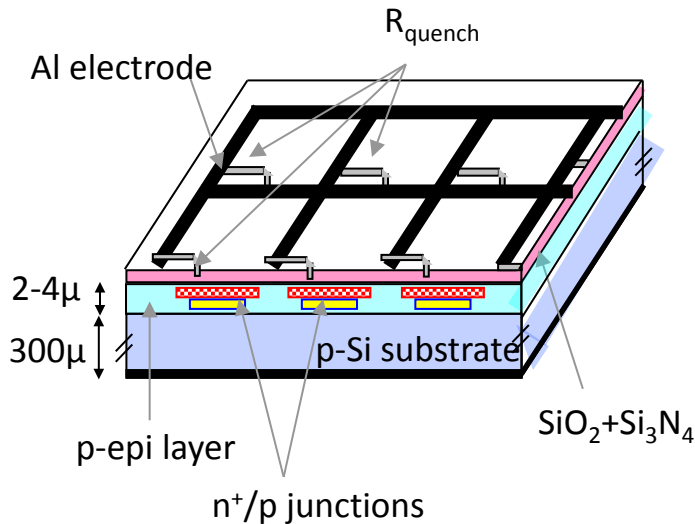


FBK SiPMs, T=22 °C



PDE(515 nm) > 20% for 2012 15  $\mu\text{m}$  cell pitch SiPMs. It was improved by a factor of >2 in comparison to the 2011 25  $\mu\text{m}$  cell pitch SiPM.

# SiPM structure and principles of operation



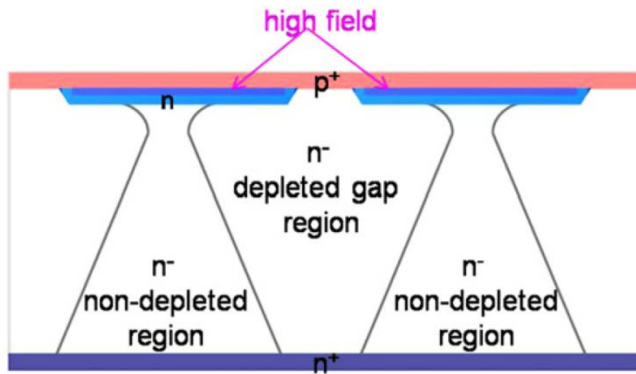
(EDIT-2011, CERN)

- SiPM is an array of small cells (SPADs) connected in parallel on a common substrate
- Each cell has its own quenching resistor (from 100k $\Omega$  to several M $\Omega$ )
- Common bias is applied to all cells (~10-20% over breakdown voltage)
- Cells fire independently
- The output signal is a sum of signals produced by individual cells

For small light pulses ( $N_\gamma \ll N_{\text{pixels}}$ ) SiPM works as an analog photon detector

# SiPMs with bulk integrated quenching resistors from MPI (SiMPI concept)

Schematic cross-section of two neighboring cells



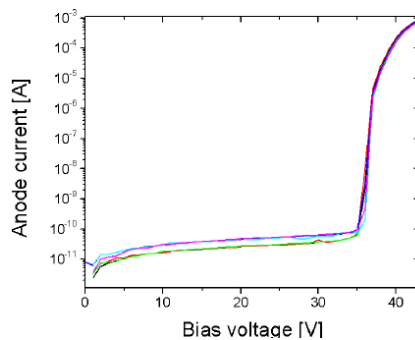
## Advantages:

- no need of polysilicon
- free entrance window for light, no metal necessary within the array
- simple technology

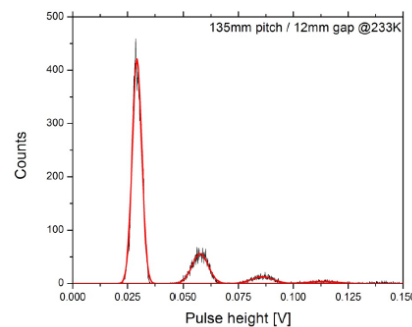
## Drawbacks:

- required depth for vertical resistors does not match wafer thickness
- wafer bonding is necessary for big pixel sizes
- significant changes of subpixel size requires change of material
- worse radiation hardness ??

Static measurements



Dynamic measurements

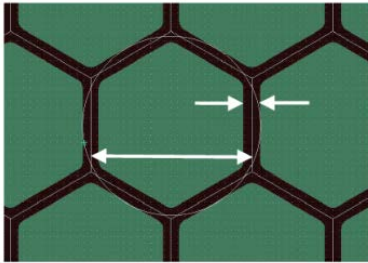


(J. Ninkovic et al., NIM A628 (2011))

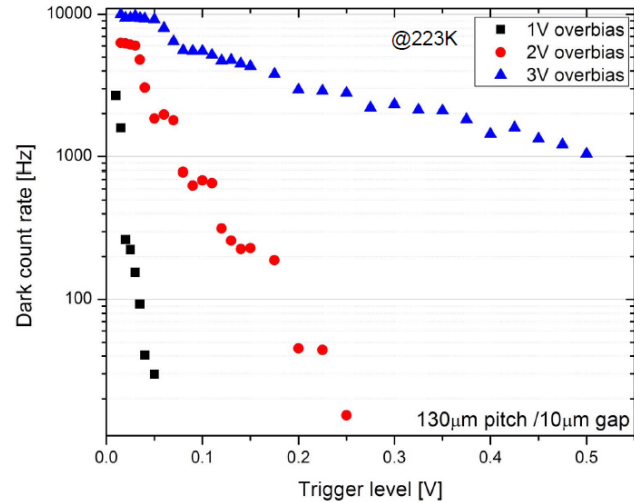
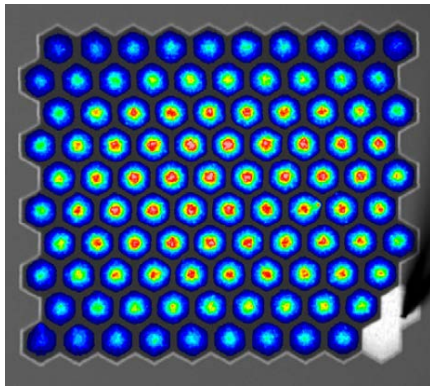


# SiMPI results

Prototype structure was recently produced



Photoemission micrograph for the 100 cell array (135  $\mu\text{m}$  pitch and a 17  $\mu\text{m}$  gap size) operated at 5V overbias.



Pitch / Gap	Fill factor	Cross talk
130 $\mu\text{m}$ / 10 $\mu\text{m}$	85.2%	29%
130 $\mu\text{m}$ / 11 $\mu\text{m}$	83.8%	27%
130 $\mu\text{m}$ / 12 $\mu\text{m}$	82.4%	25%
130 $\mu\text{m}$ / 20 $\mu\text{m}$	71.6%	15%

PDE estimate:

- Optical entrance window: 90% @400nm
- Geiger efficiency : 50% @ 2V overbias      80% @5V overbias

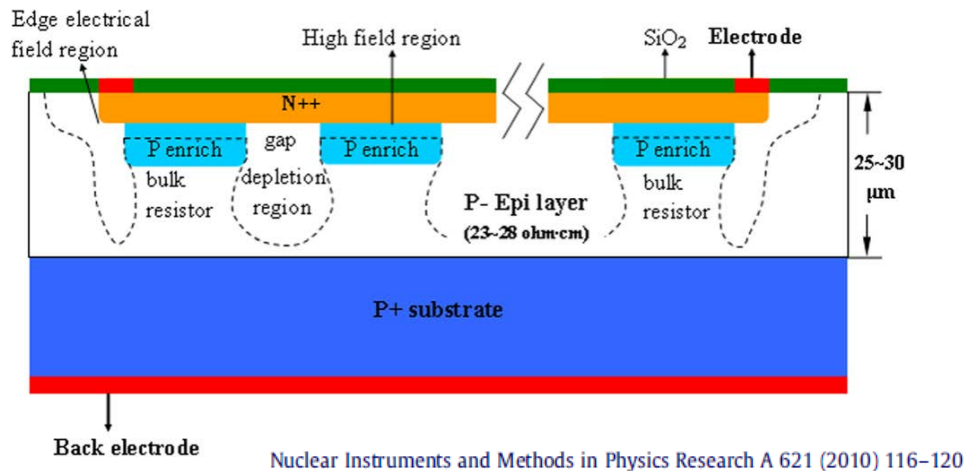
Pitch / Gap	Fill factor	PDE
130 $\mu\text{m}$ / 10 $\mu\text{m}$	85.2%	39%      61%
130 $\mu\text{m}$ / 11 $\mu\text{m}$	83.8%	38%      60%
130 $\mu\text{m}$ / 12 $\mu\text{m}$	82.4%	37%      59%
130 $\mu\text{m}$ / 20 $\mu\text{m}$	71.6%	32%      52%

(J. Ninkovic et al., NIM A628 (2011))

(J. Ninkovic, IEEE NSS/MIC conf., 2010)

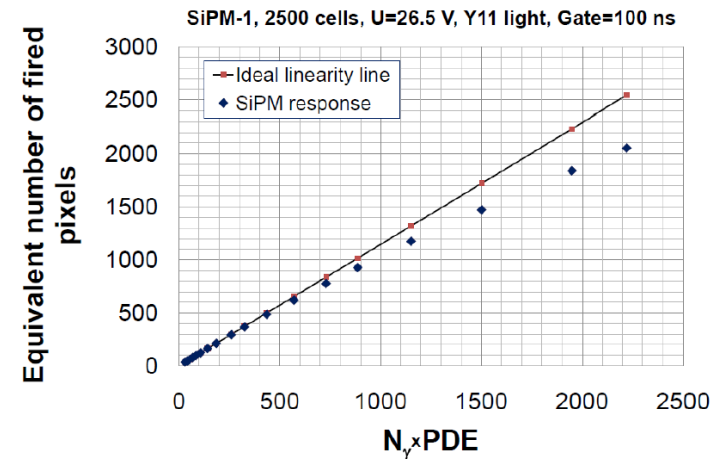
# Large dynamic range SiPMs with bulk integrated quenching resistors from NDL(Beijing)

Schematic structure of the SiPM with bulk integrated resistors ( $S=0.5 \times 0.5 \text{ mm}^2$ , 10 000 cells/ $\text{mm}^2$ )

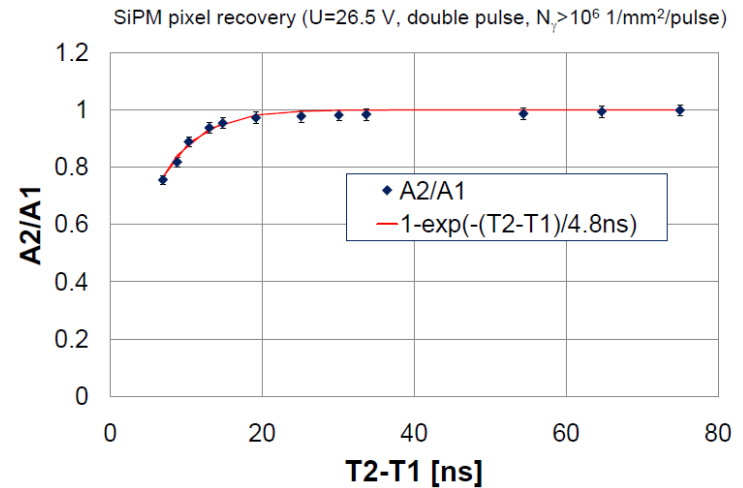
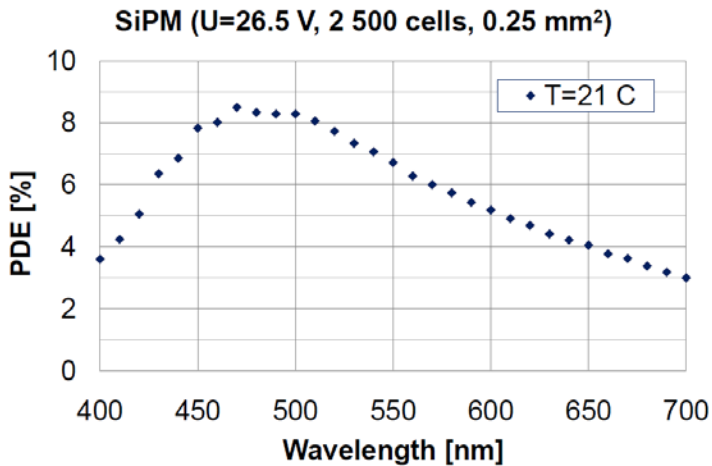
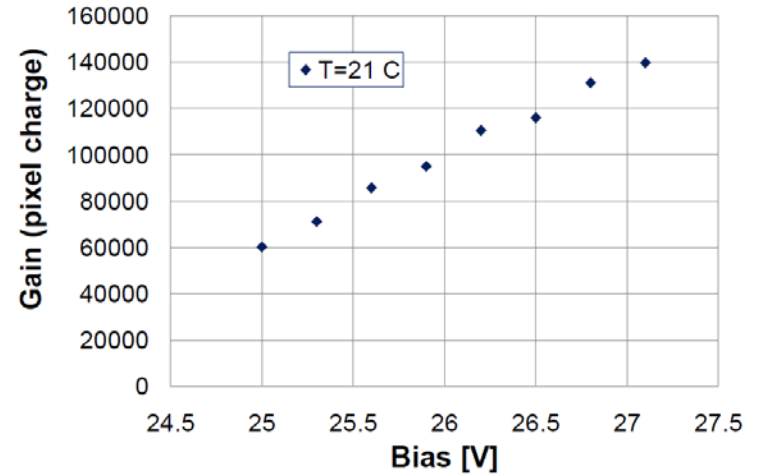
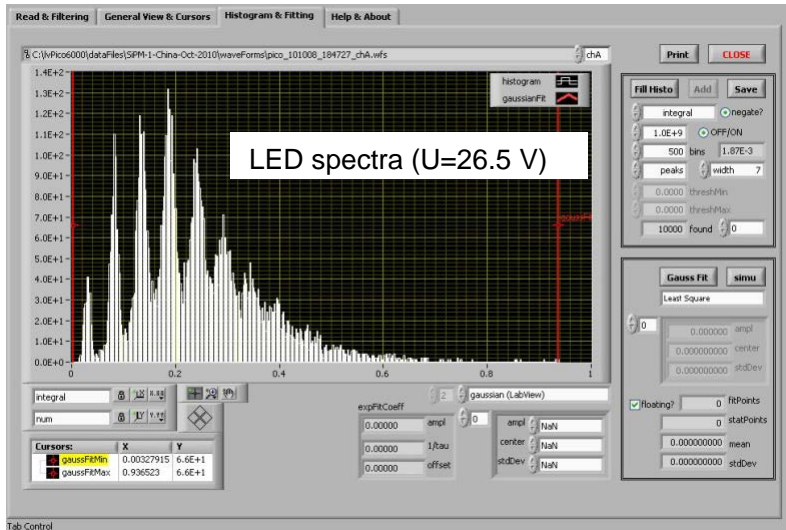


- n on p (structure for green light)
- sensitive area - 0.25  $\text{mm}^2$
- number of cells - 2 500
- operating voltage- 26.5 V
- quenching resistor value - 200-300  $\text{k}\Omega$

## SiPM non-linearity



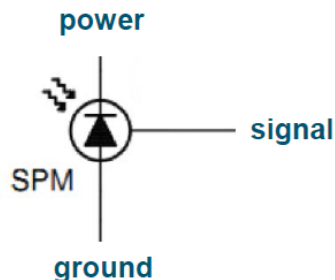
# NDL SiPM results



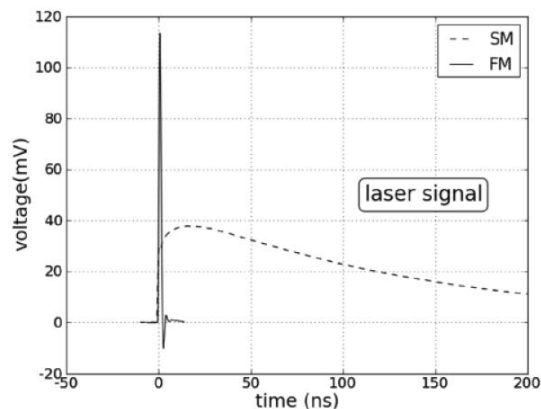
# SiPM with Fast Timing Output (SensL)

SensL has developed a fast mode output in addition to the standard output

SensL Micro-FB-10035-X18 SiPM (45  $\mu\text{m}$  cell pitch)

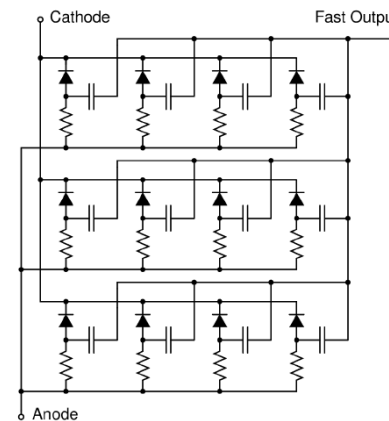


N. Pavlov, "Silicon Photomultiplier and Readout Method", *USPTO Patent Application Publication*, No. US2013/0099100 A1, 2013.

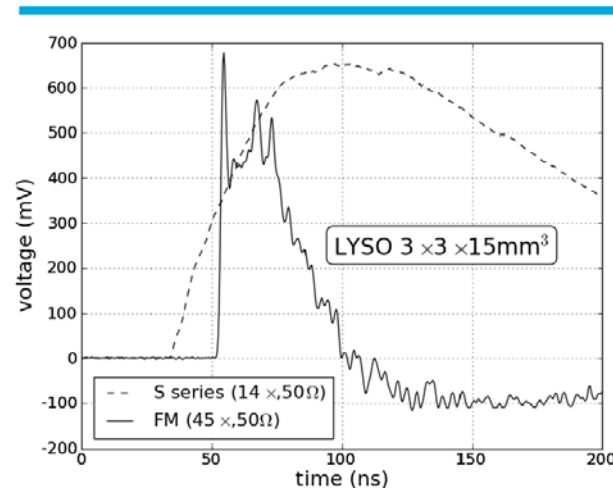


Comparison of typical MicroFM output with that from other conventional SensL SPMs (such as the MicroSM) when illuminated with a fast laser.

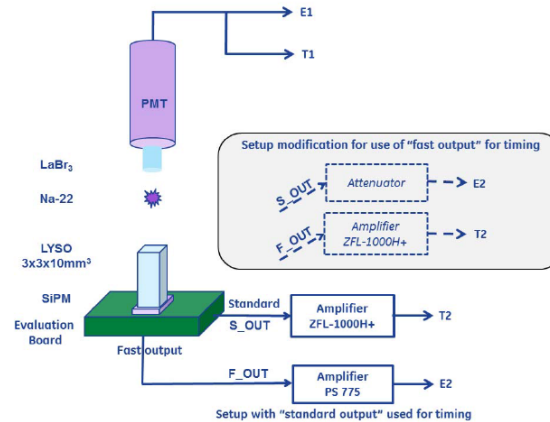
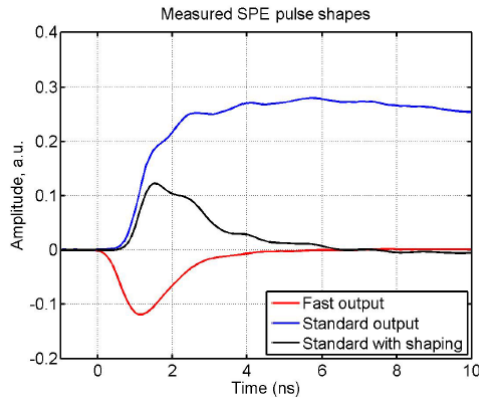
Concept schematic of the SensL fast output SiPM



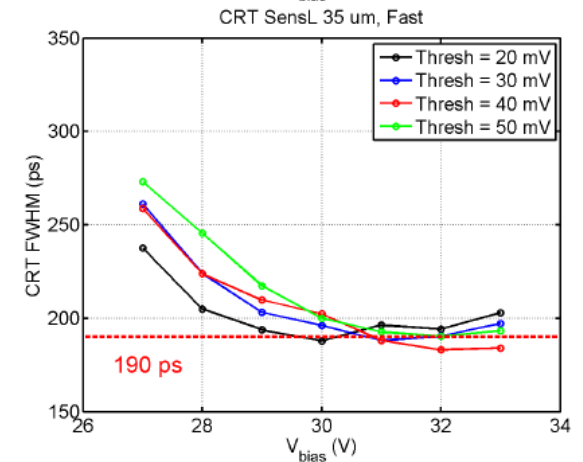
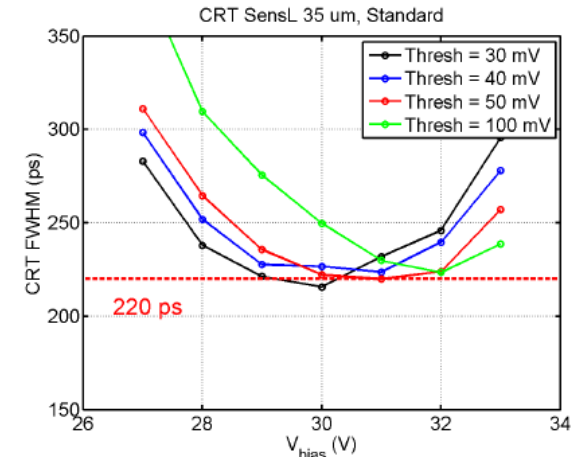
FM Signal with L(Y)SO Output



# CRT measurements using MicroFB SensL SiPM

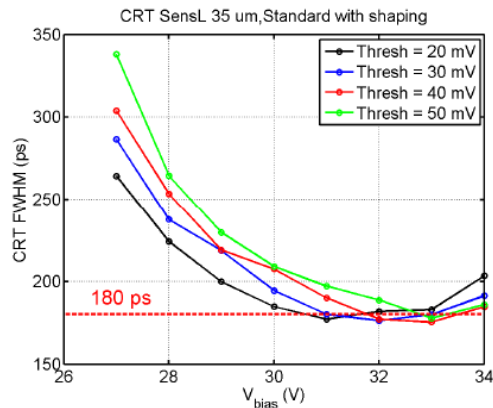


Measured SPE signals from SensL MicroFB-30035 SiPM



## CRT measurement set-up

S.Dolinsky et al., 2013  
IEEE NSS-MIC Conference  
Record

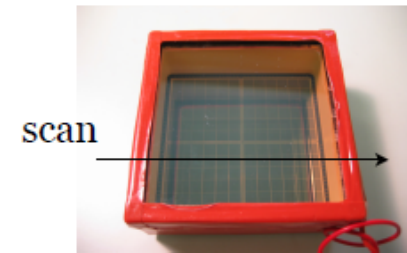
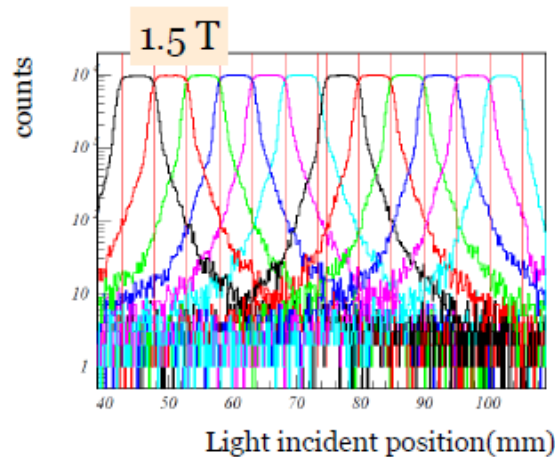
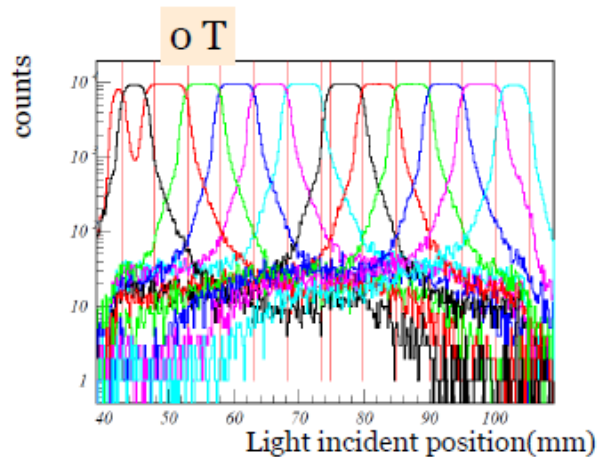


Measured CRT vs. SiPM bias from SensL MicroFB-30035 SiPM with external C-R shaping ( $t=2$  ns) applied to standard output.

Measured CRT vs. SiPM bias for a fixed timing comparator threshold for SensL MicroFB-30035 SiPM. Top: standard output used for timing. Bottom: fast output used for timing

# HAPD response in magnetic field

- Response scan for entire HAPD channels were done under an axial magnetic field of 1.5 Tesla.

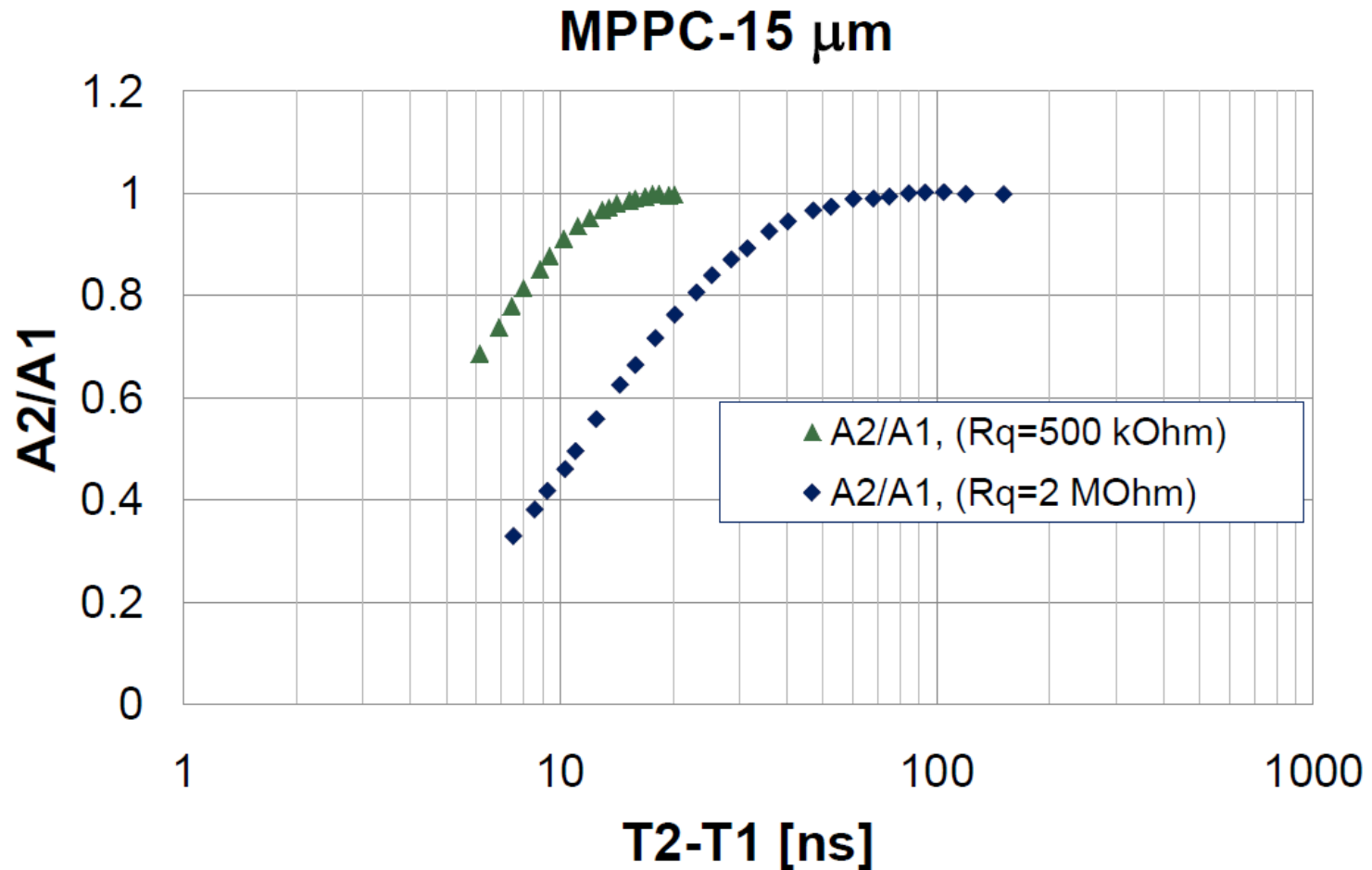


The excellent response for single photon and background becomes better

Performance is improved in the presence of a magnetic field !

(I.Adachi, PhotoDet 2012)

# Cell recovery studies with fast UV LED



Measured using double LED pulse method

# Time resolution

SiPMs have excellent timing properties

Dependence of SiPM timing on the  
number of simultaneous photons

FBK SiPM

Poisson statistics:  $\sigma_t \propto 1/\sqrt{N_{pe}}$

